

CEPC vertex detector prototype status

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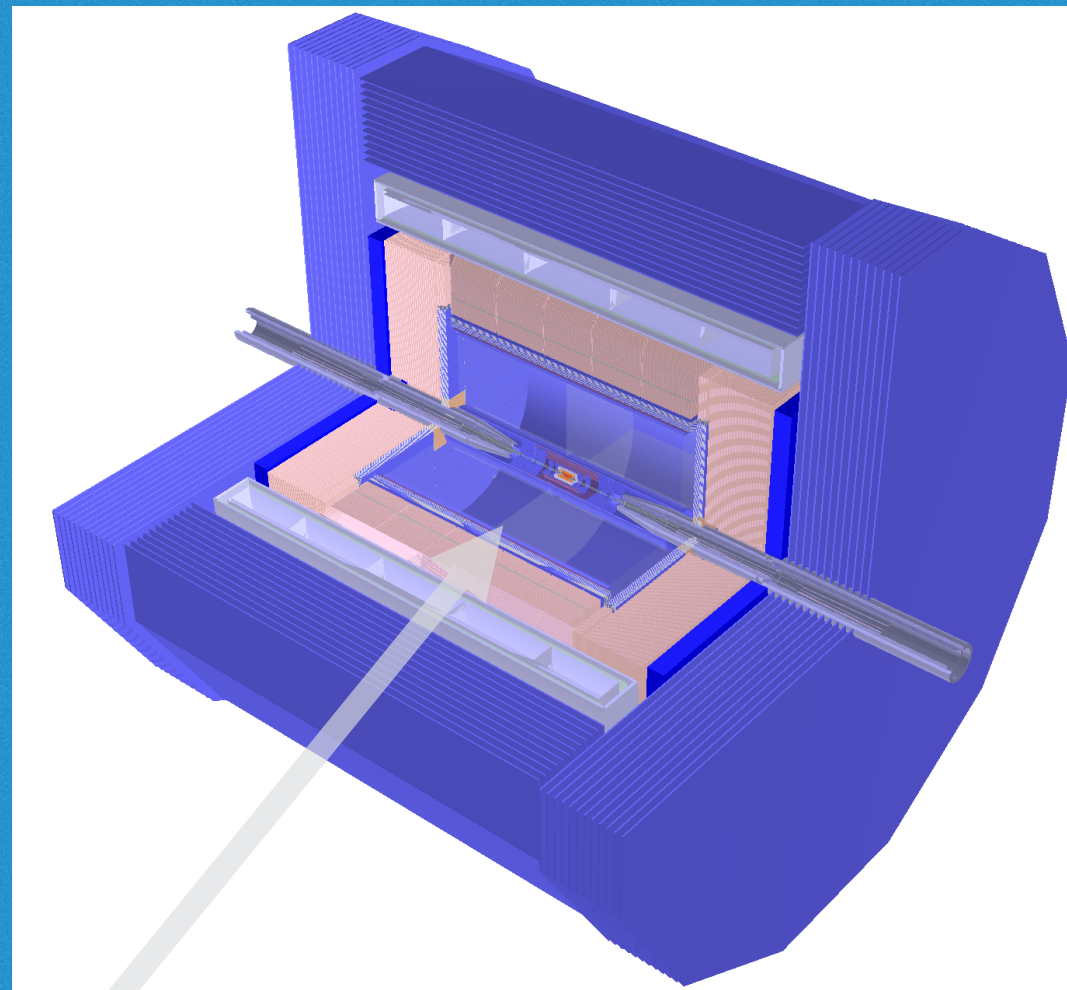
For the CEPC vertex detector prototype team

CEPC detector concept

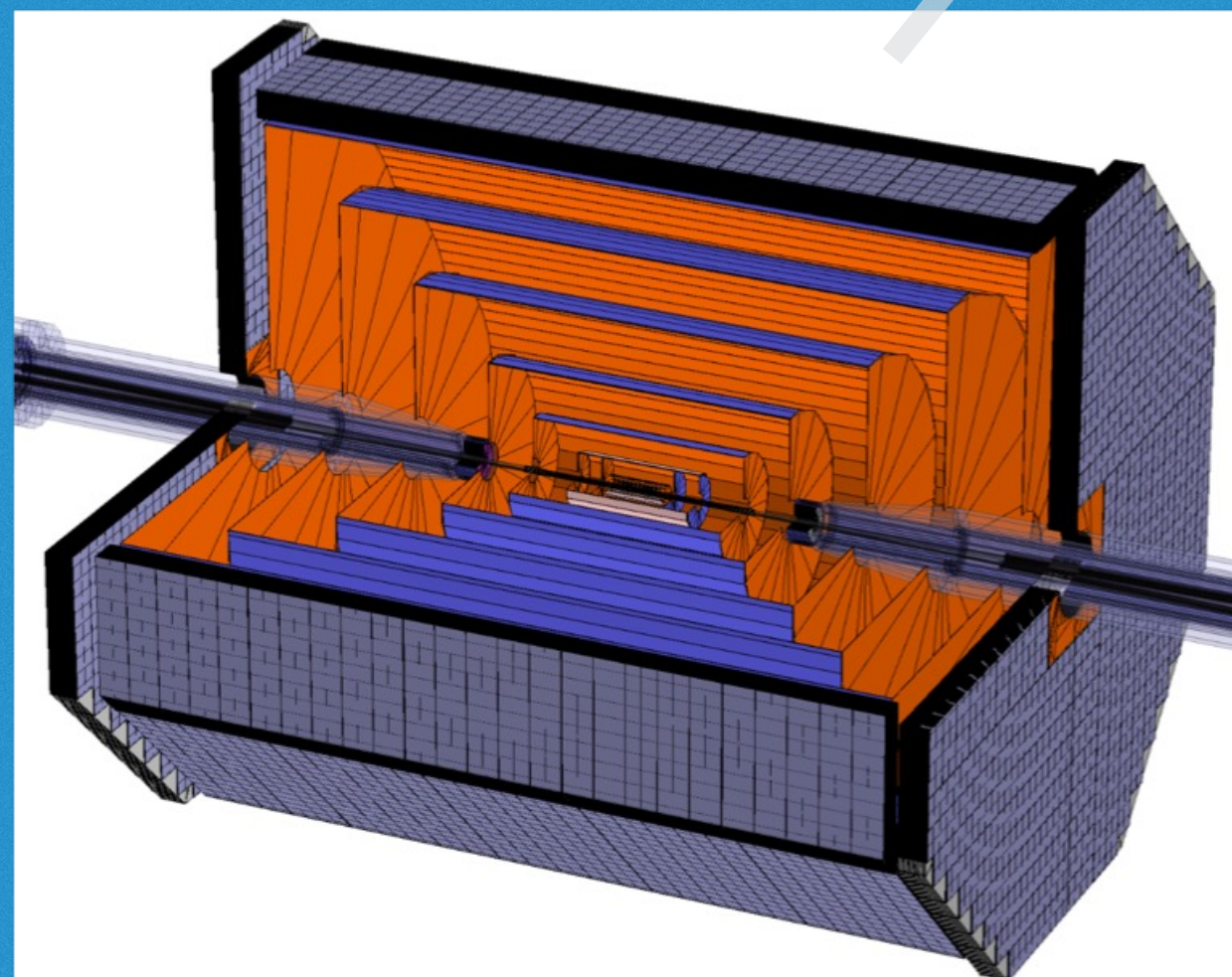
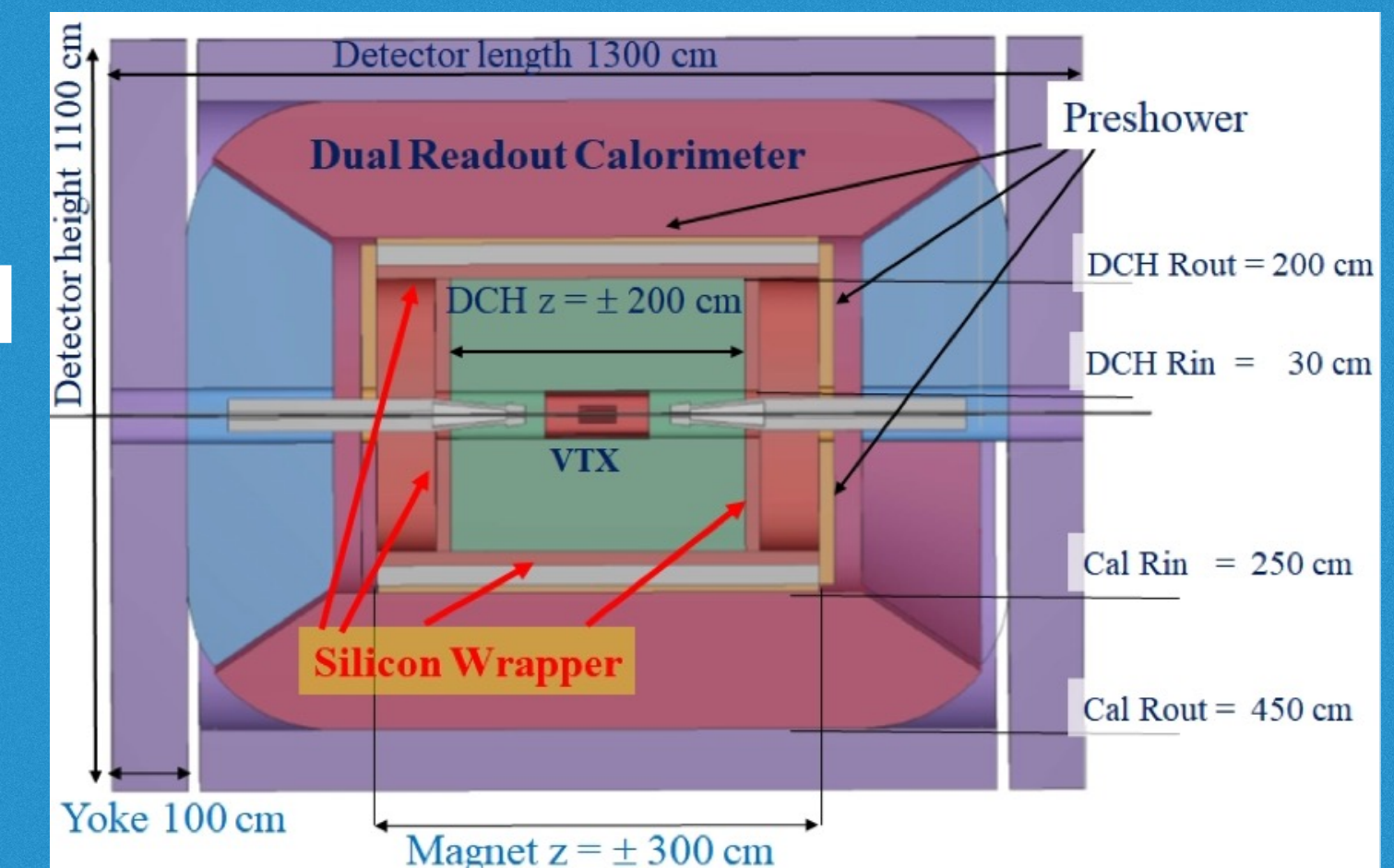
**CEPC plans for
2 interaction points**

➤ **All four detector concepts require high-precision silicon vertex detectors**

**ILD-like detector
(3 Tesla)**

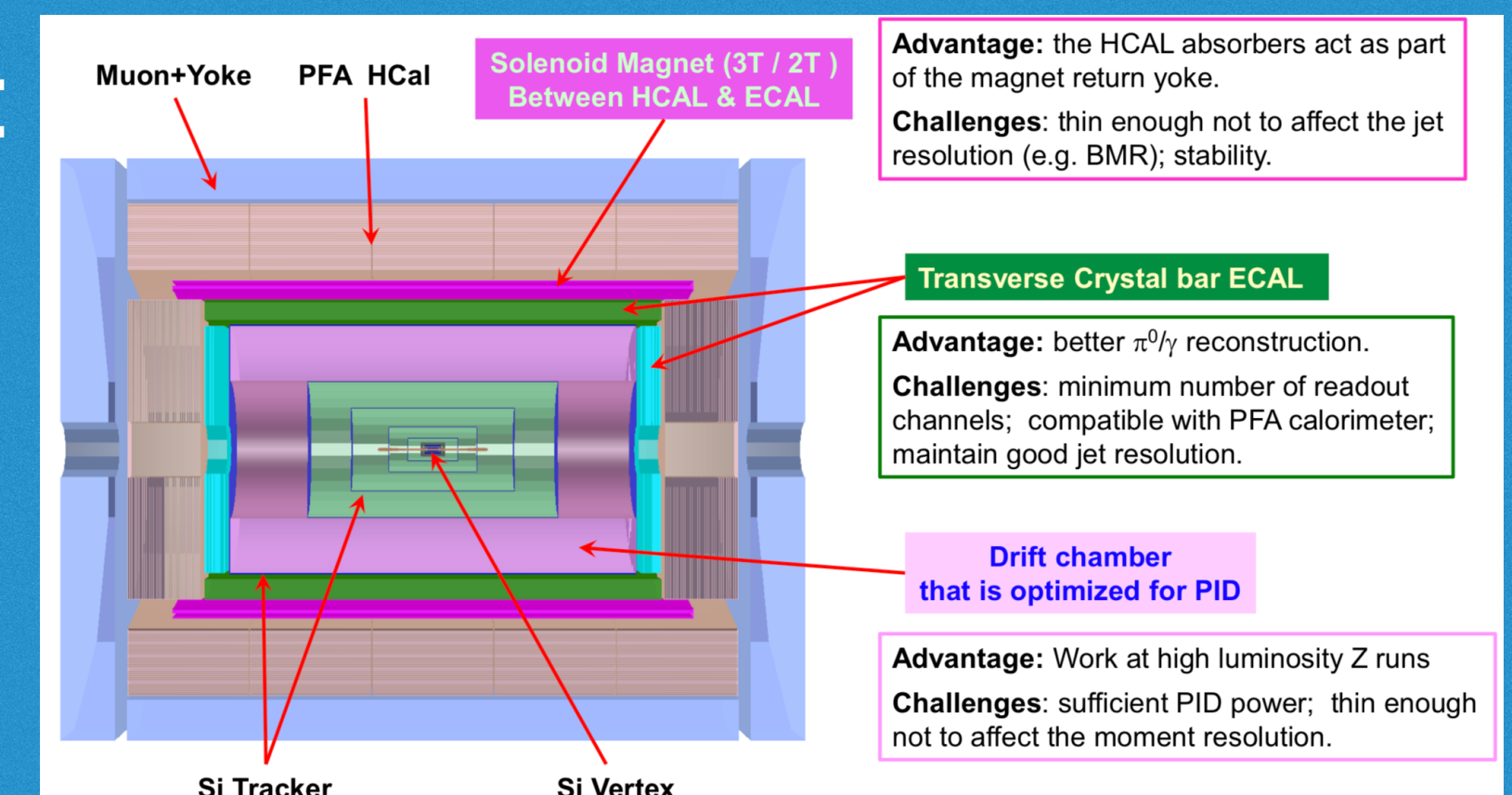


**Low
magnetic field
concept
(2 Tesla)**



**Full silicon
tracker
concept**

4th concept



Vertex detector: Physics goal

- Produce a world-class vertex detector prototype
 - Small inner radius, close to beam pipe
 - Spatial resolution: $3\sim 5\ \mu\text{m}$ (pixel detector)
 - Low material budget $<0.15\% X_0$ per layer
 - Timing resolution: $\sim 25\text{ns}$ (40MHz collision @ Z pole)

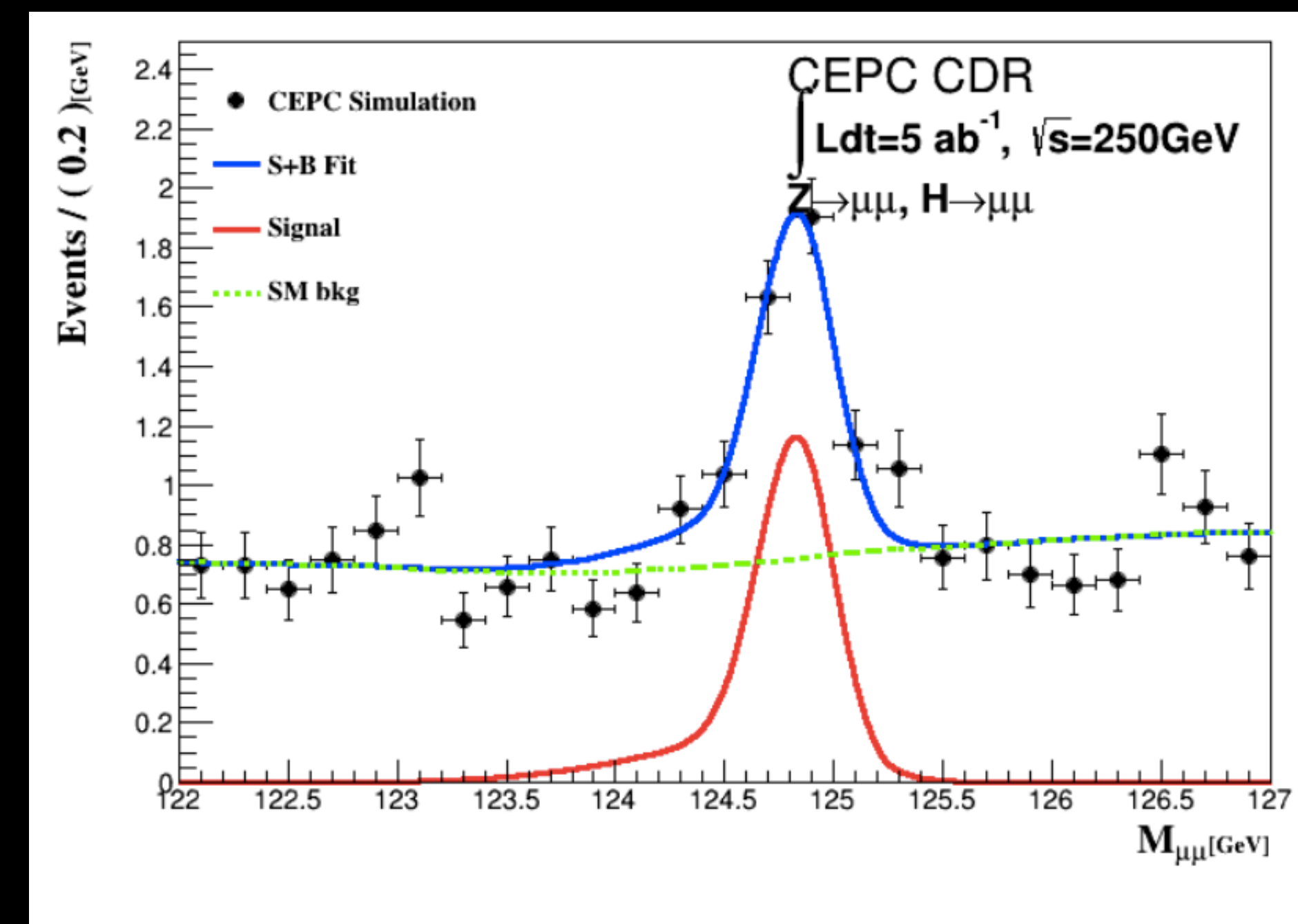
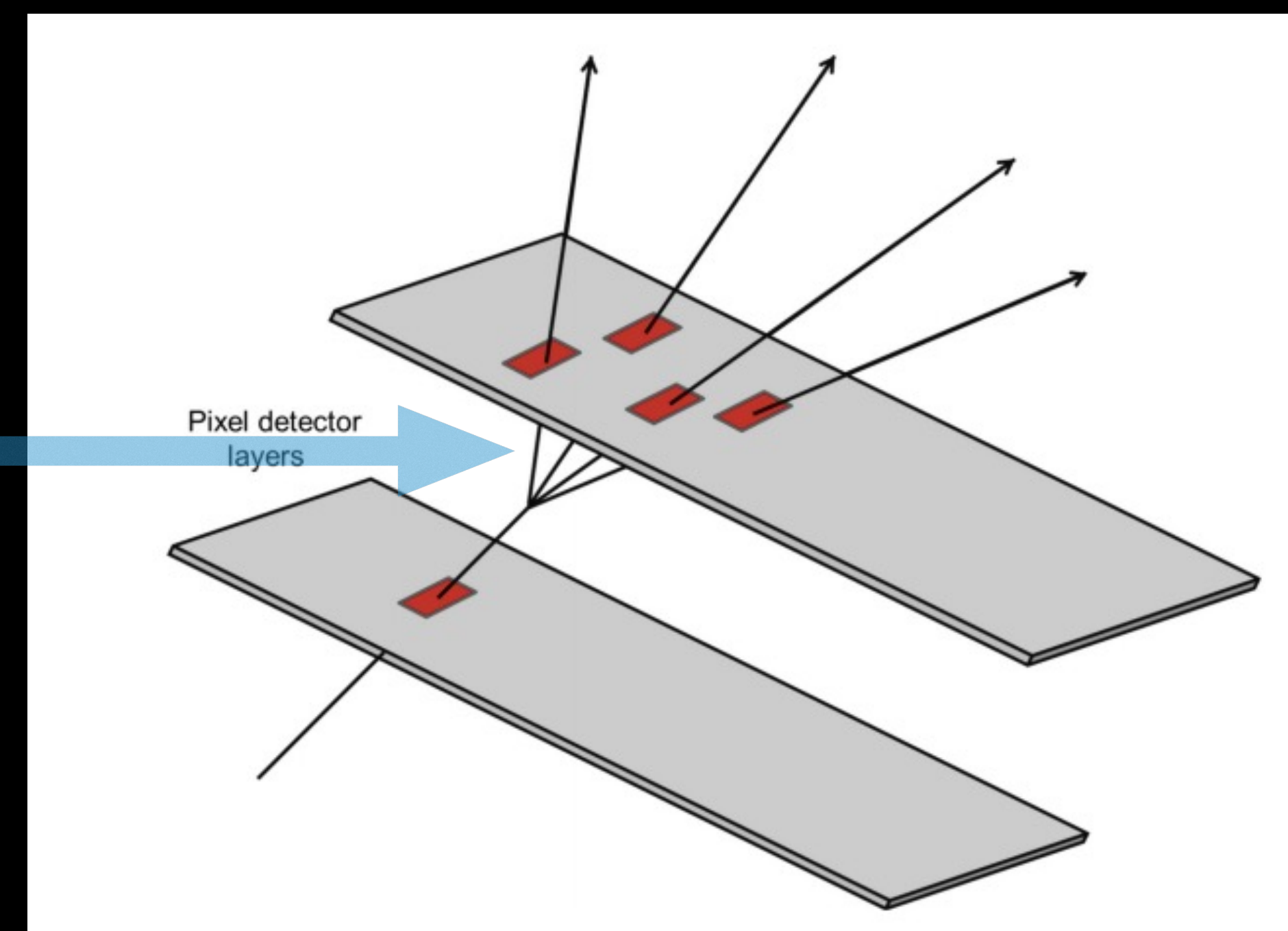
- Physics motivation

- Higgs precision measurement
 - $H \rightarrow b\bar{b}$ precise vertex reconstruction
 - $H \rightarrow \mu\mu$ (precise momentum measurement)

**Need tracking detector with
high spatial resolution**

- Main technology

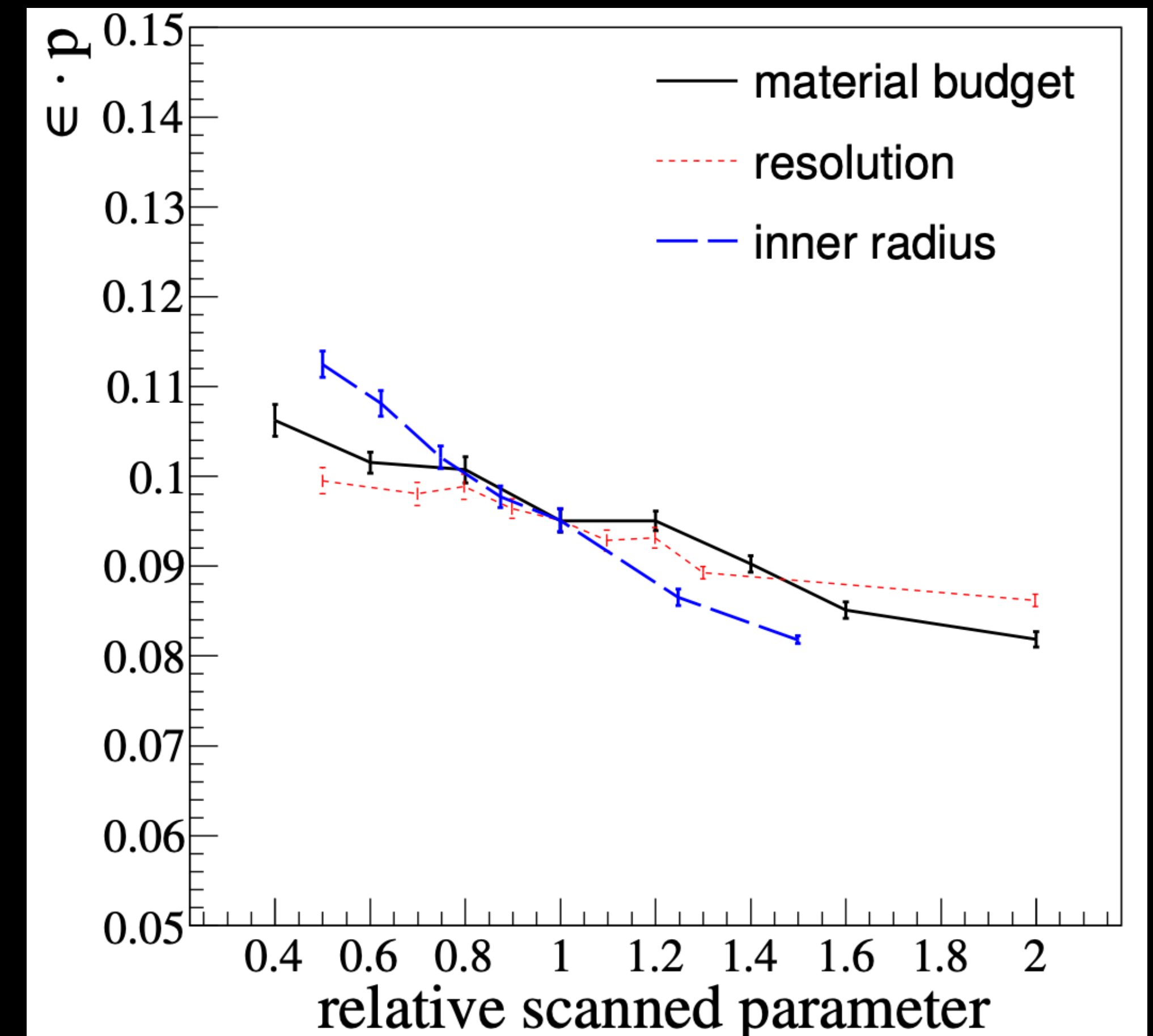
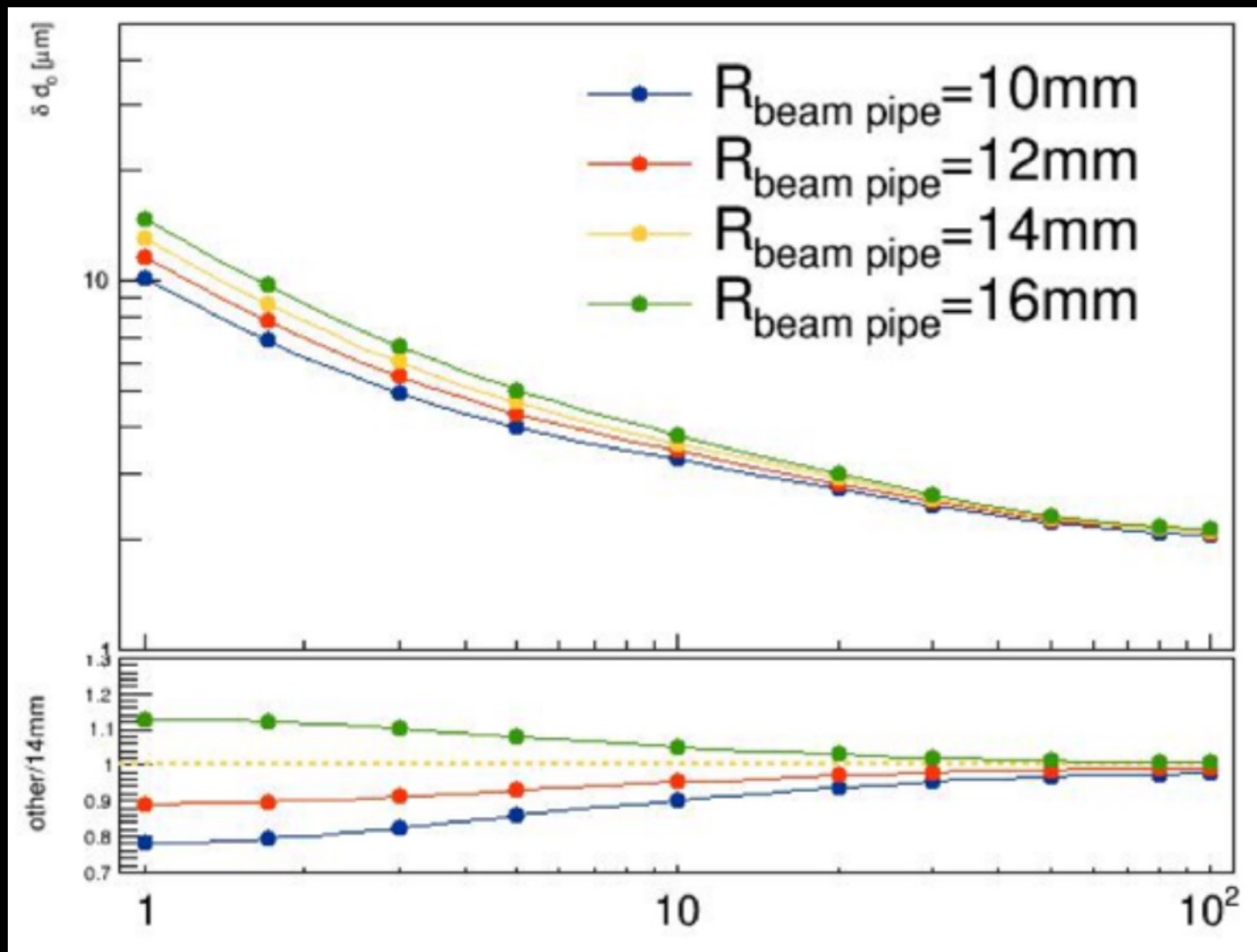
- Develop the know-how in China to build such detector
- High spatial resolution technology \rightarrow pixel detector
- Radiation resistance technology



Requirement on vertex detector

- 1st priority: Small inner radius, close to beam pipe (new baseline beam pipe radius=**10um**)
- 2nd priority: Low material budget **<0.15% X0 per layer**
- 3rd priority: High resolution pixel sensor: **3~5 μm**
- Global Timing resolution of CEPC tracker: **$\sim 25\text{ns}$ (40MHz collision @ Z pole)**

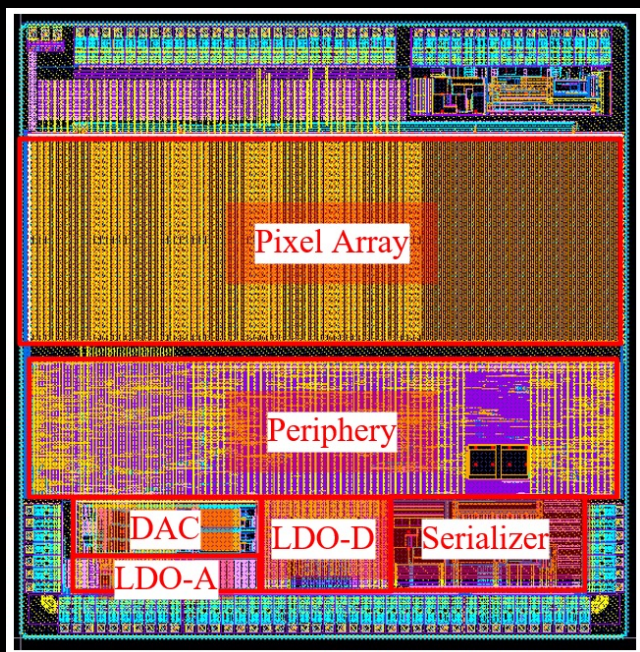
C-tagging performance



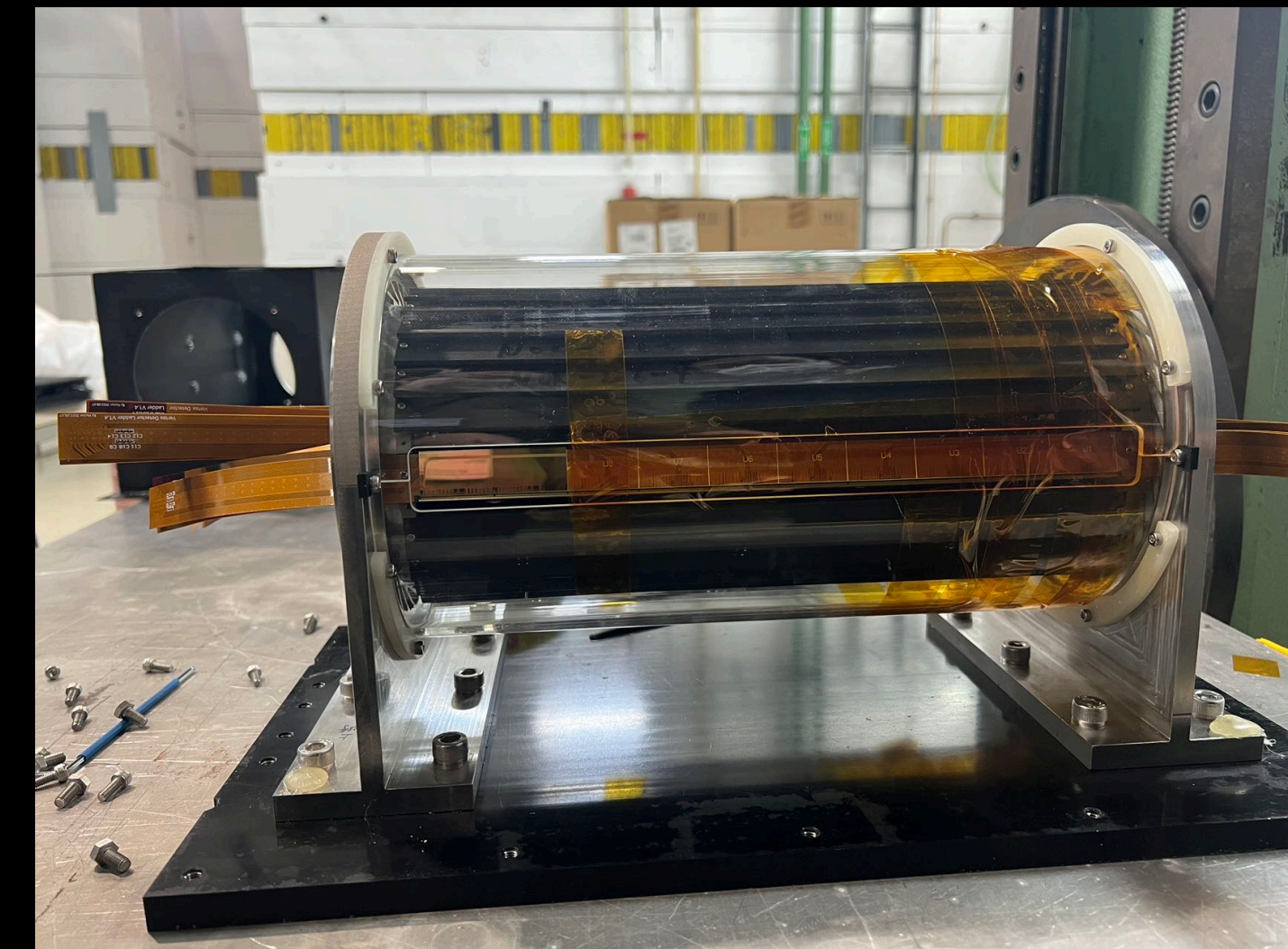
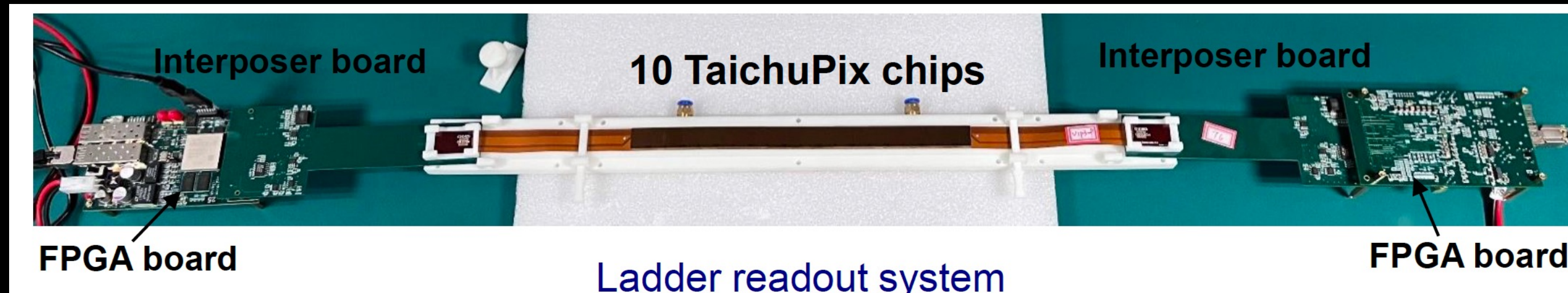
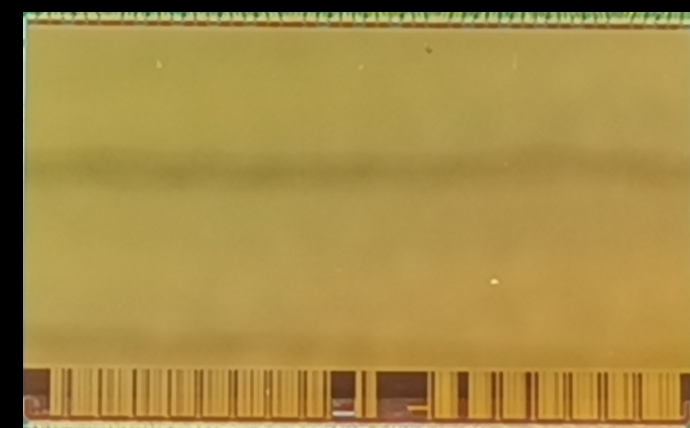
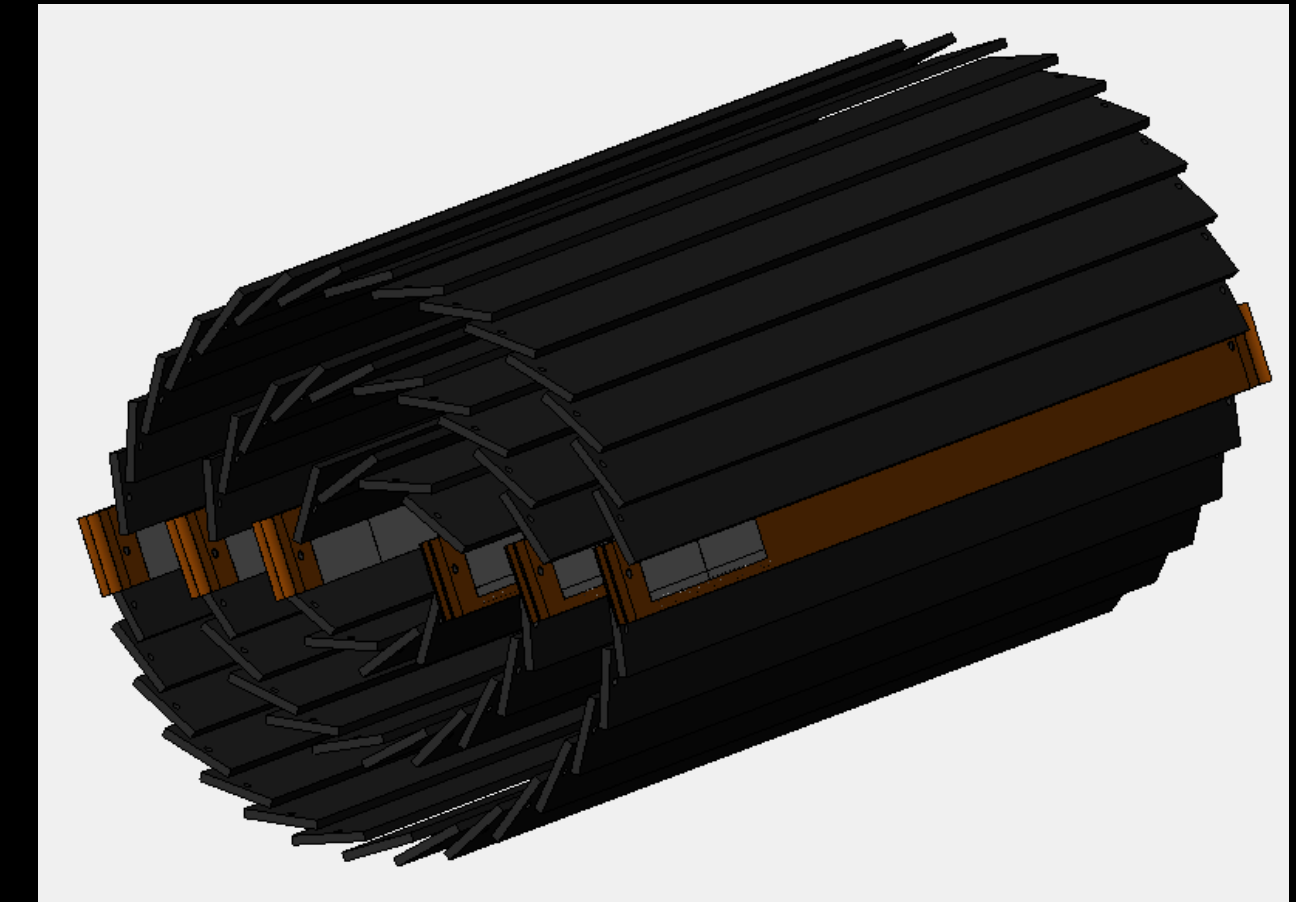
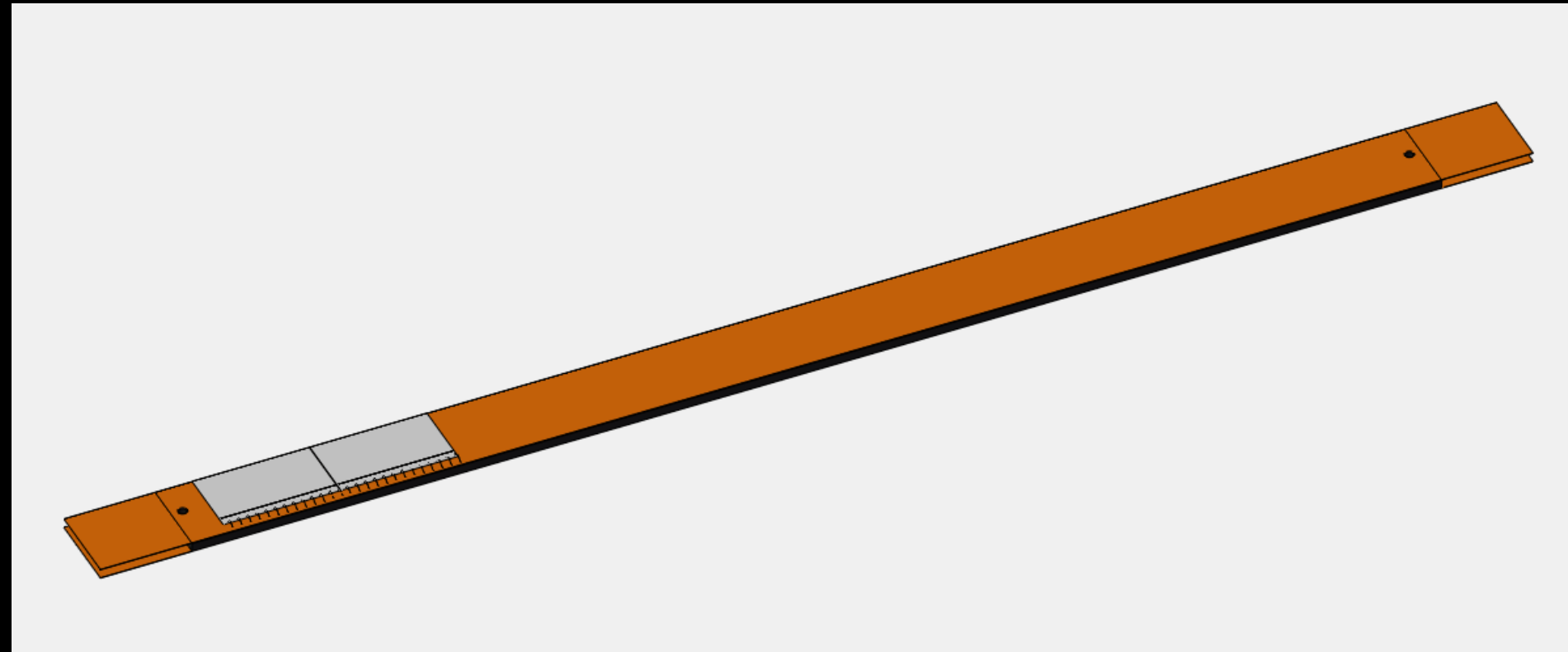
Overview of CEPC vertex detector R & D

Vertex detector Prototype for beam test

CMOS imaging sensor prototyping



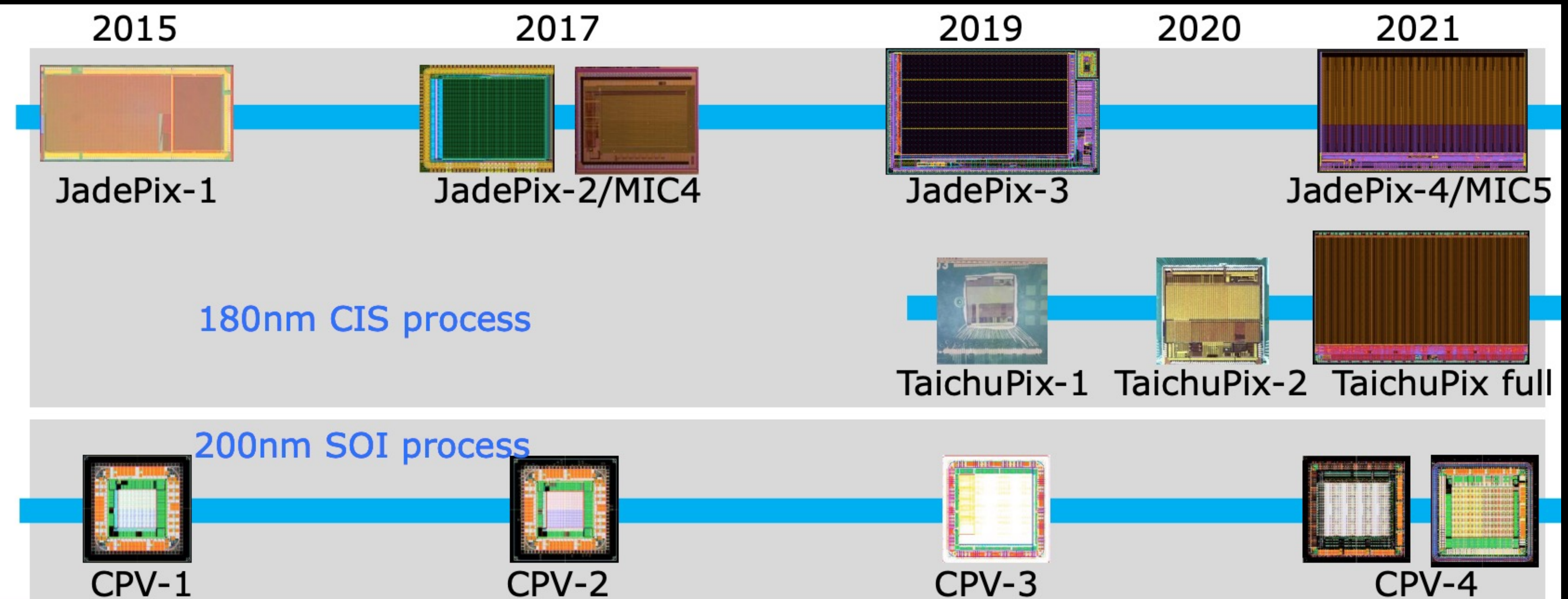
Detector module (ladder) Prototyping



- Design CMOS imaging sensor chip
- Detector Module prototyping
- Vertex Detector assembly and testbeam

Road map of sensor R & D

- This talk focus on more TaichuPix based CEPC vertex detector prototype
- More details chip development in talks tomorrow in electronics section
- 3D-integrated pixel circuit for a low power and small pitch SOI sensor, Yunpeng LU
- Development of TaichuPix pixel chips for the first CEPC vertex detector prototype, Ying Zhang



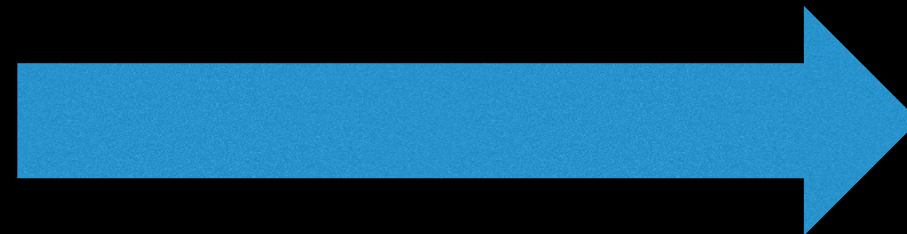
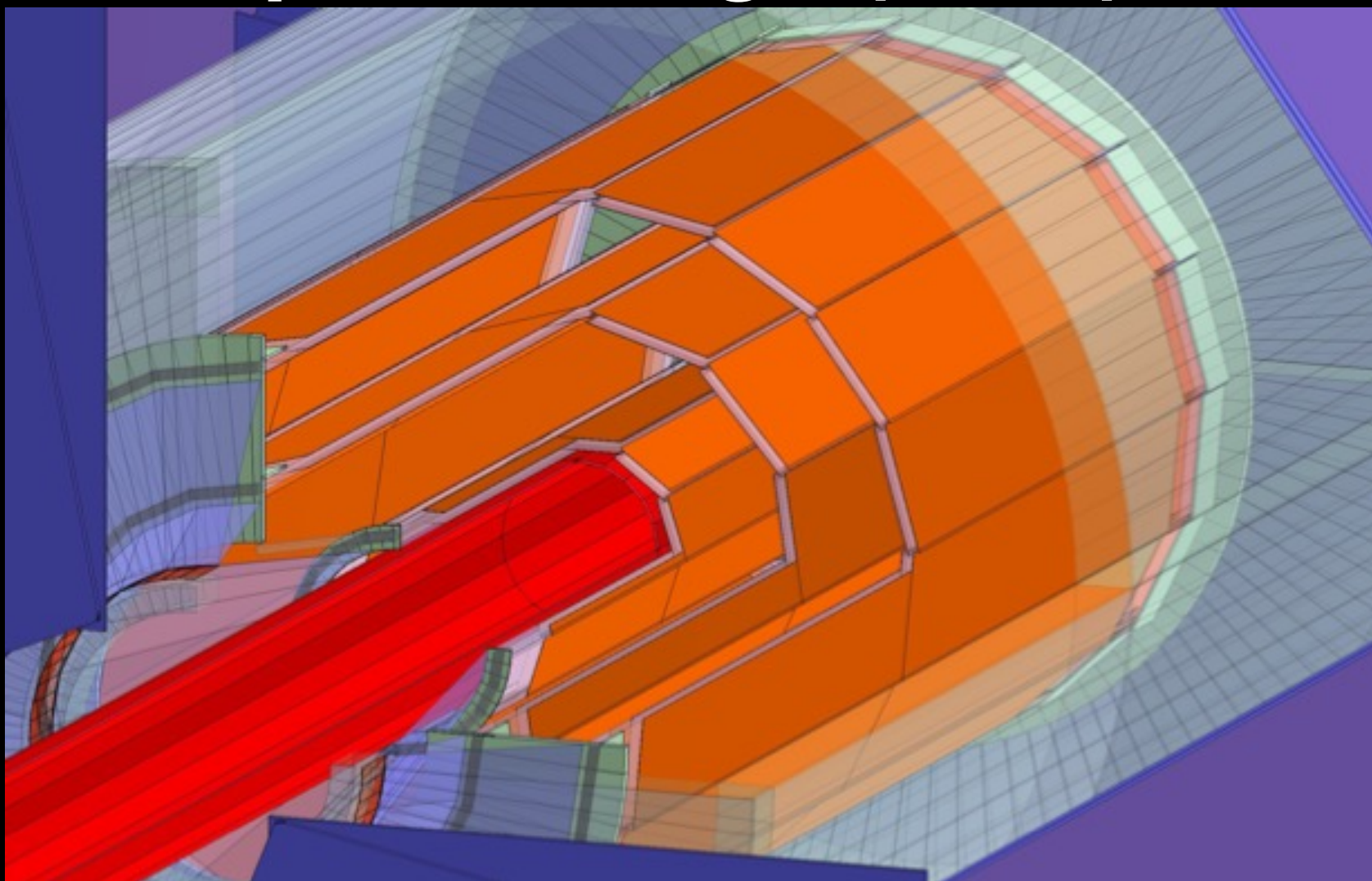
Research Team in MOST2 silicon project

Institutes	Tasks
IHEP	Full CMOS chip modeling, Pixel Analog, PLL block Detector module (ladder) prototyping Data acquisition system R & D Vertex detector assembly and commissioning Irradiation, test beam organization
IFAE(Spain)/CCNU	CMOS sensor chip: Pixel Digital
NWPU	CMOS sensor chip: Periphery Logic, LDO
ShanDong University	CMOS sensor chip: Bias generation, TCAD simulation Sensor test board design
Nanjing University	Irradiation, test beam

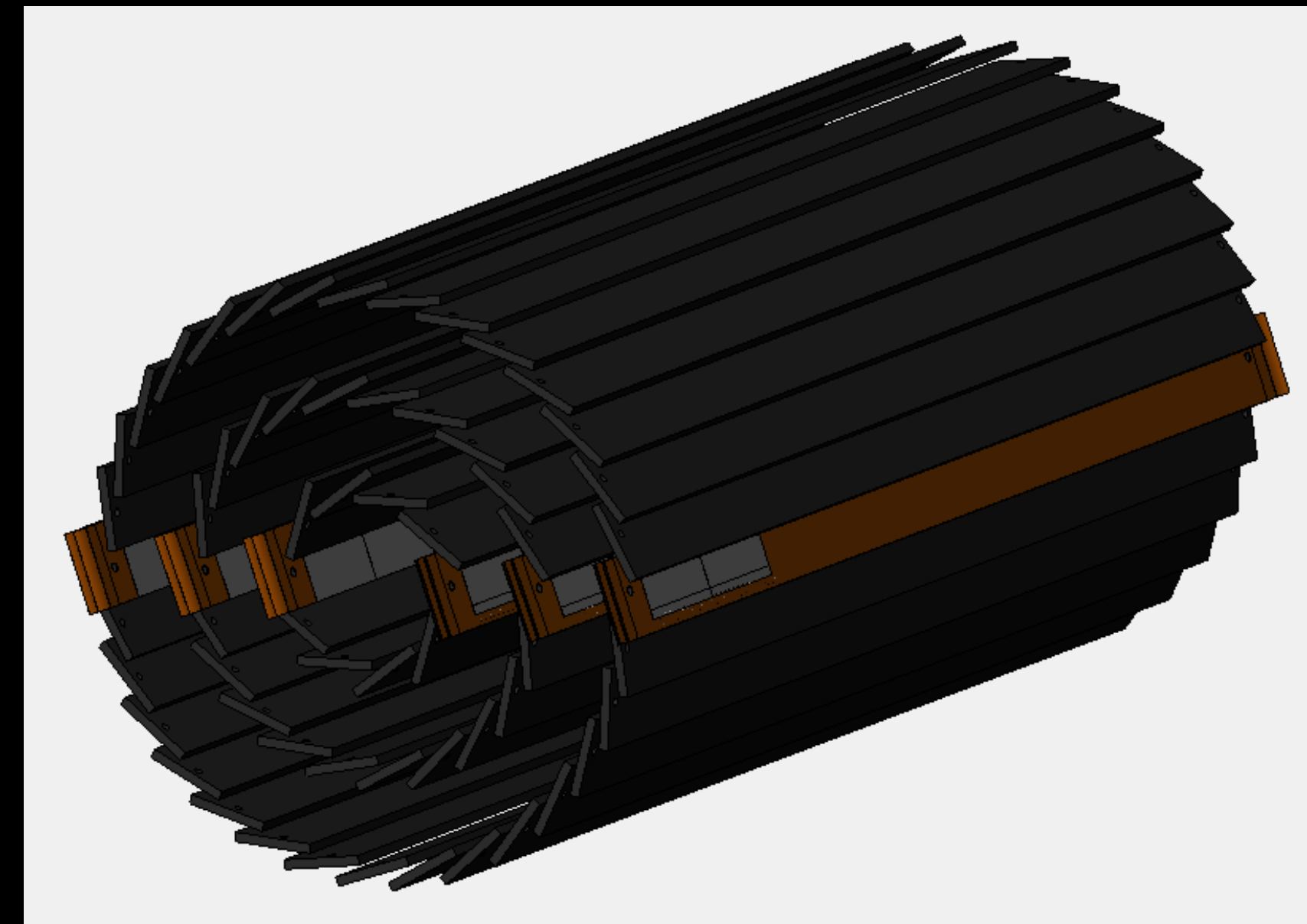
Vertex detector prototype structure optimization

- Based on CEPC vertex detector conceptual design → Three double-layer barrel detector
 - This project plan to prototype the important part of vertex detector (CDR design)
 - The cost for the full vertex detector is high (eg: ~50 M CHF for ATLAS ITk pixel detector)
 - Plan to build full mechanical part of the detector
 - install a sector of ladders in prototype , not necessary to build full vertex for R & D
- Optimize the geometry based on real ASIC and electronics dimension
 - Optimize geometry based on its physics performance from simulation
 - Engineering design of prototype structure

**CEPC Vertex detector
Conceptual design (2016)**

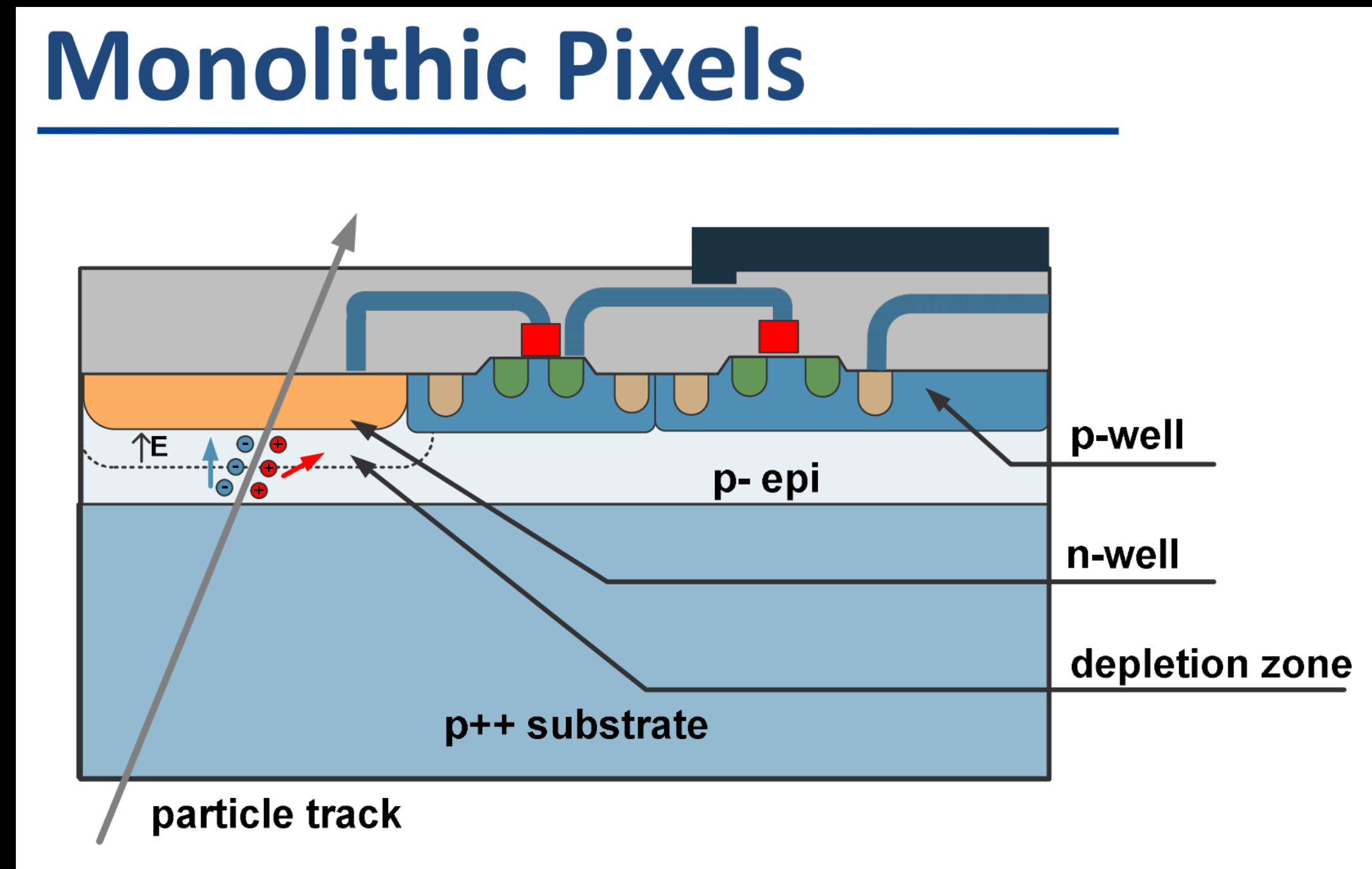
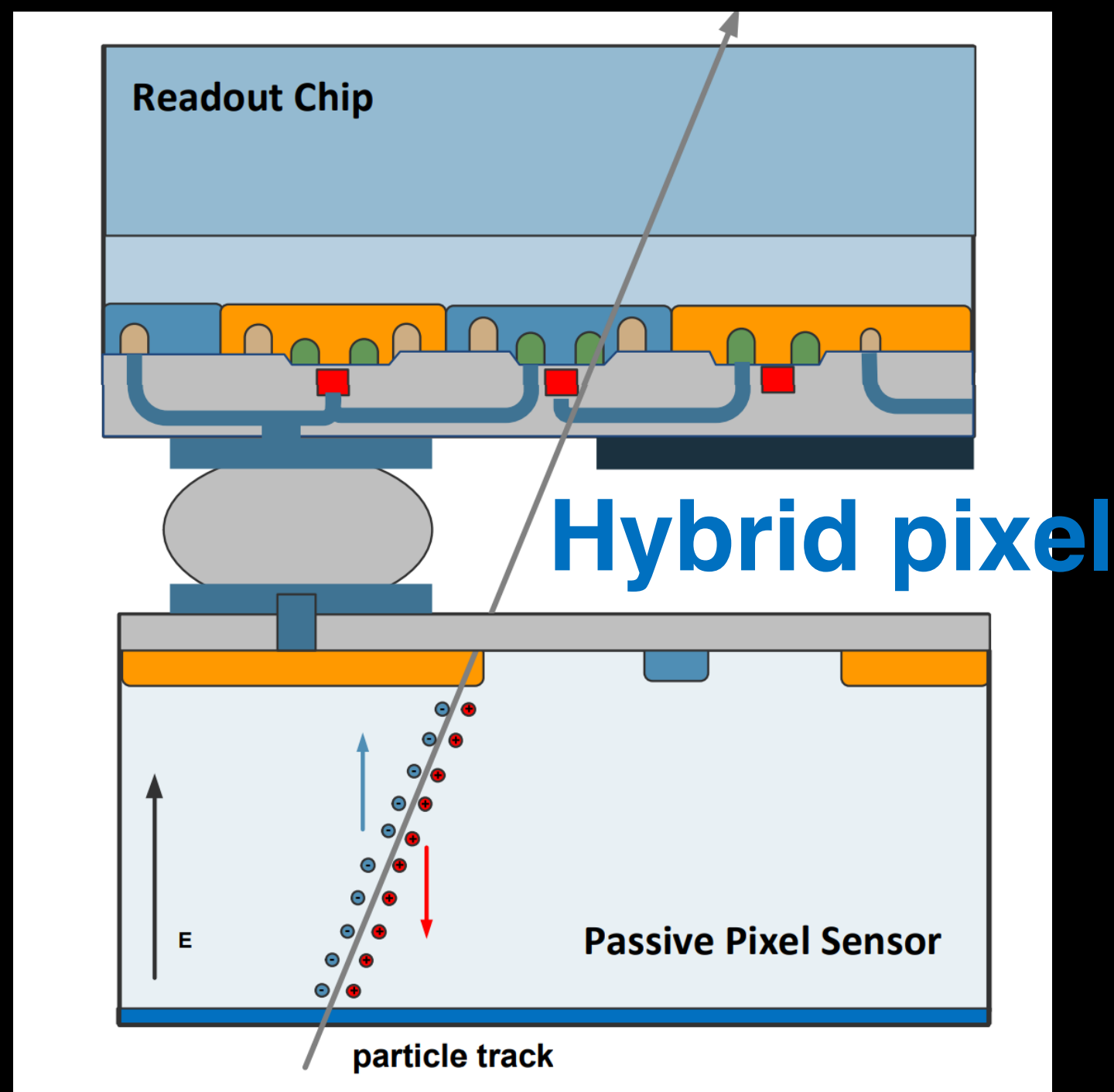


**This project
Vertex detector prototype design**



CMOS MONOLITHIC PIXEL SENSOR

- Conventional Hybrid pixel technology at Large Hadron Collider
 - Need to bump bonding with readout ASIC
 - Typical pixel size $\geq 50\mu\text{m}$, much more difficult for bump bonding with smaller pixels
- CMOS Monolithic pixel (CIS process) is ideal for CEPC application
 - Sensor and ASIC high integrated in one chip, easier for detector assembly
 - Can have compact structure in pixel array design.
 - Pixel size can be reduced to $25\mu\text{m}$ or below \rightarrow can achieve better spatial resolution



CMOS Sensor chip R & D

- The existing CMOS monolithic pixel sensors can't fully satisfy the requirement
- Major Challenges for the CMOS sensor
 - Small pixel size -> high resolution (3-5 μm)
 - Radiation tolerance (per year): >1 Mrad
 - High readout speed -> for high luminosity CEPC Z pole running (40MHz)

	ALPIDE	ATLAS-MAPS (MONOPIX / MALTA)	MIMOSA
Pixel size	✓	X	✓
Readout Speed	X	✓	X
TID	X (?)	✓	✓

TaichuPix readout architecture

➤ High resolution and high data rate

➤ Data-driven readout design

■ Pixel 25 μm \times 25 μm

- Continuously active front-end, in-pixel discrimination
- Fast-readout digital, with masking & testing config. logic

■ Column-drain readout for pixel matrix

- Priority based data-driven readout
- Readout time: 50 ns for each pixel

■ 2-level FIFO architecture

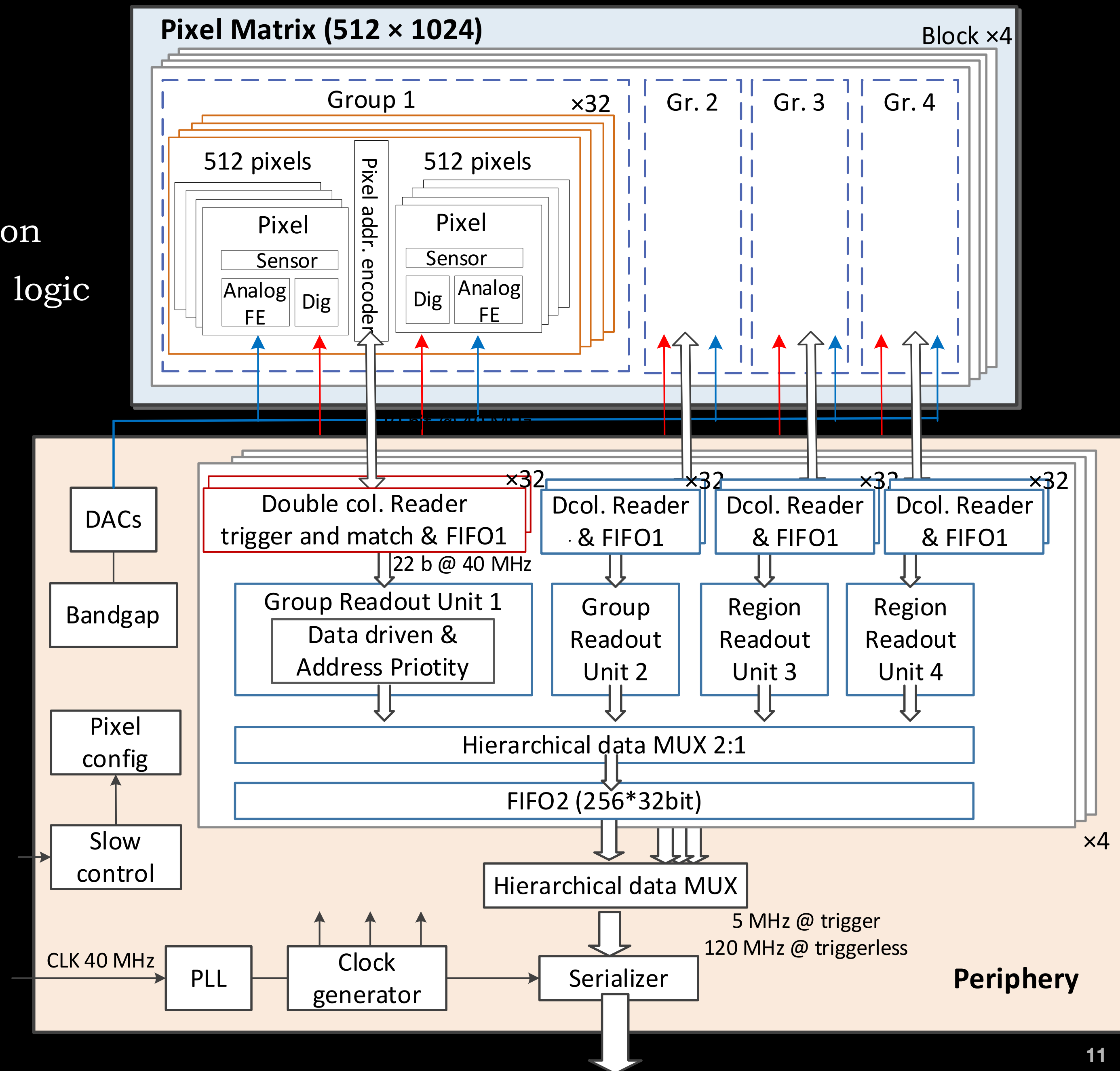
- L1 FIFO: de-randomize the injecting charge
- L2 FIFO: match the in/out data rate
- between core and interface

■ Trigger-less & Trigger mode compatible

- Trigger-less: 3.84 Gbps data interface
- Trigger: data coincidence by time stamp
only matched event will be readout

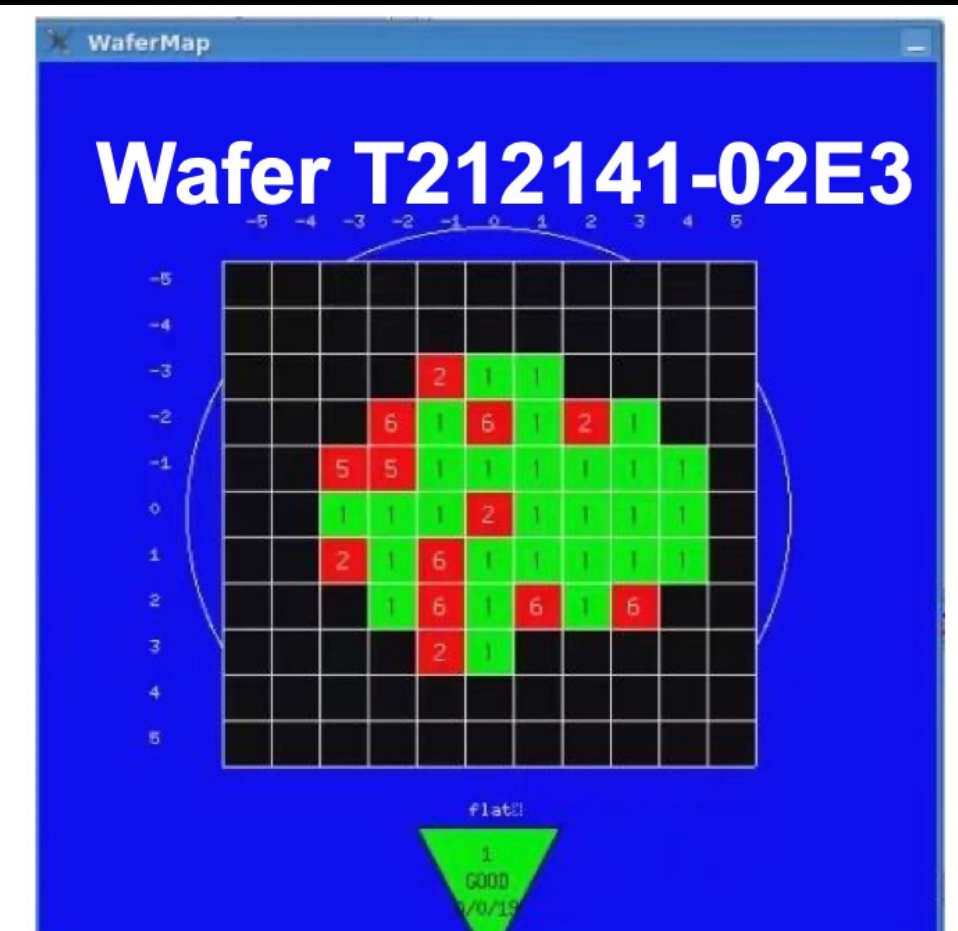
■ Features standalone operation

- On-chip bias generation, LDO, slow control, etc.

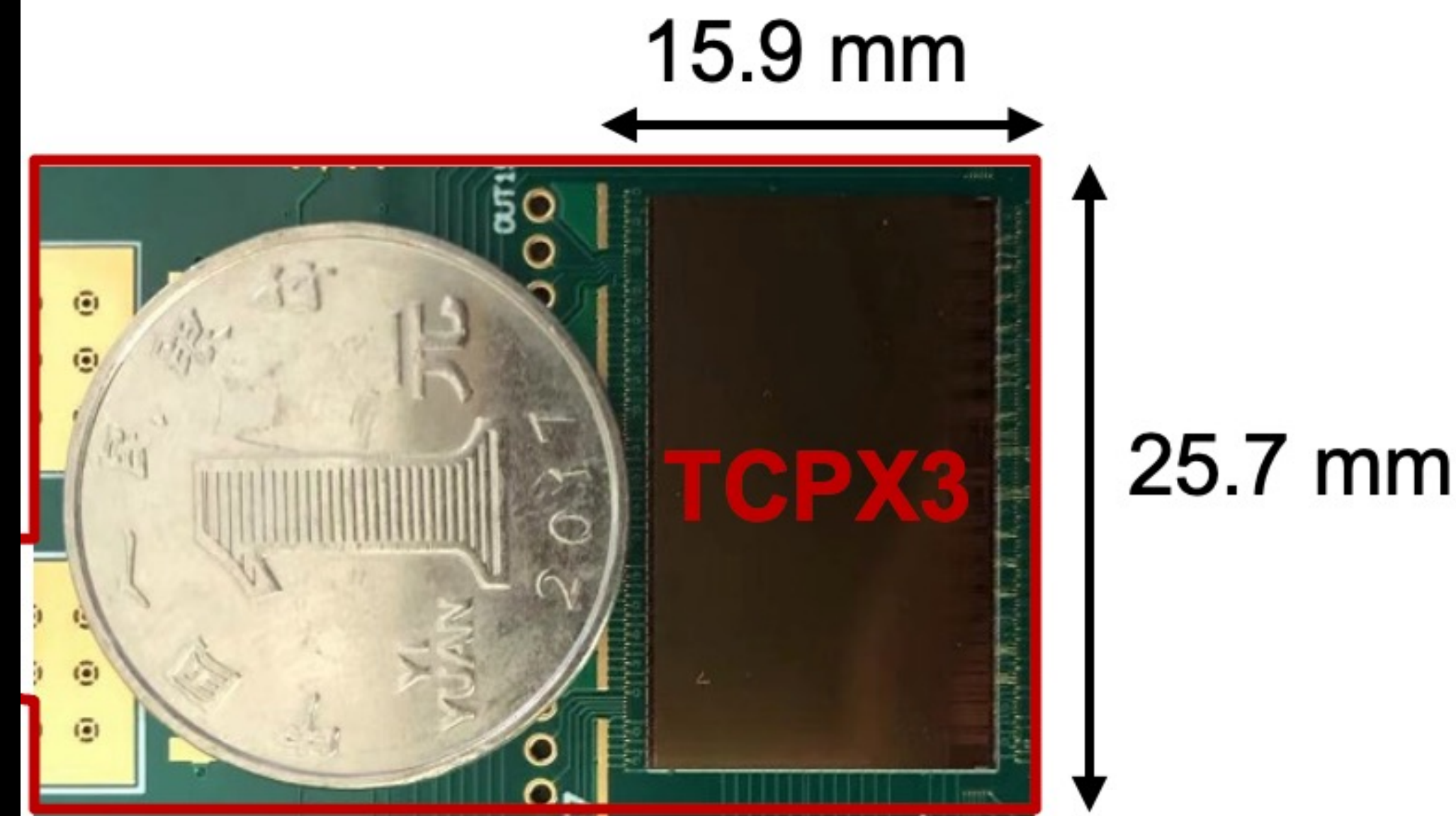
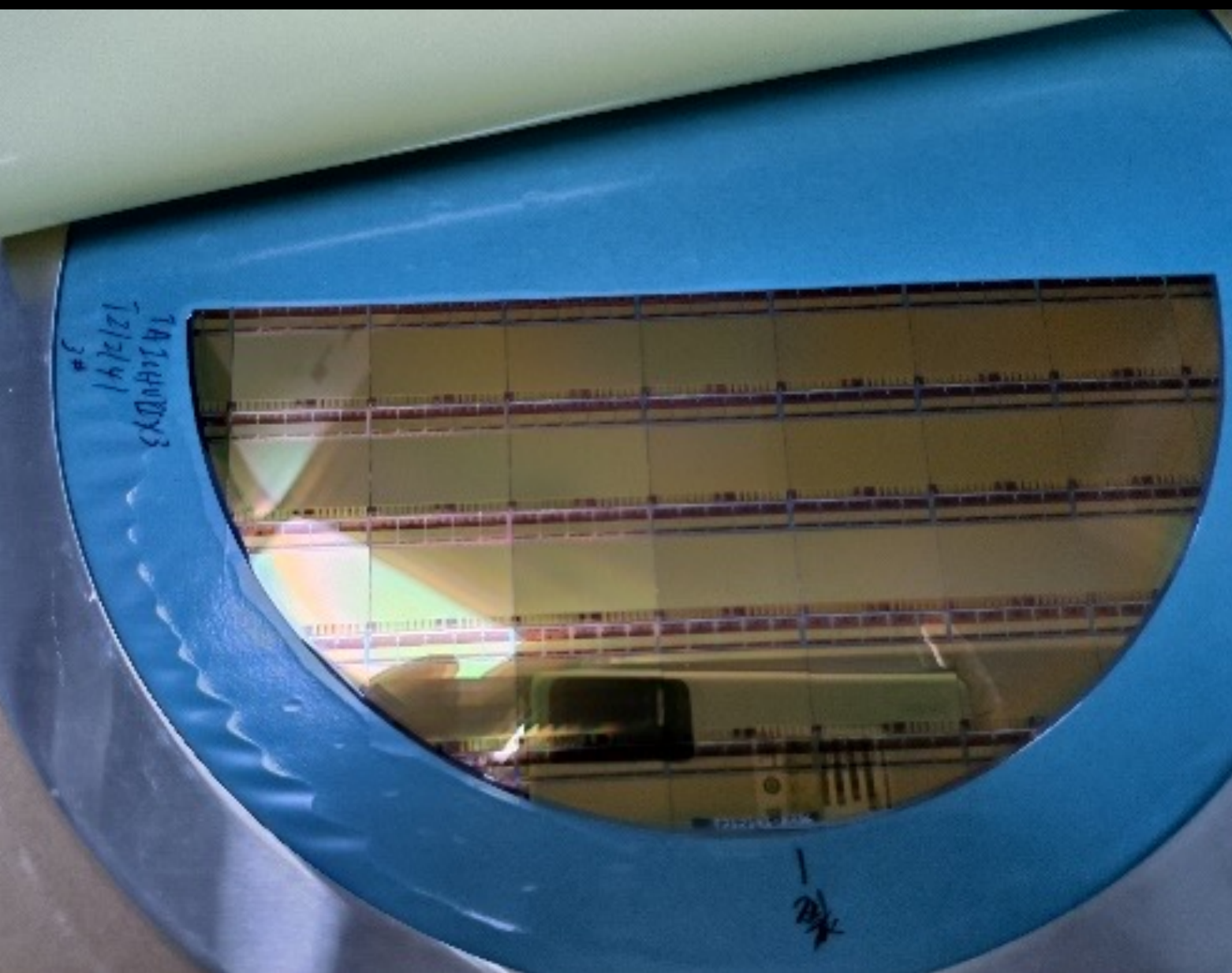


Full-size TaichuPix3 prototyping (engineering run)

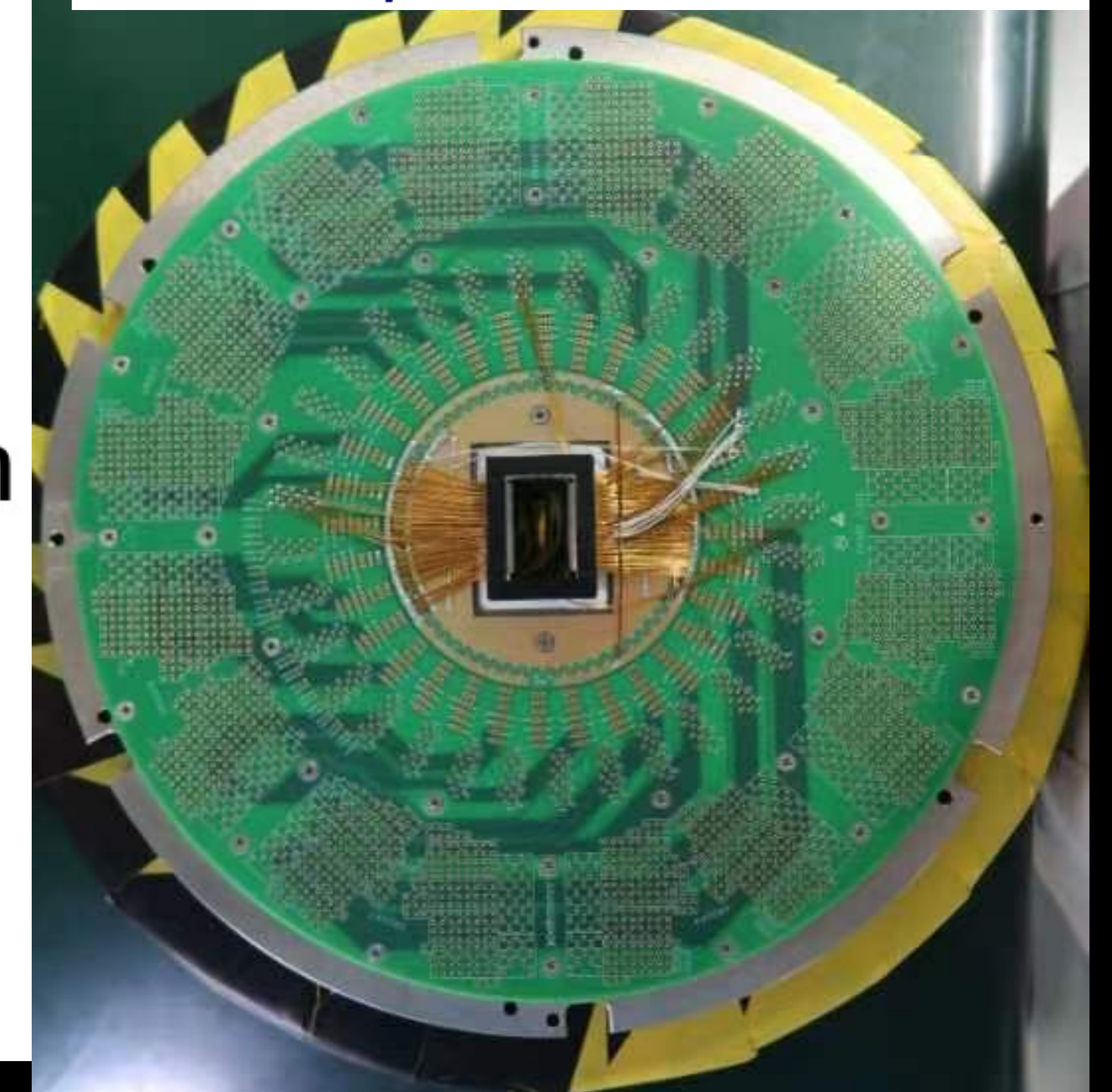
- Developed the first full-size CMOS pixel sensor for particle detector in China
 - Full size **1024×512** Pixel array, Chip Size: **15.9×25.7mm**
 - **25μm×25μm** pixel size → high spatial resolution
 - Process: **Towerjazz 180nm CIS process**
 - Fast Periphery digital readout , high-speed data interface



An example of wafer test result

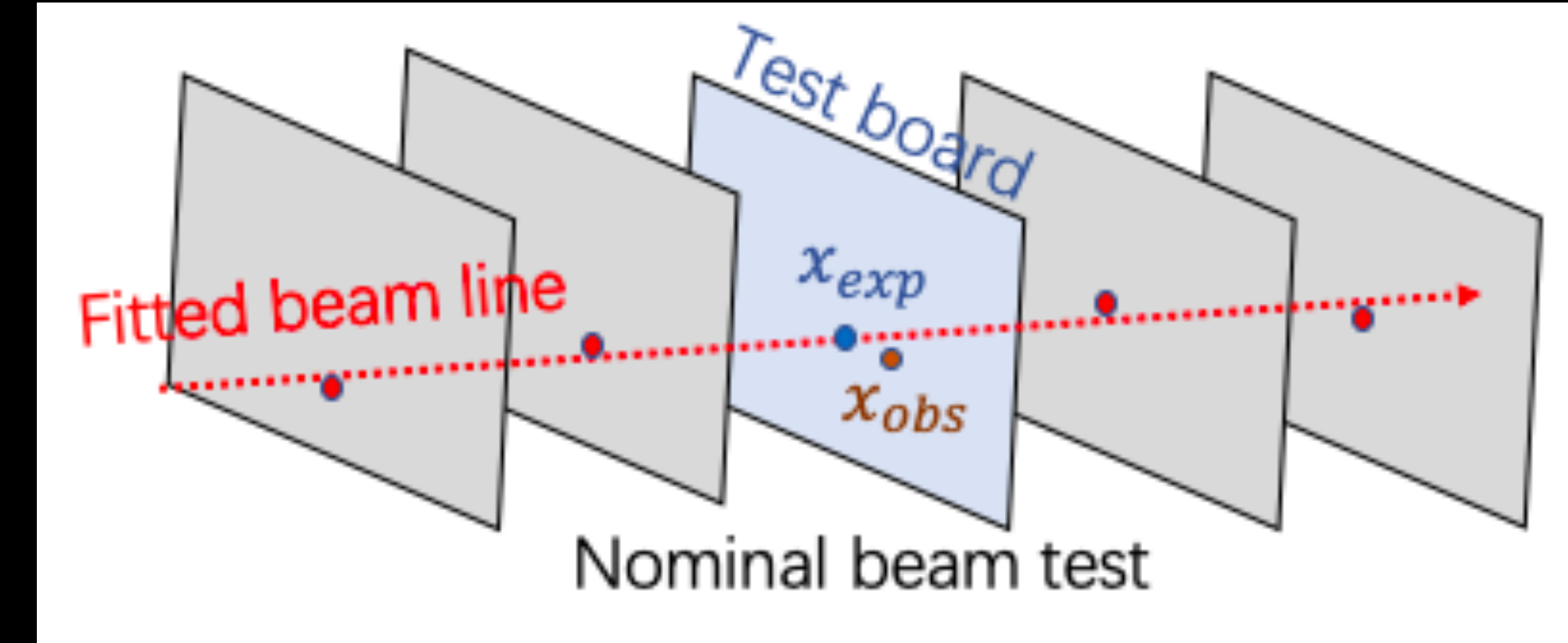


TaichuPix-3 chip vs. coin

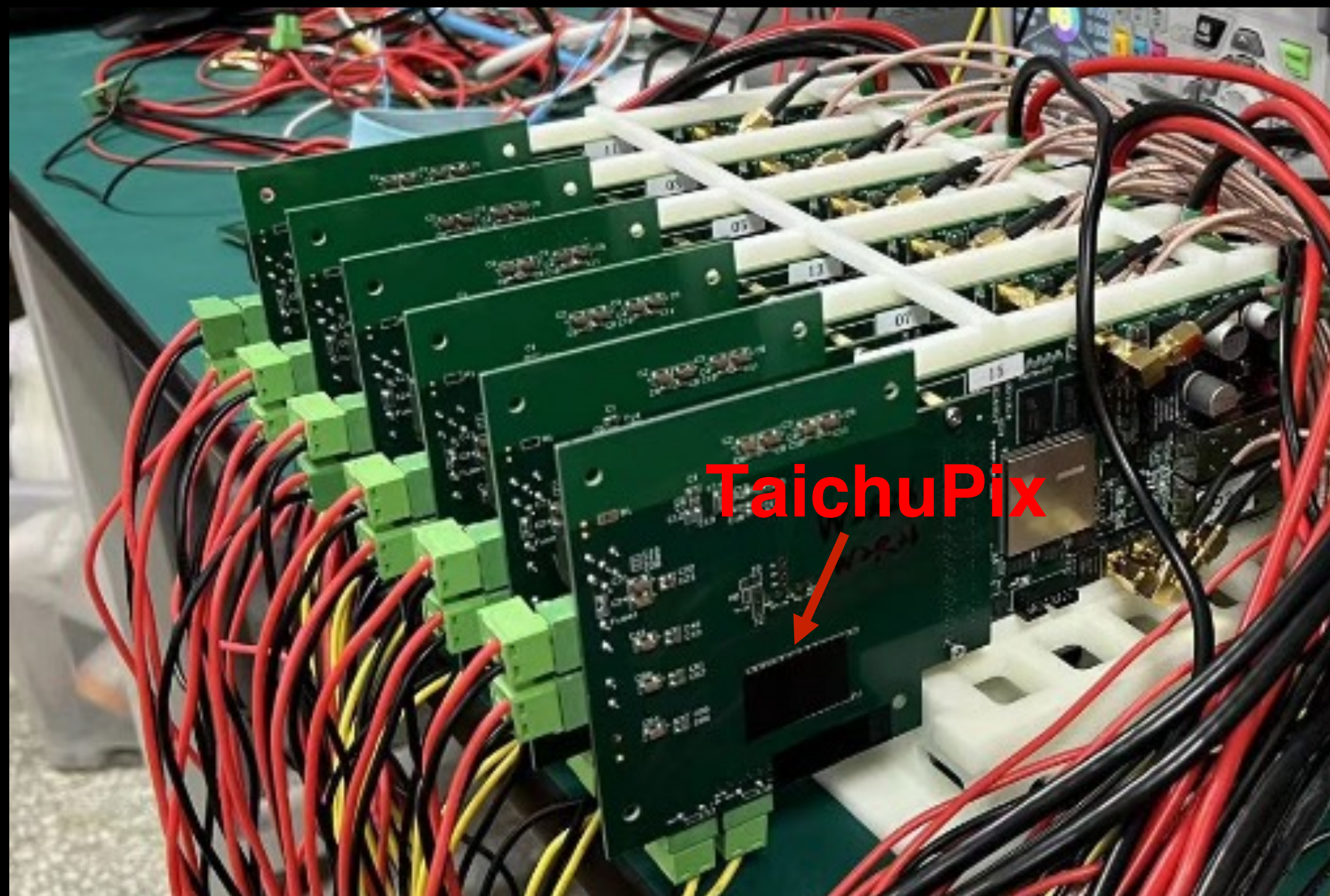


Spatial resolution measured by testbeam

- The 6-layer of TaichuPix-3 telescope built
 - Tested at DESY with 4-5 GeV electron beam, 1kHz rate
 - One layer of TaichuPix used as Detector-Under-Test (DUT)
 - Other five layers as beam telescope used for track fitting
 - Spatial resolution of TaichuPix reach $4.78\ \mu\text{m}$
 - Reach the goal of the project (3-5 μm)

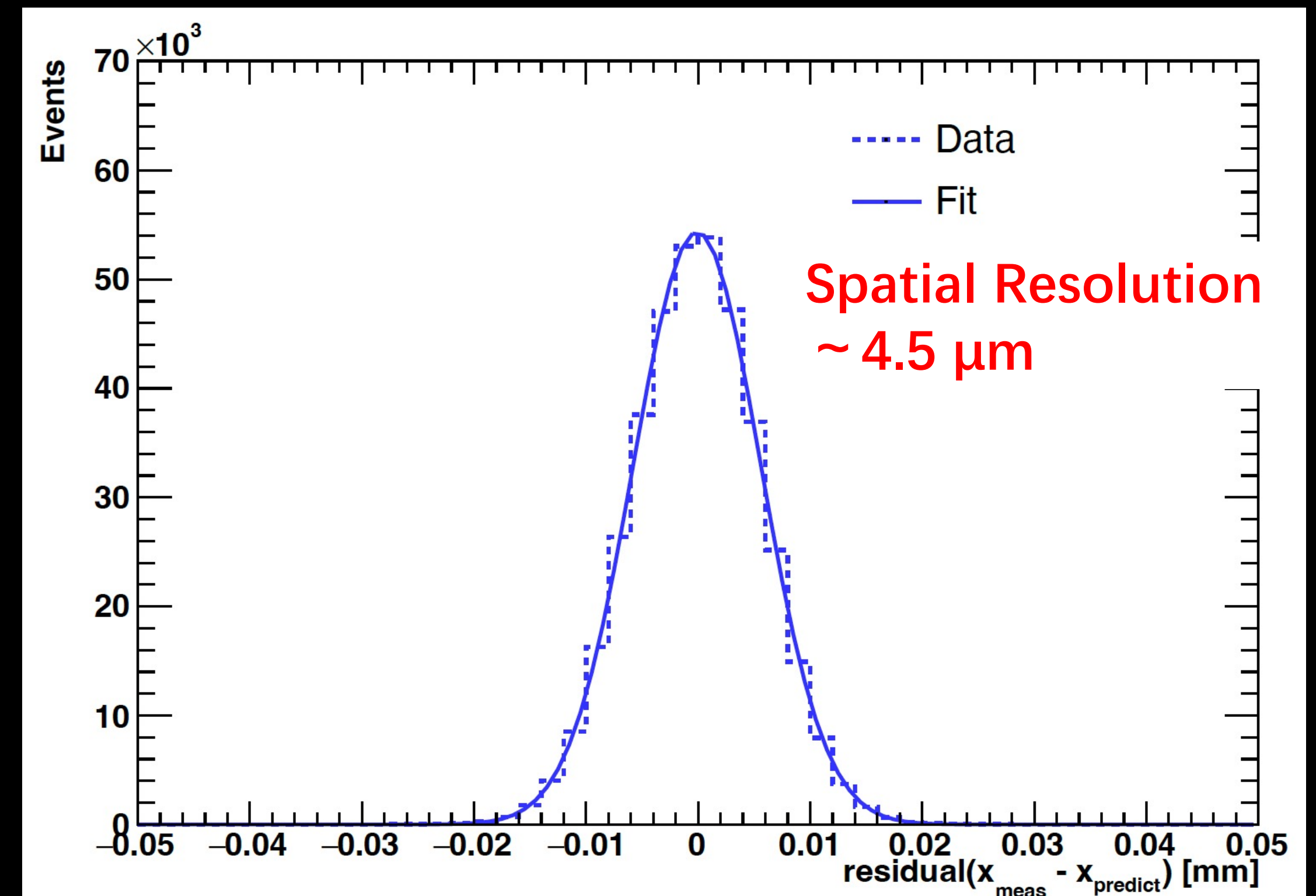


Setup for Taichupix beam telescope



Residual distribution

DUT measured position – expected position from track



Spatial resolution measured by testbeam : alignment

- The measured hits position misaligned due to non-ideal installation precision
- Method: Millepede matrix method

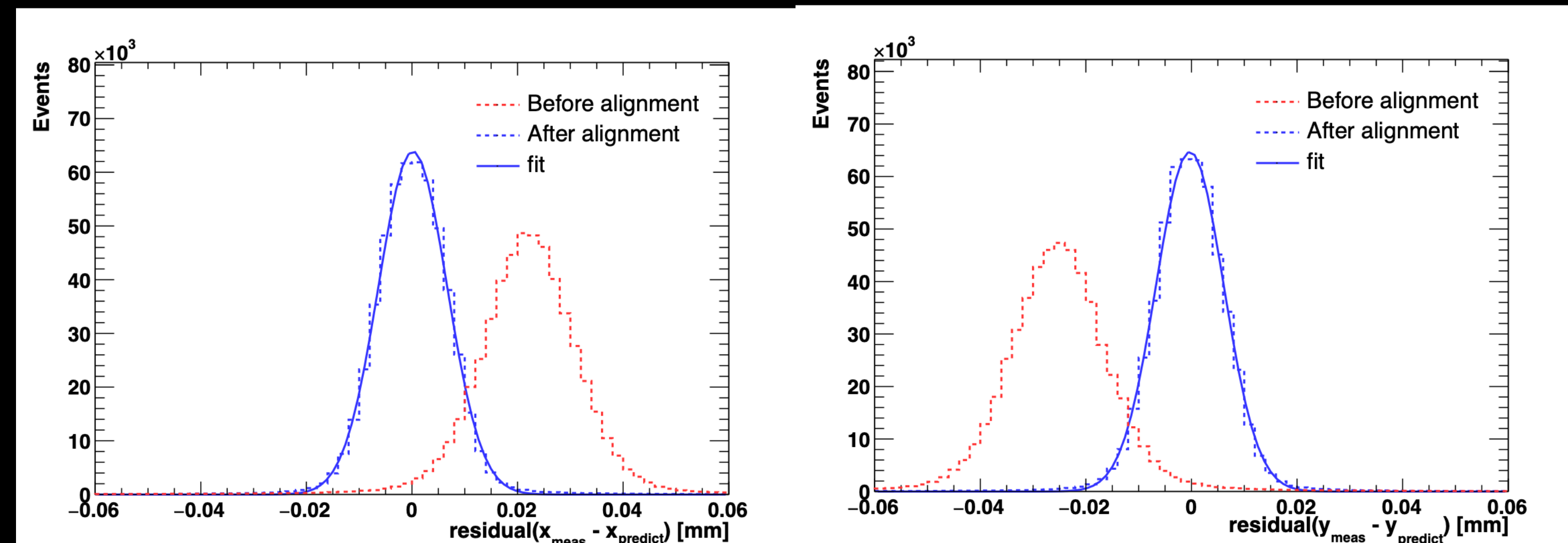
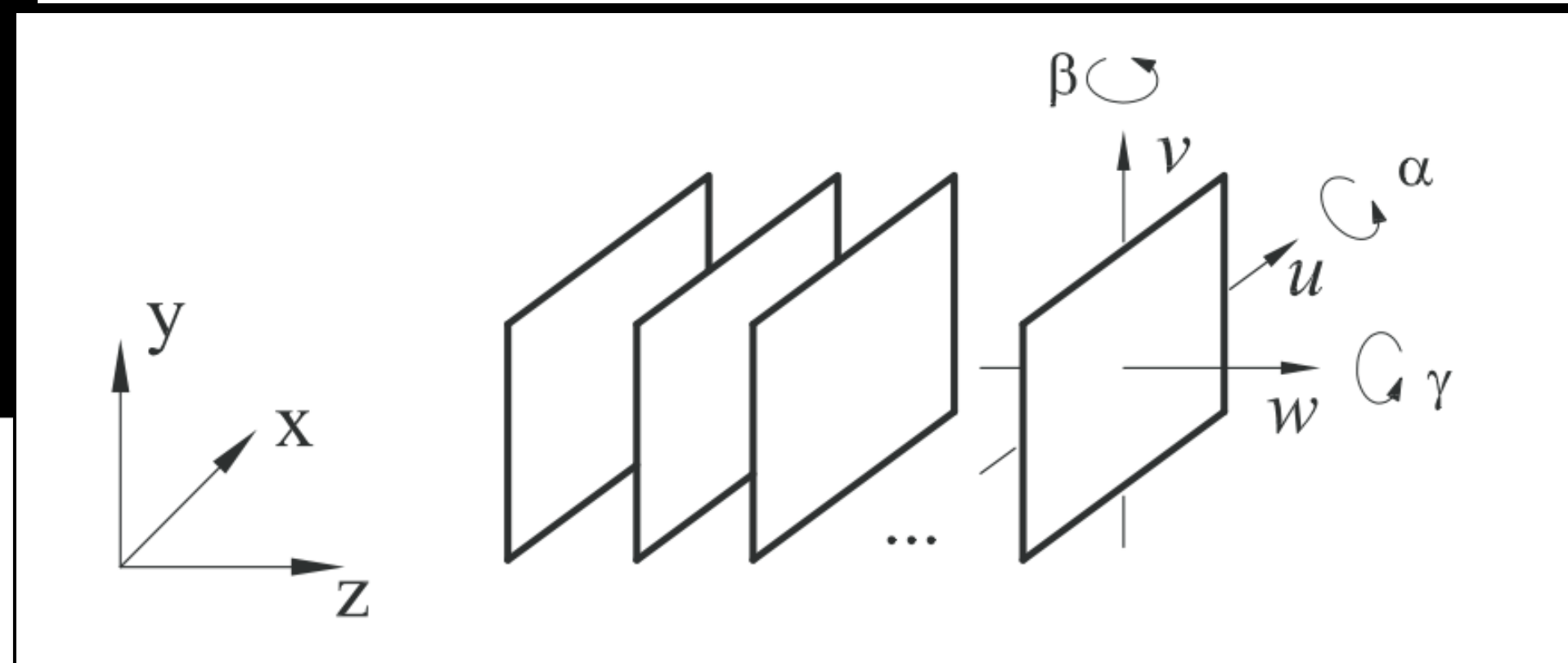
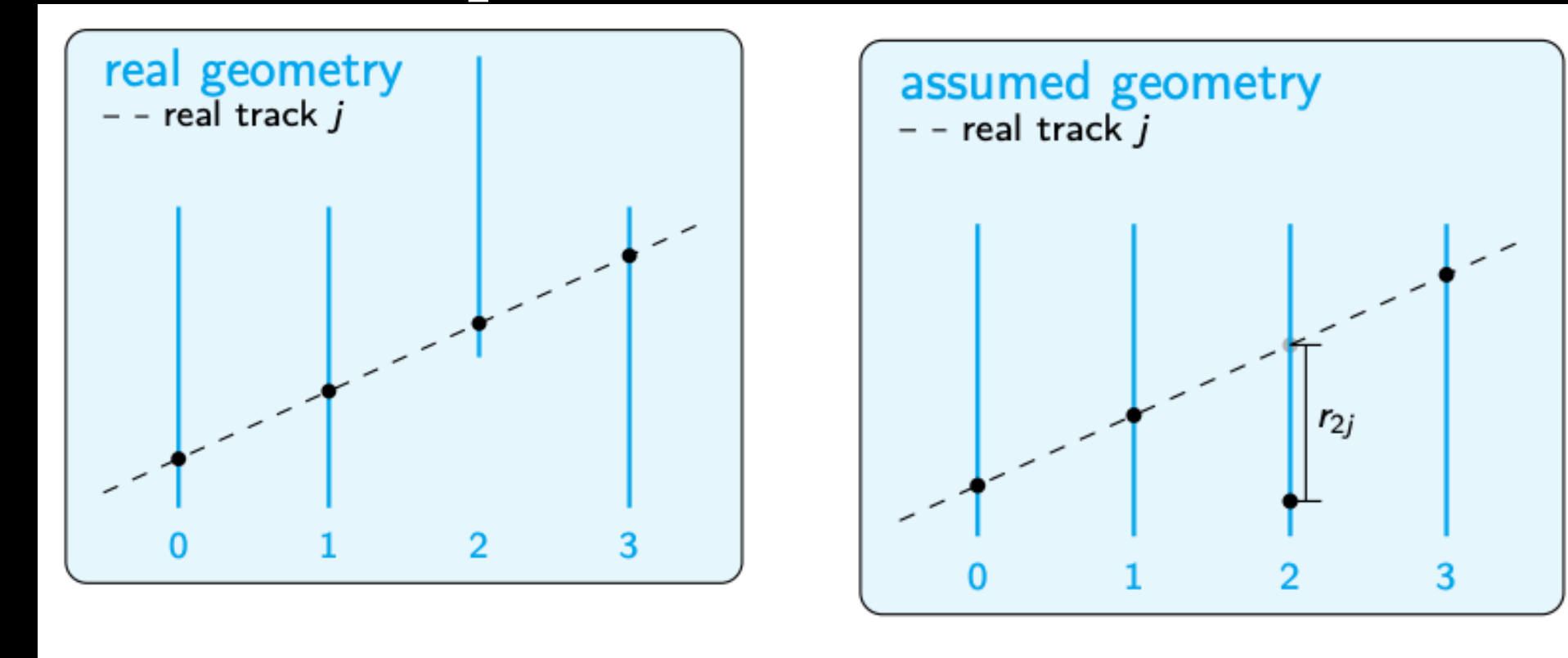
$$\chi^2 = \sum_{j \in \text{tracks}} \sum_{i \in \text{hits}} \vec{r}_{ij}^T(g, l_j) V_{ij}^{-1} \vec{r}_{ij}(g, l_j)$$

Six alignment parameters used for each chip position

Translation along X, Y, Z direction

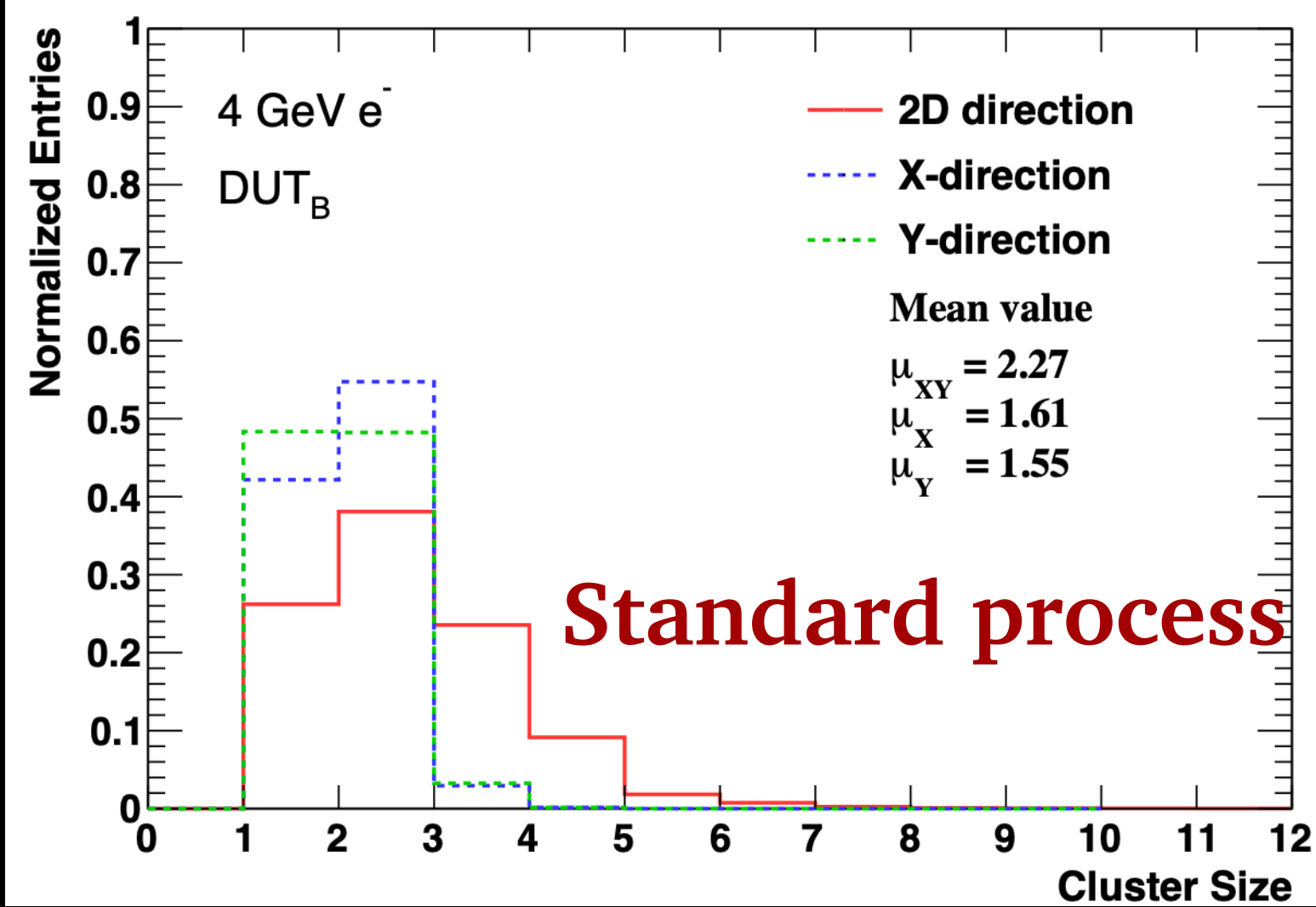
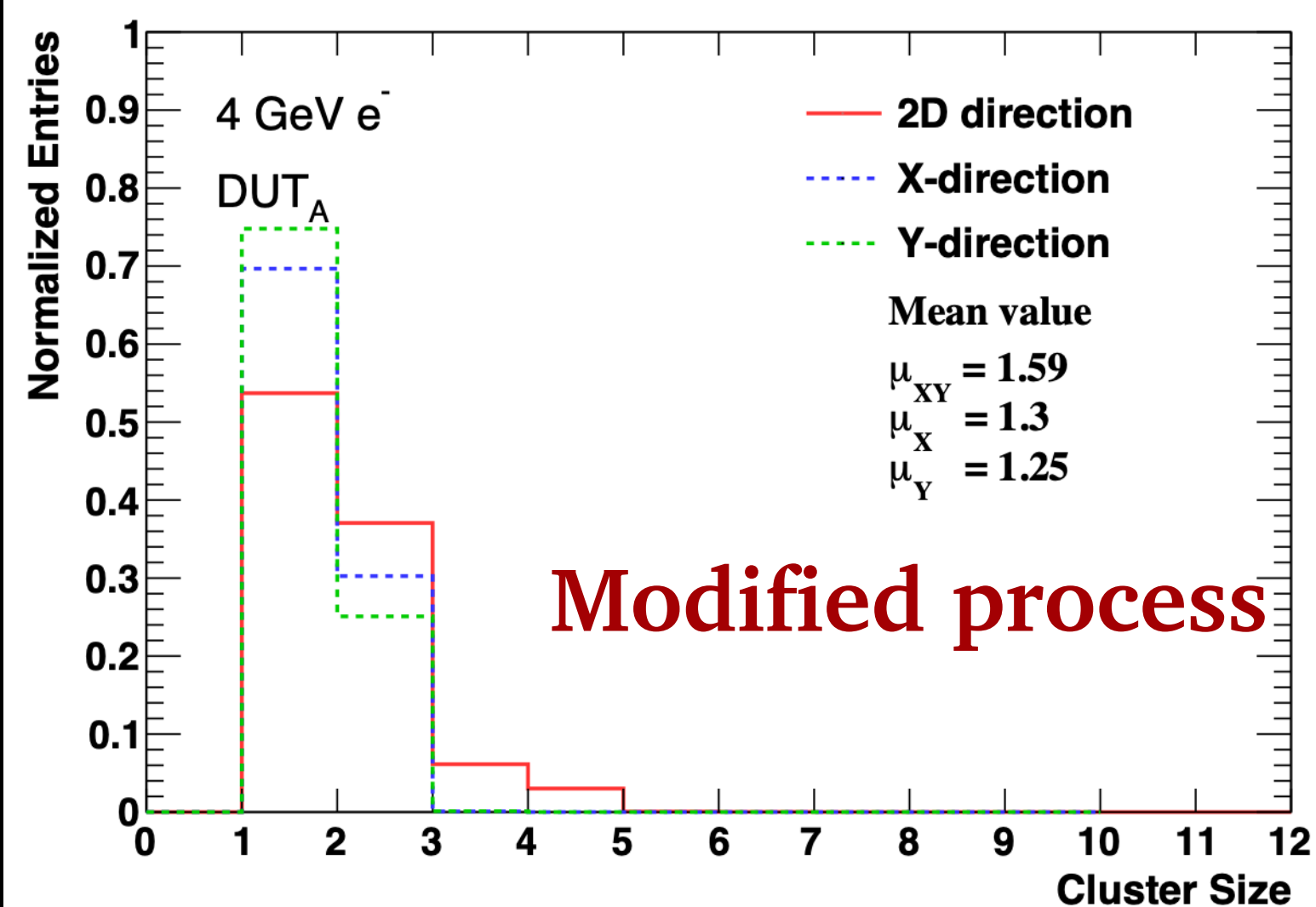
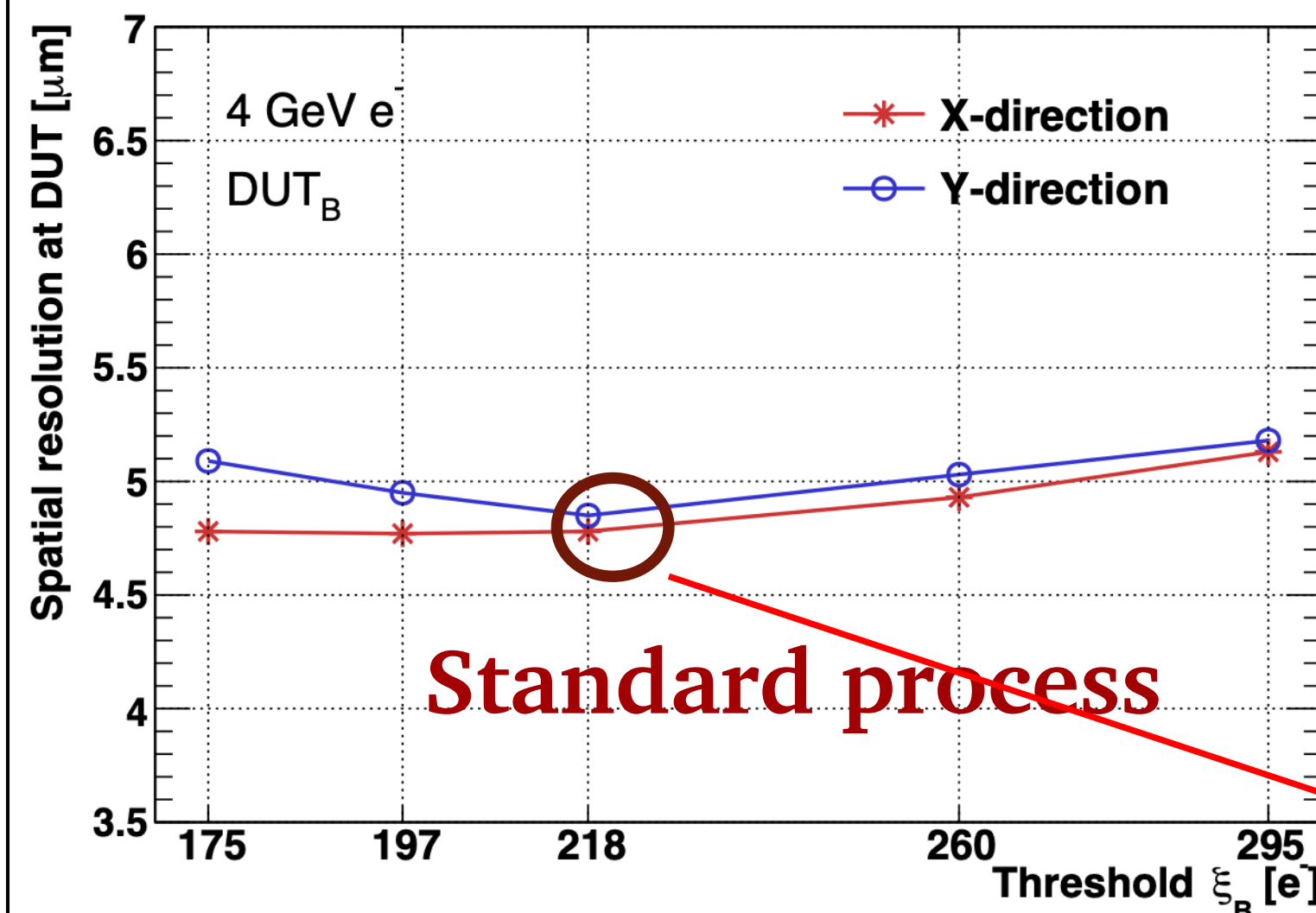
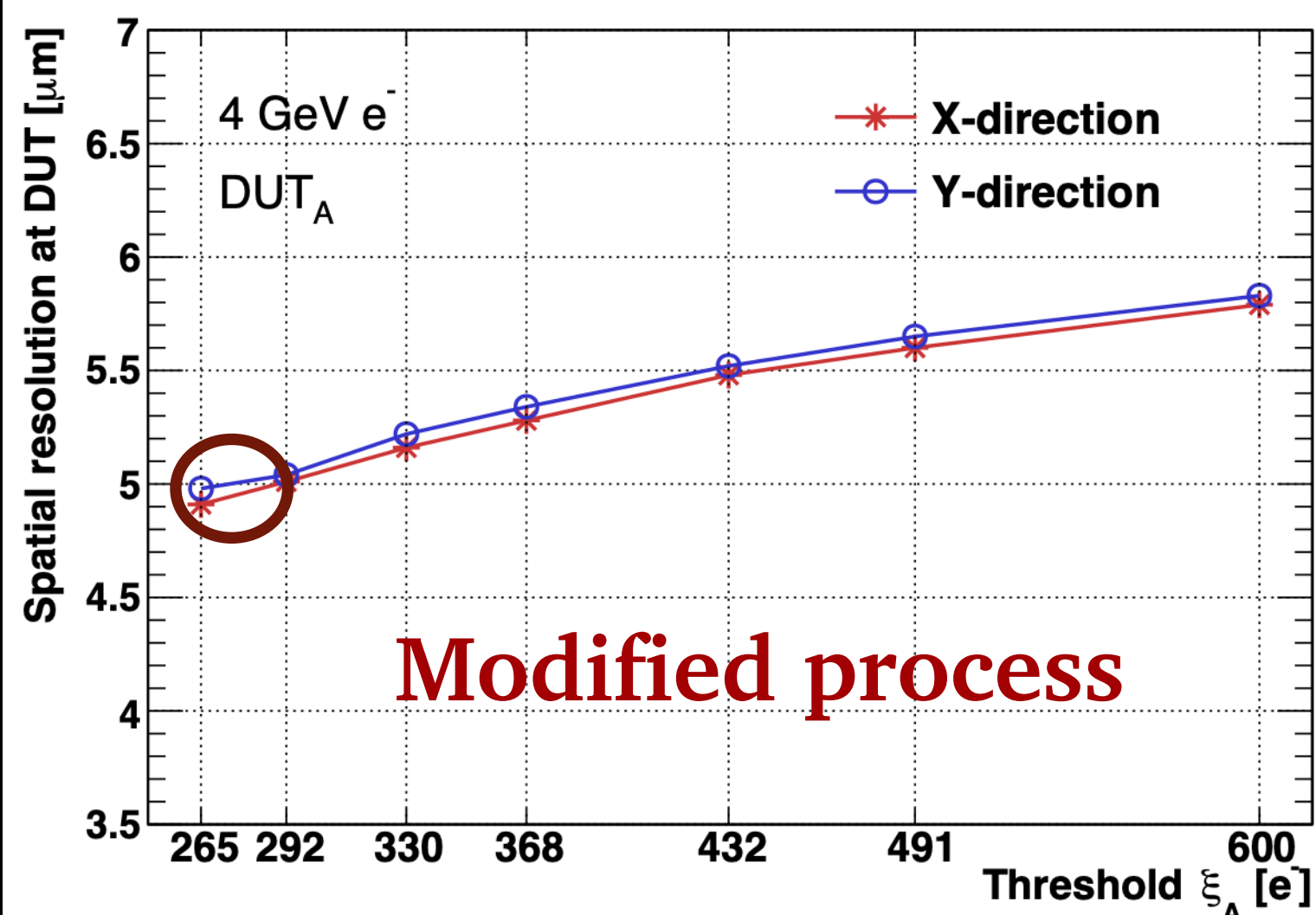
Rotation around X, Y, Z axis

Impact of the alignment on residual distribution

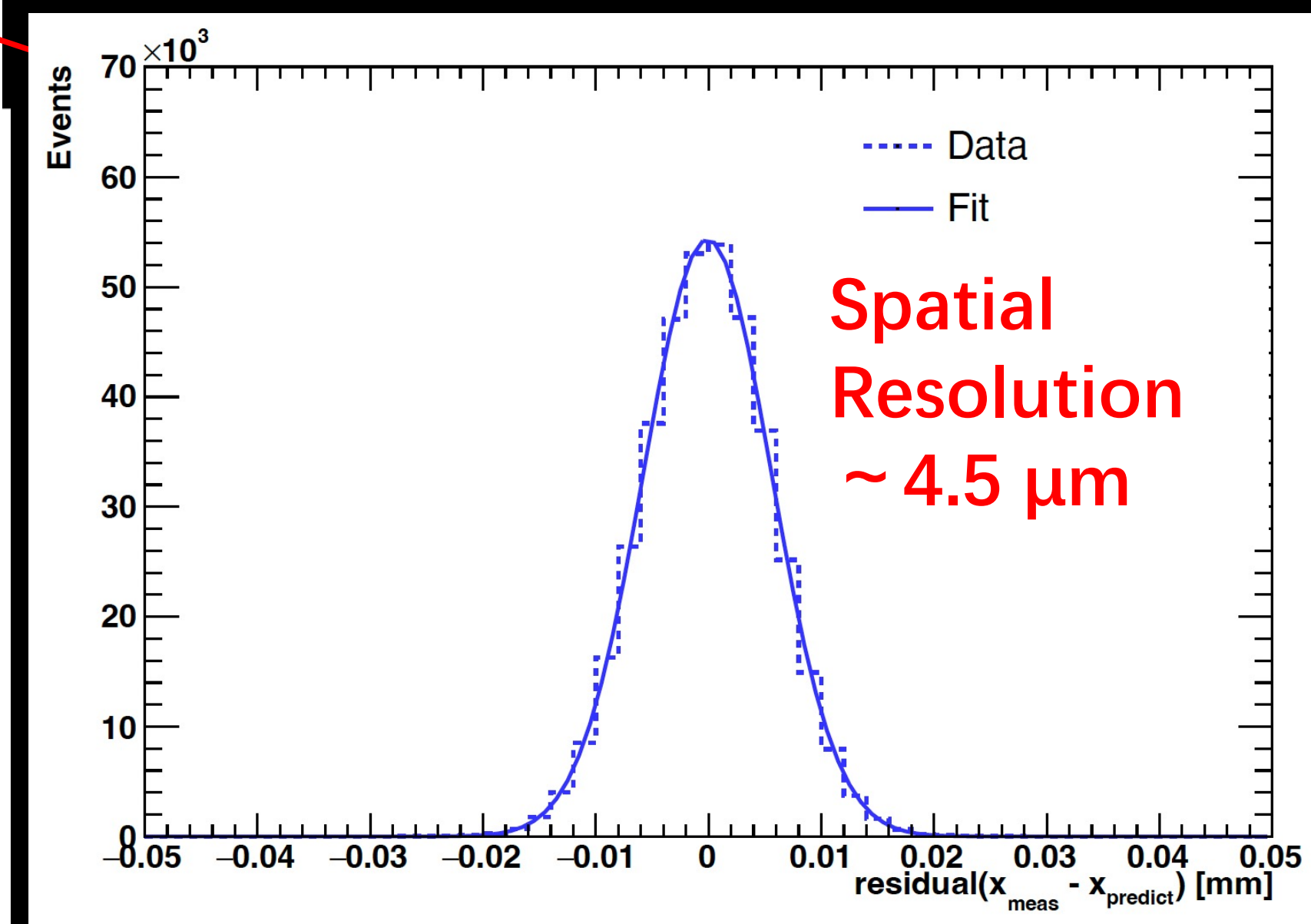


Spatial resolution and cluster size VS threshold

- The spatial resolution extracted by the unbiased residual distribution after subtracting the track uncertainty → **The spatial resolution less than 5 μm**



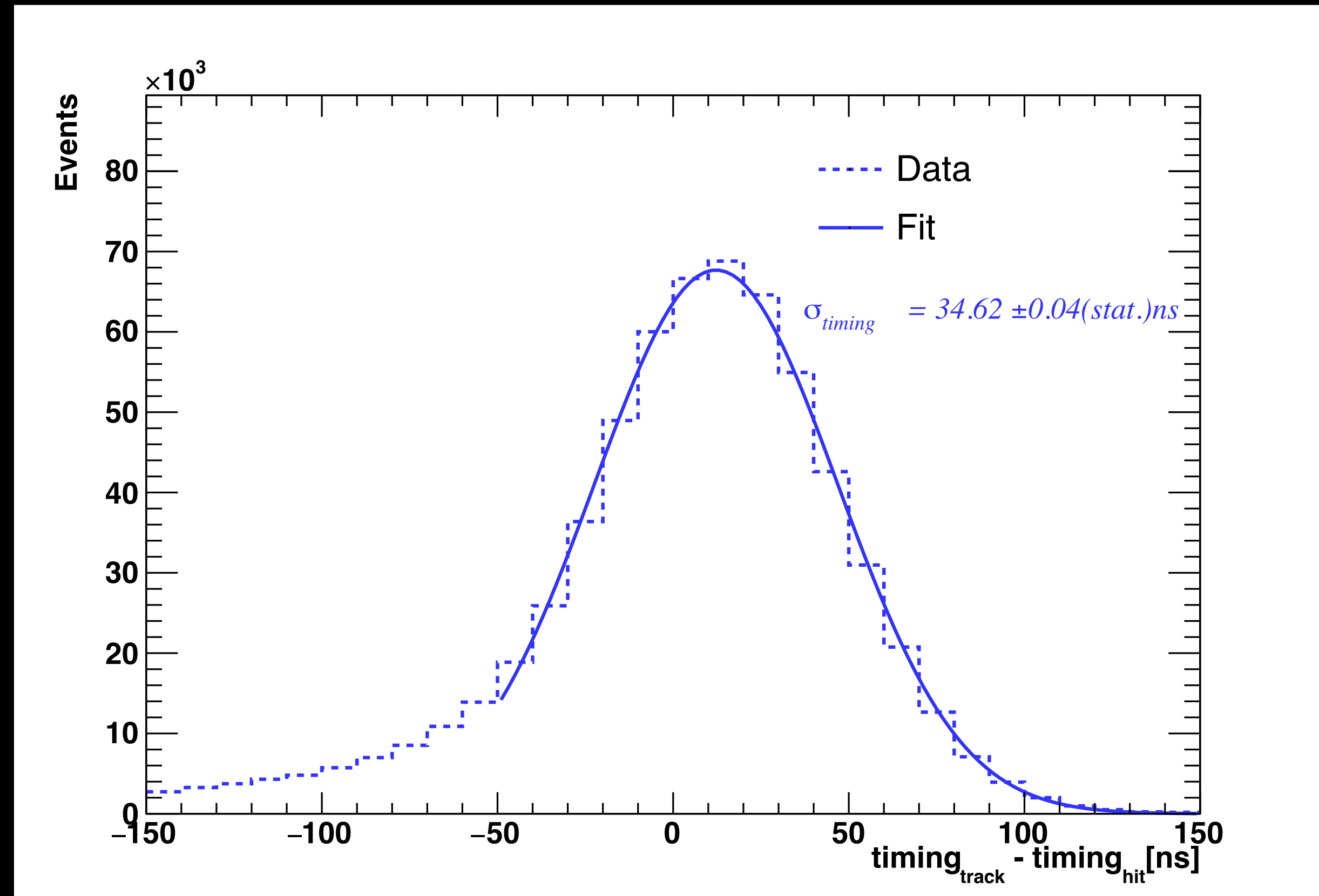
- Less charge sharing effects in modified process with full depletion
- If lowering the threshold, cluster size will be dominated by noise



Time resolution of Taichupix (Preliminary result)

- CEPC tracker resolution requirement: **25ns @40MHz Z pole collision**
- Taichupix telescope have two time stamp:
 - Time stamp from FPGA (all 6 Taichu chip synchronized by FPGA)
 - Precise time stamp from Taichu chip
- Time resolution is $\sim 35\text{ns}$ @20MHz clock
 - By comparing telescope track time Vs DUT time

Track time - DUT time

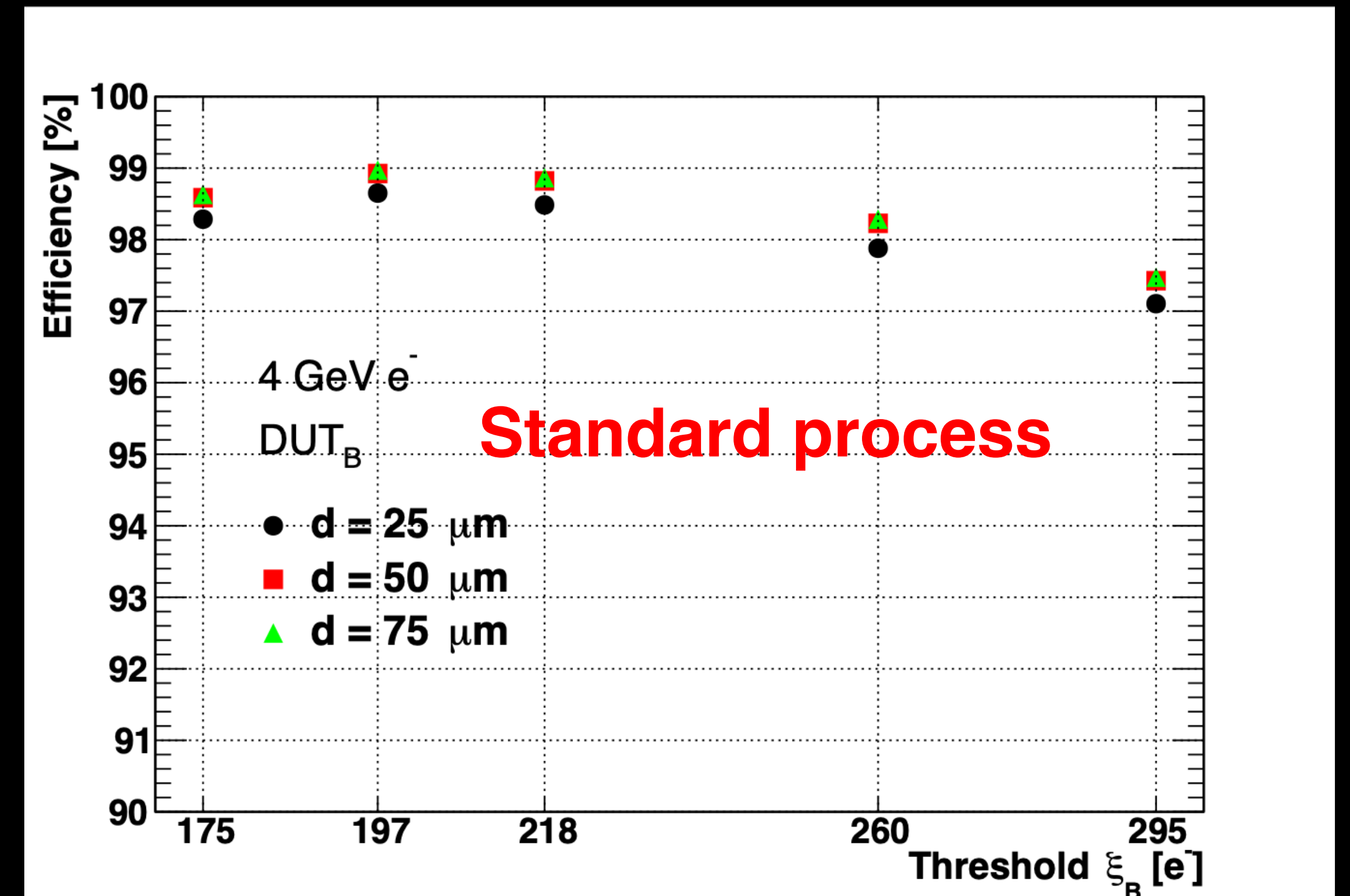
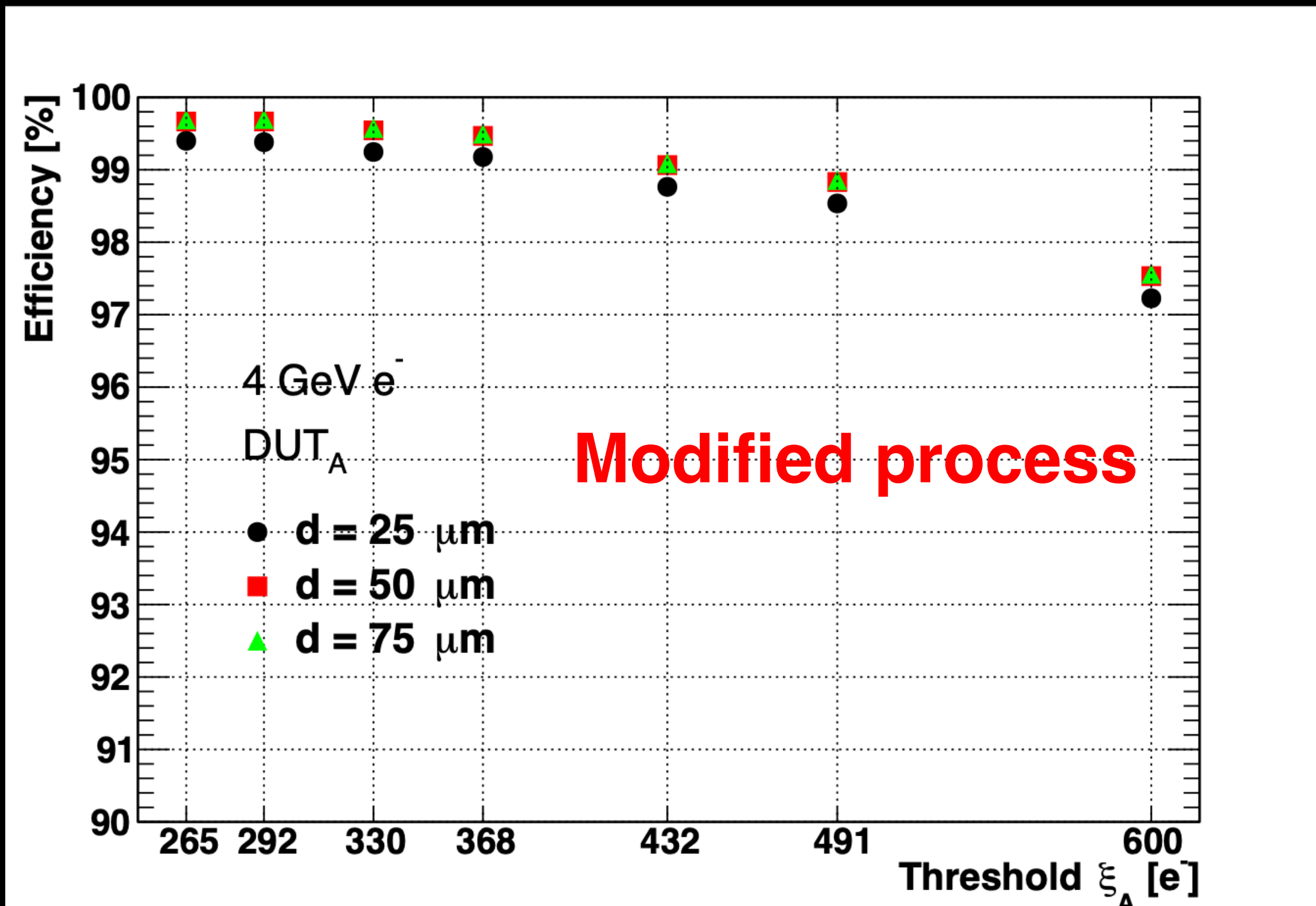


Efficiency Vs threshold

- Efficiency is the ratio of tracks that match the hit on the DUT within a distance around the predicted hit from the telescope to all tracks of the telescope
- It can reach about 99% efficiency in optimized threshold

$$\epsilon = \frac{N_{\text{matched Tracks}}}{N_{\text{tel}}^{\text{Tracks}}}$$

$|x_{\text{meas}}, y_{\text{meas}} - x_{\text{pre}}, y_{\text{pre}}| < d$



Detector module (ladder) R & D

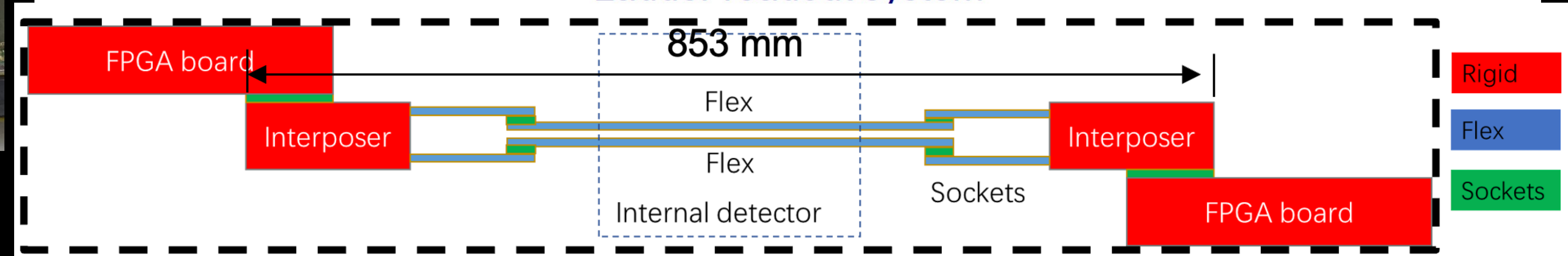
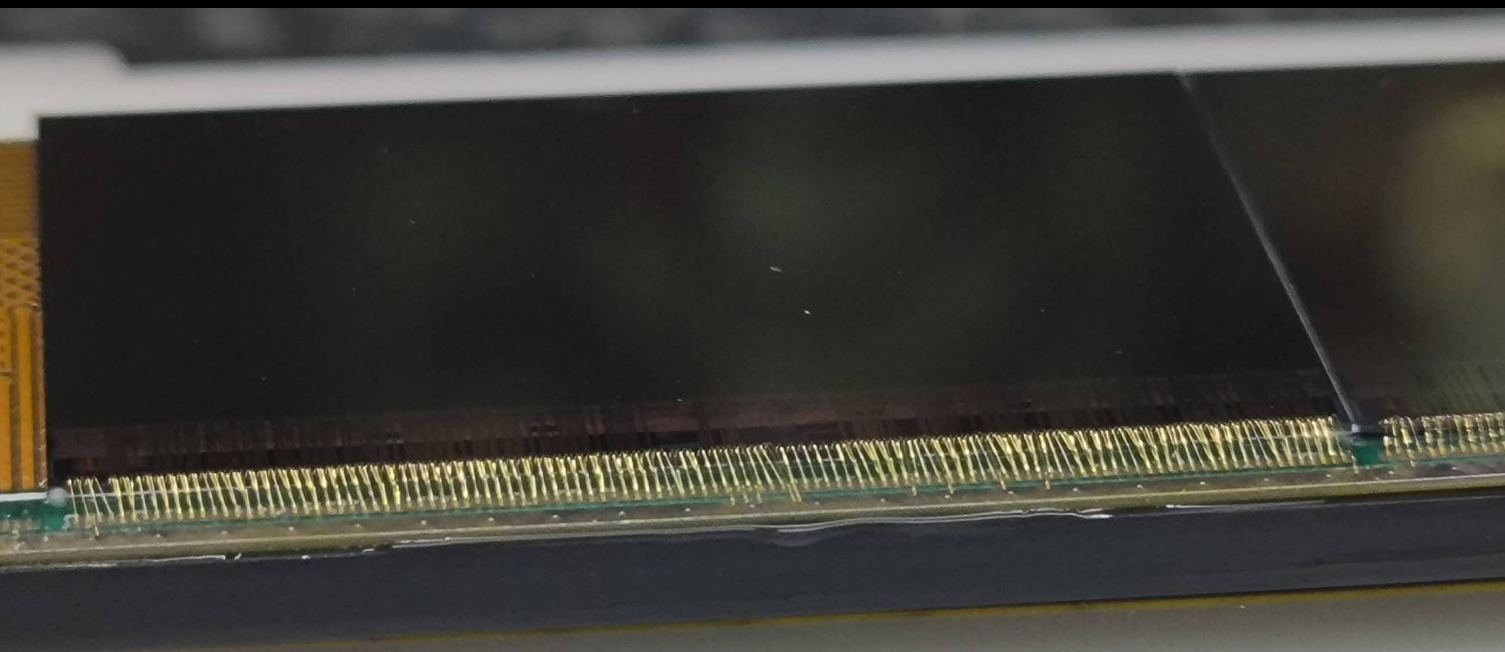
- Completed detector module (ladder) design

- Detector module (ladder) = 10 sensors + readout board + support structure + control board
- Sensors are glued and wire bonded to the flexible PCB, supported by carbon fiber support
- Signal, clock, control, power, ground will be handled by control board through flexible PCB

- Challenges

- Long flex cable → hard to assemble & some issue with power distribution and delay
- Limited space for power and ground placement → bad isolation between signals

Taichupix chip wire bonded on FlexPCB

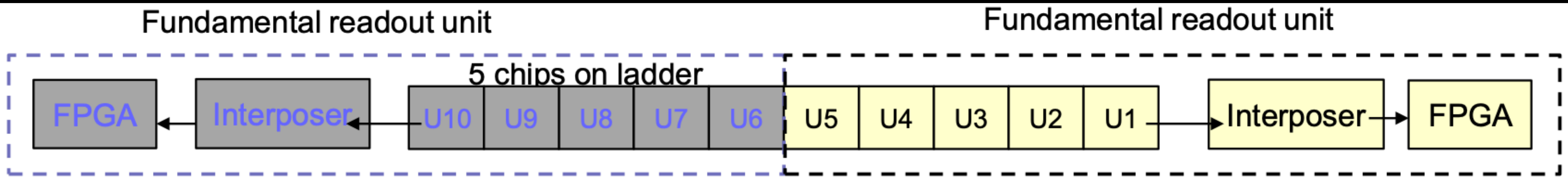


- Solutions

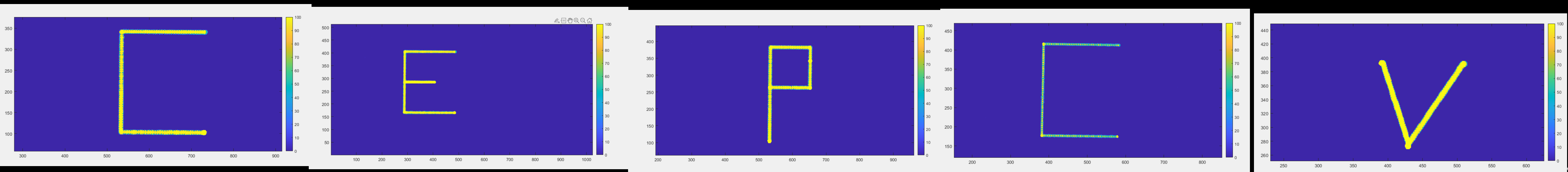
- Readout from both ends, readout compose of three parts, careful design on power placement

Laser test result of ladder

- A full ladder includes two identical fundamental readout units
 - Each contains 5 TaichuPix chips, a interposer board, a FPGA readout board
- Functionality of a full ladder fundamental readout unit was verified
 - Scanning a laser spot on the different chips with a step of 50 μm ,
 - Clear and correct letter imaging observed
 - Demonstrating 5 chips working together → one ladder readout unit working



Laser tests on Taichupix chip on full ladder
("CEPCV" pattern by scanning laser on different chips on ladder)



Double-side ladder in CECF vertex detector

- Ladder in vertex detector is double-sided
 - Two flexible PCB + one carbon fiber support
- Both side has wire-bonding → Challenging
- Dedicated tooling for double-side assembly

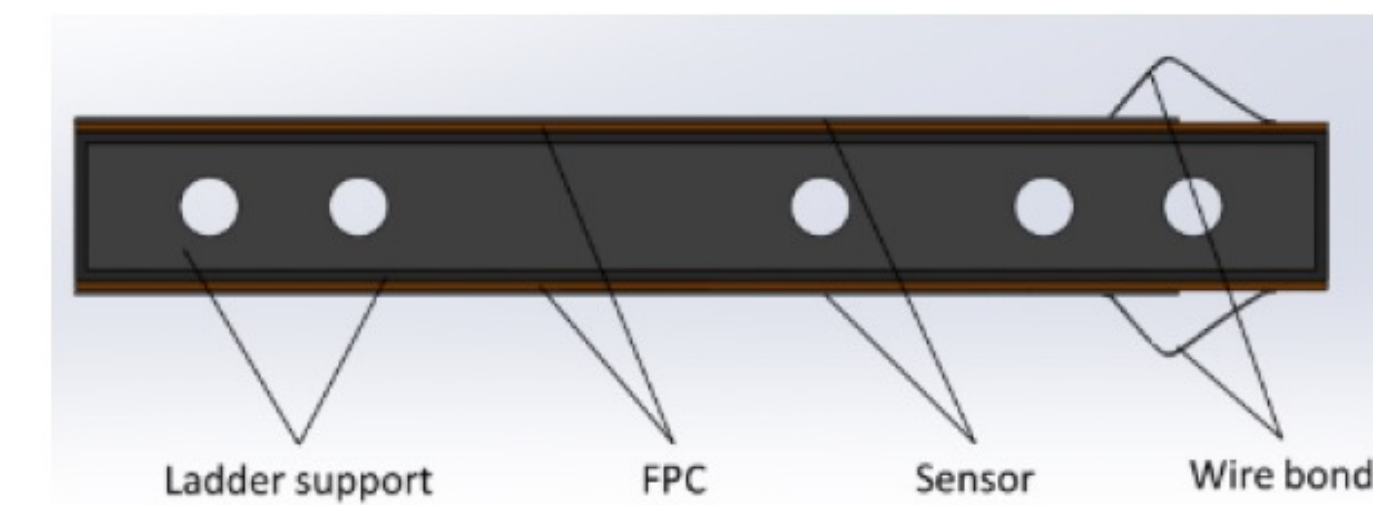
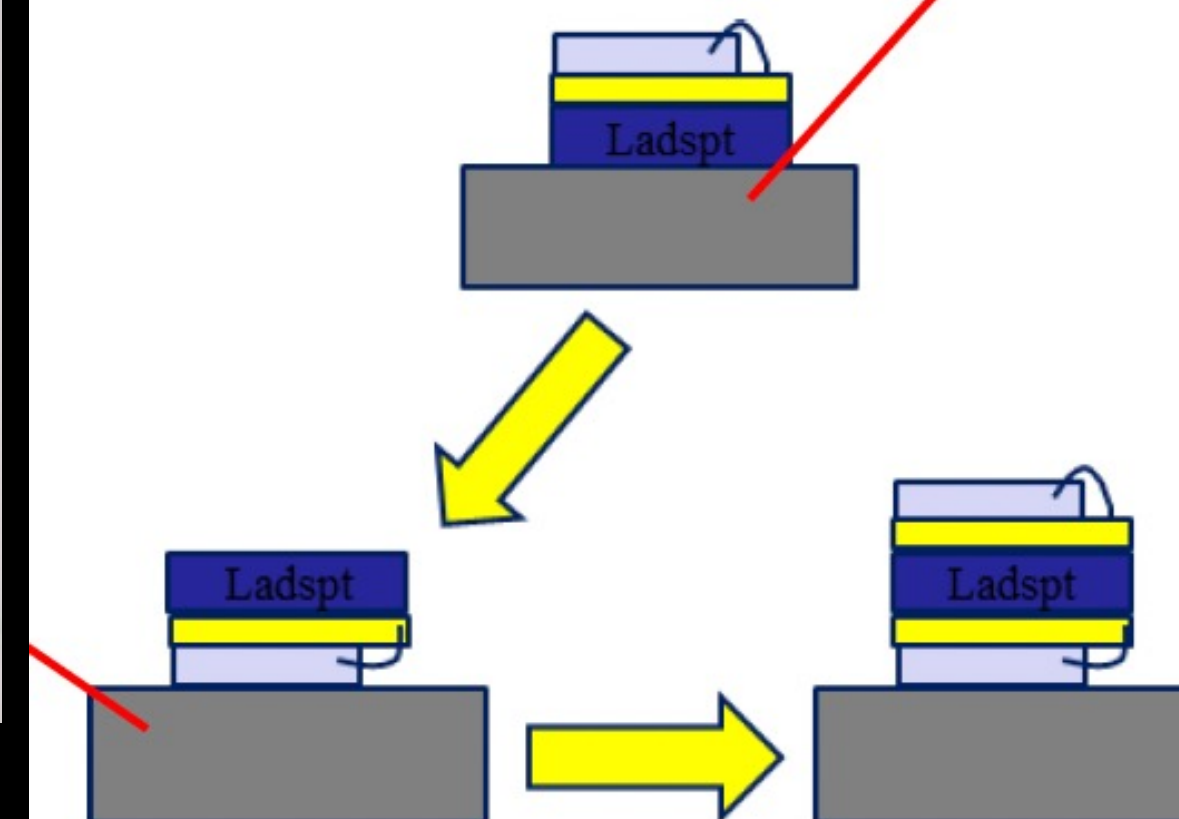
**Designed and fabricate
carbon fiber support**



Module fixation and protection components



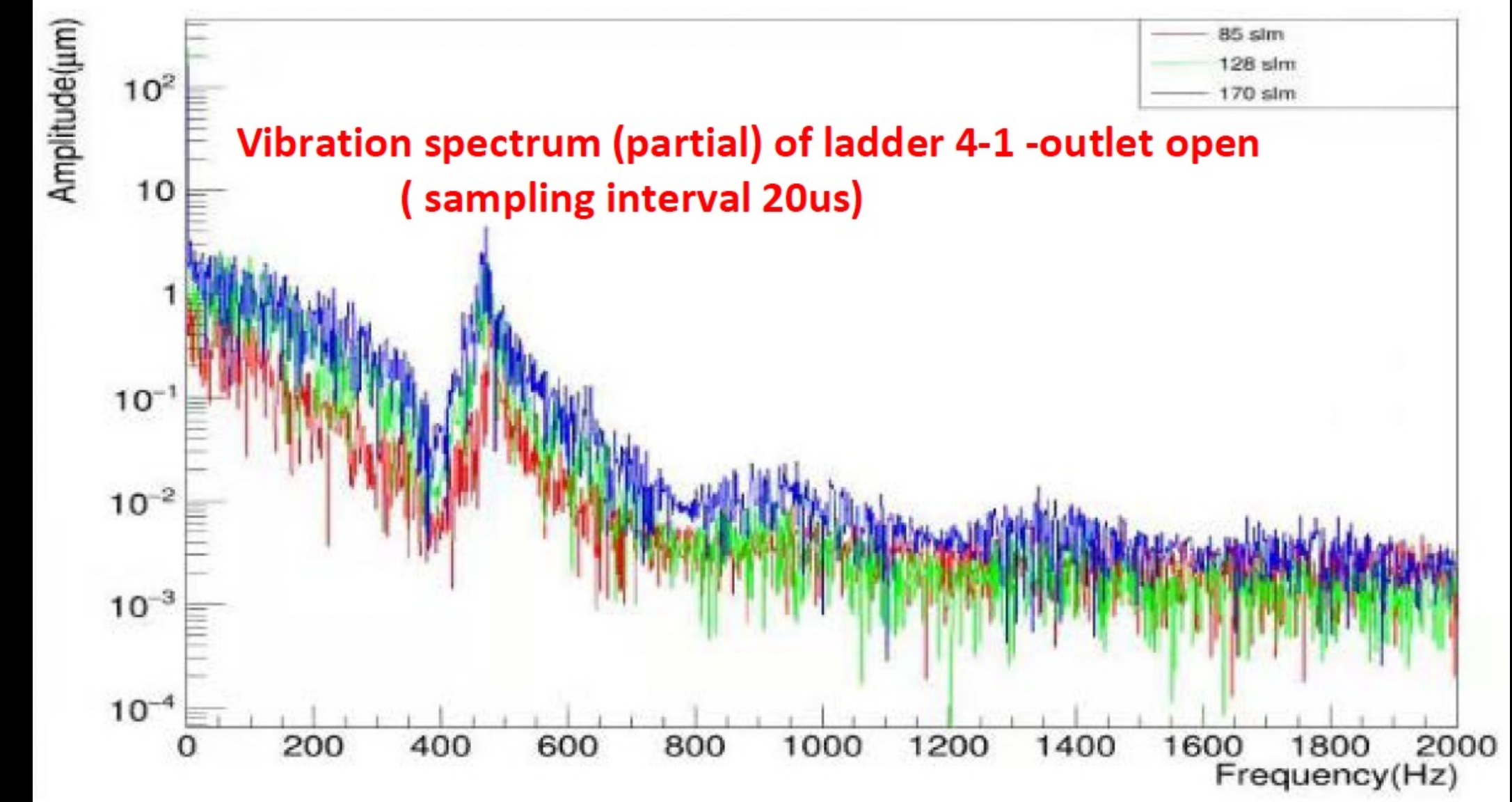
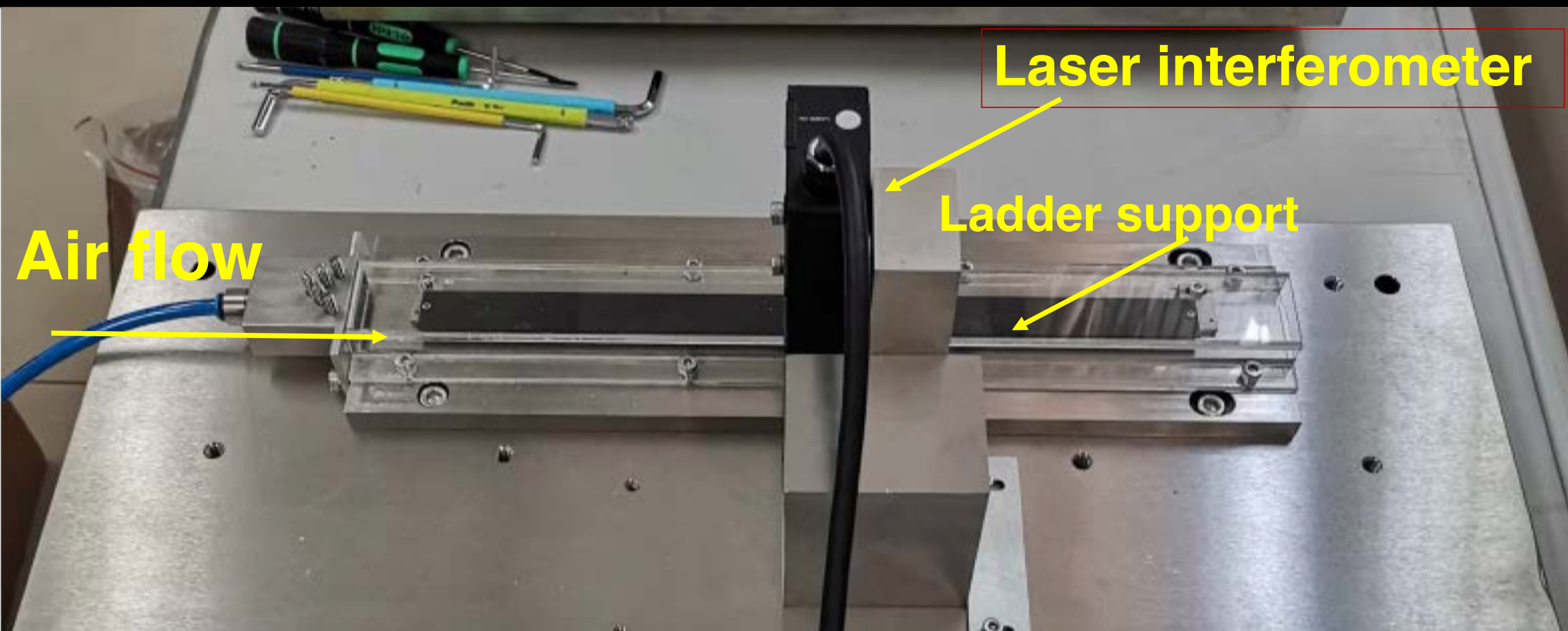
Vacuum plate for flex and CFRP support fixation



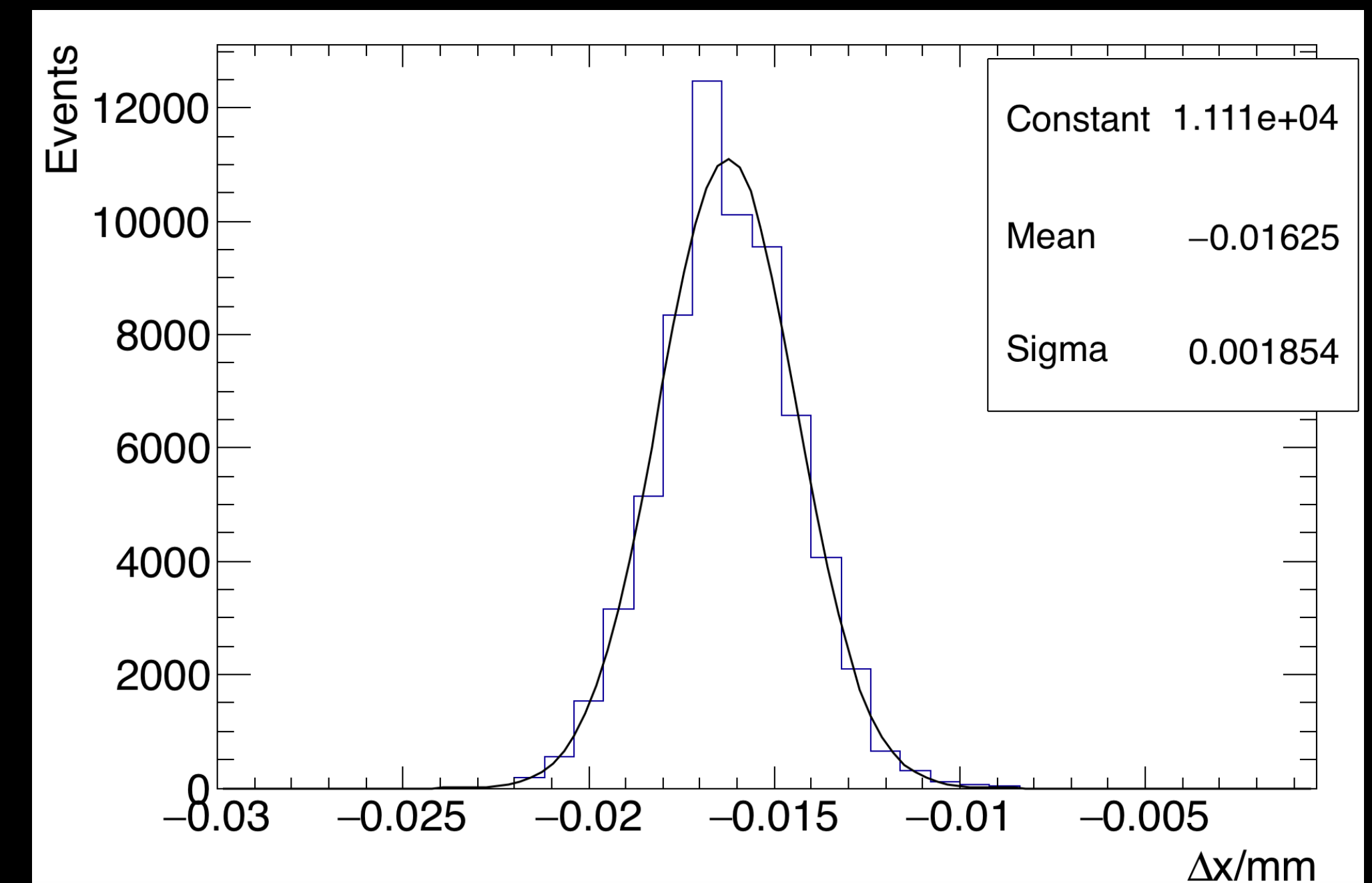
Air Cooling test on ladder

- Test bench setup for ladder air-cooling
- Vibration follows Gaussian distribution
 - Core of Gaussian is still under control 1~2 μm

Test setup prototype for ladder cooling
Use compressed air for cooling

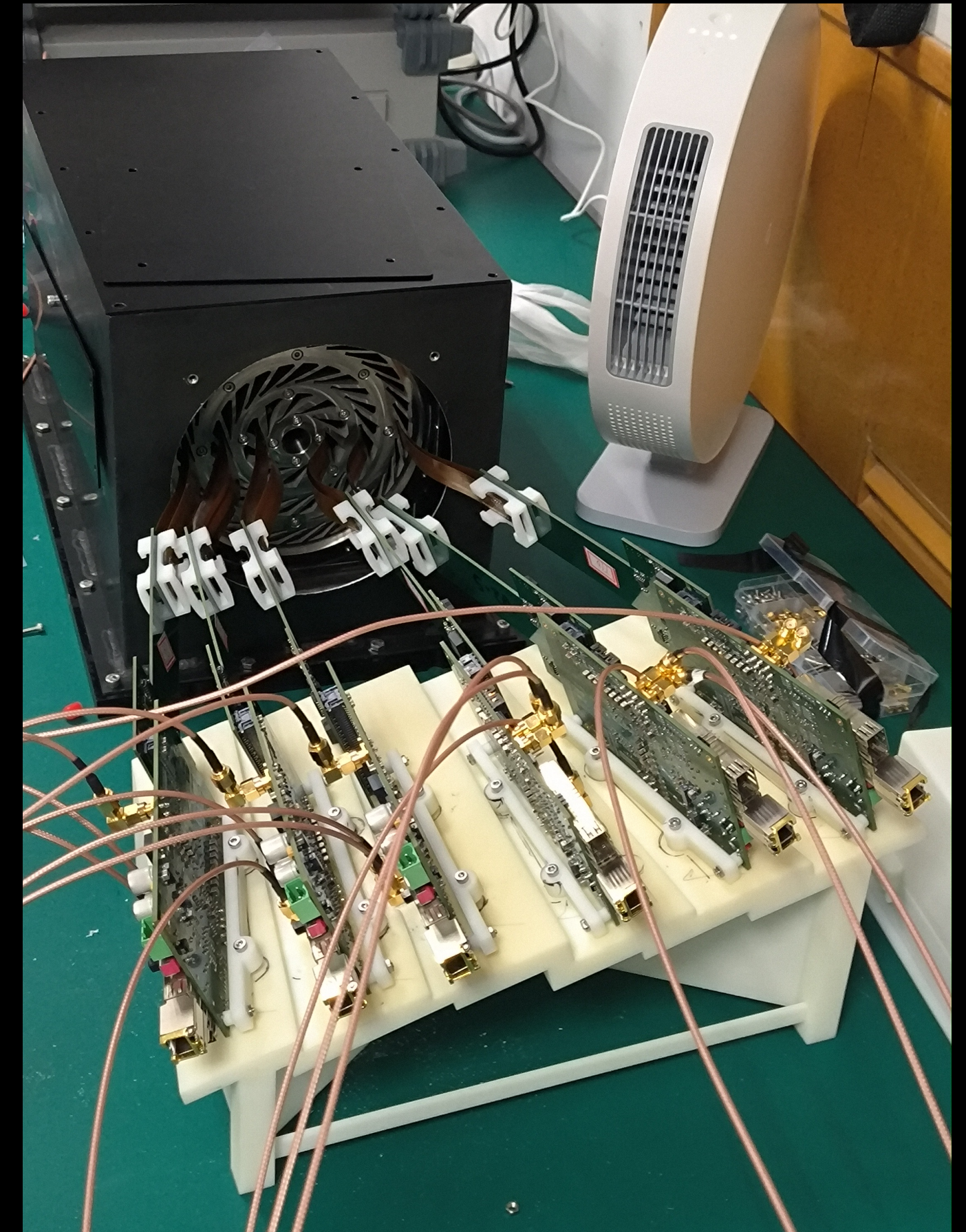
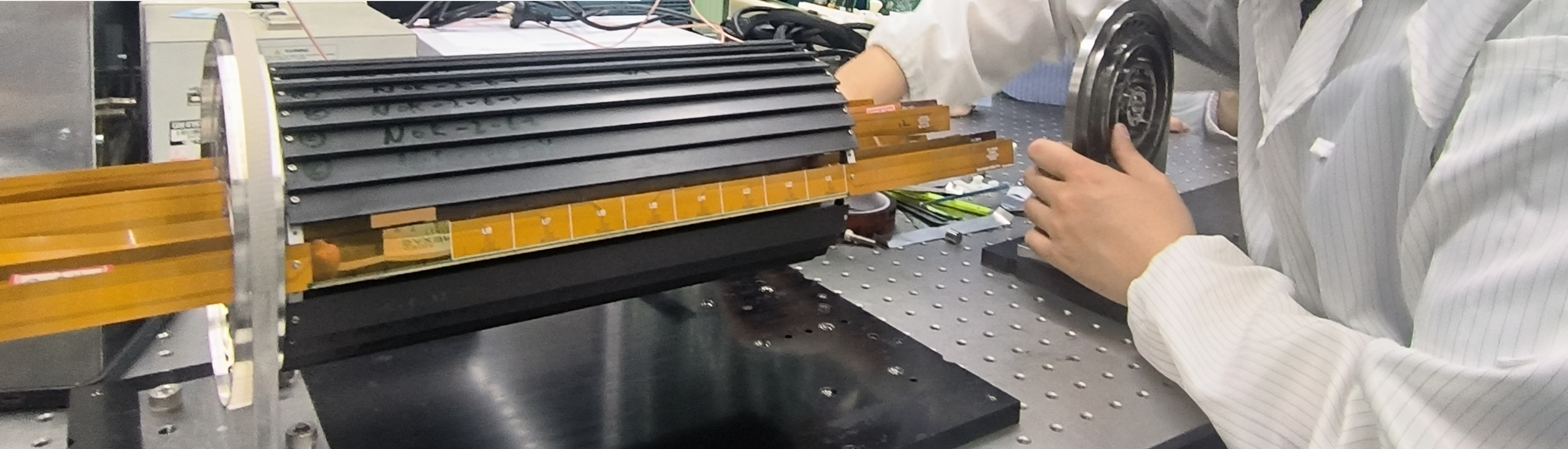
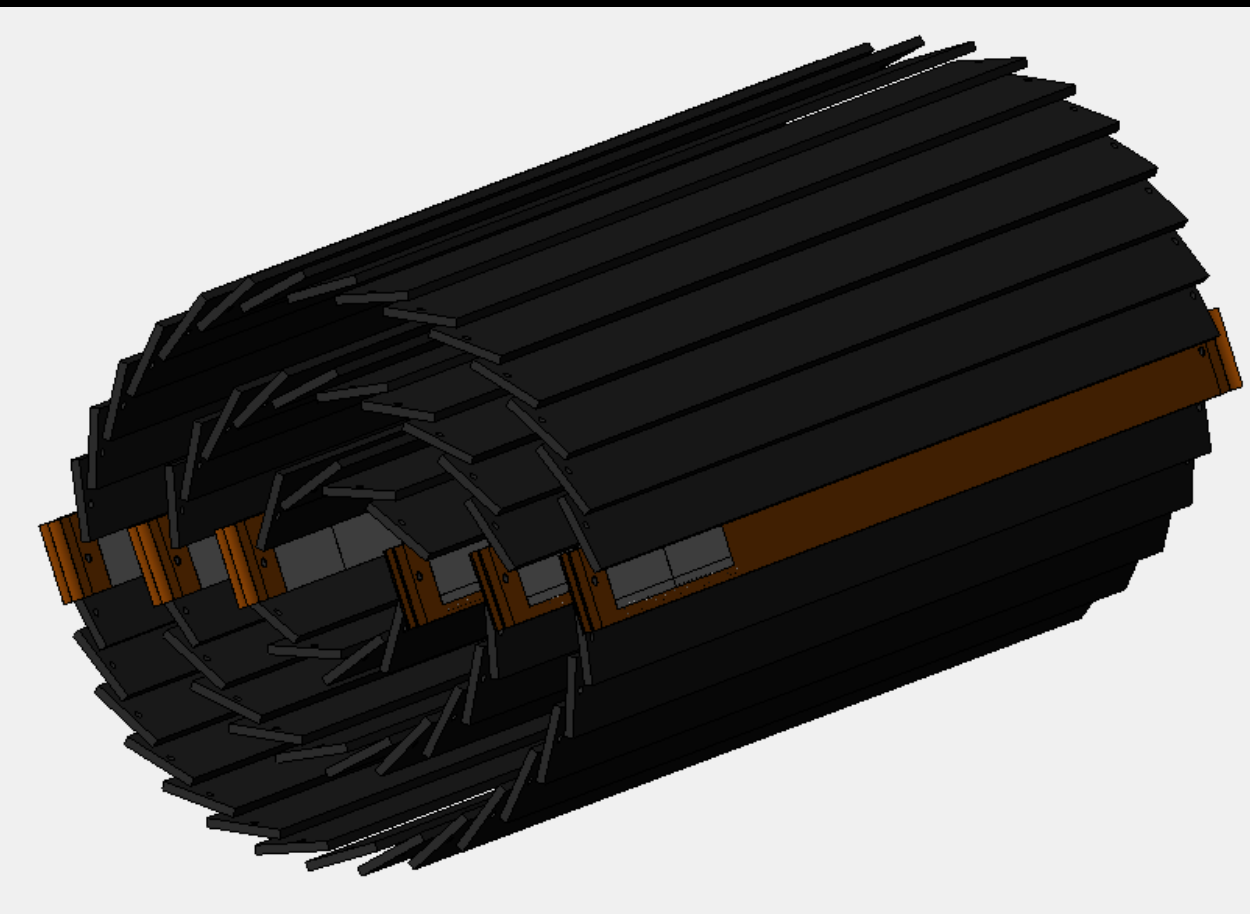


Typical Vibration displacement
during air cooling



Vertex detector Prototype assembly

- Six double-side ladders installed on the vertex detector prototype
 - 12 flex PCB , 24 Taichupix chips installed on detector prototype



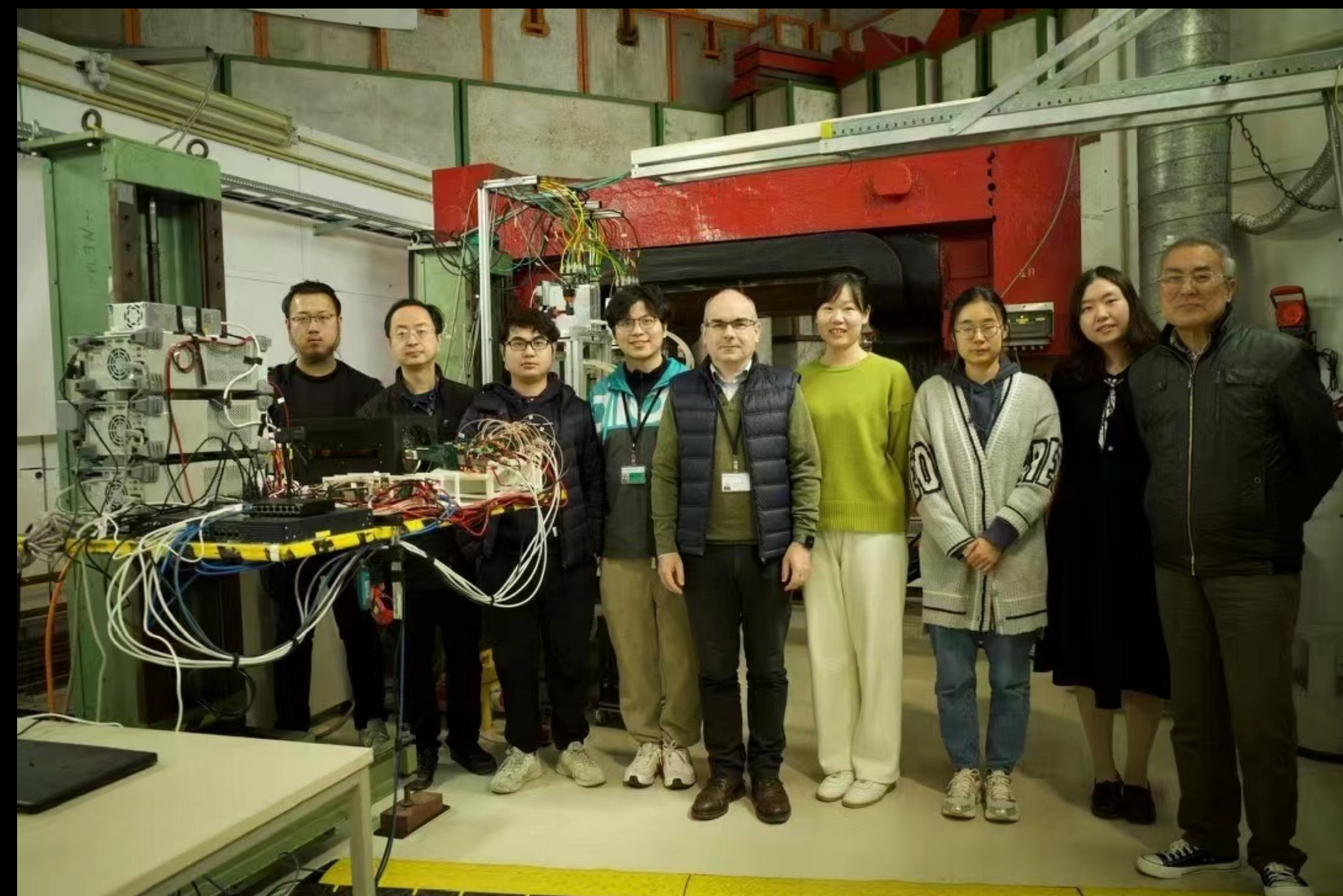
Test beam @ DESY

- 2nd testbeam: April 11-23 2023 DESY test beam in Germany (4-6GeV electron)
 - Vertex detector prototype testbeam
- 1st testbeam: Dec 12-22 2022 DESY test beam in Germany (4-6GeV electron)
 - TaichuPix Beam Telescope testbeam

2022 DESY test beam



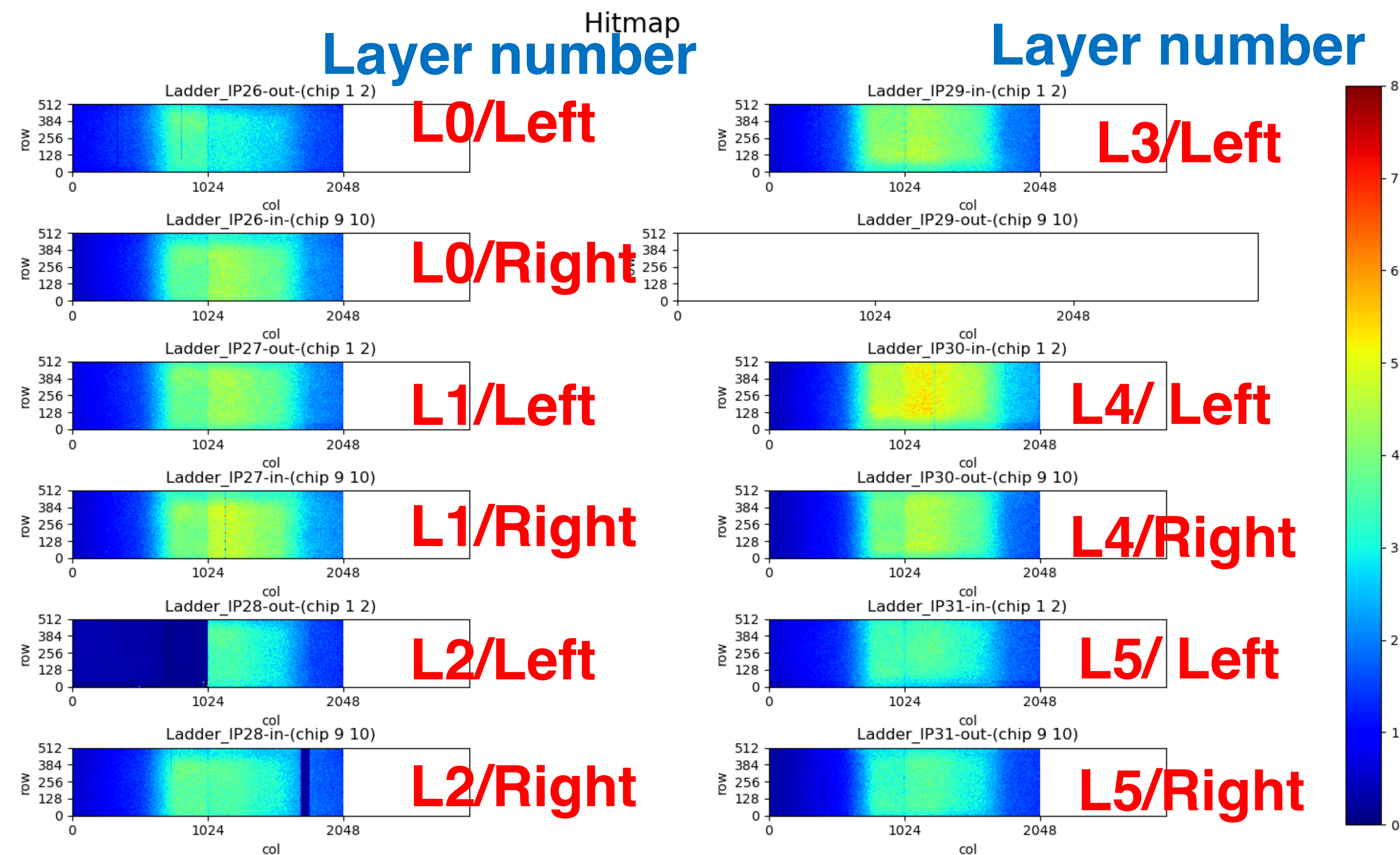
2023 DESY test beam



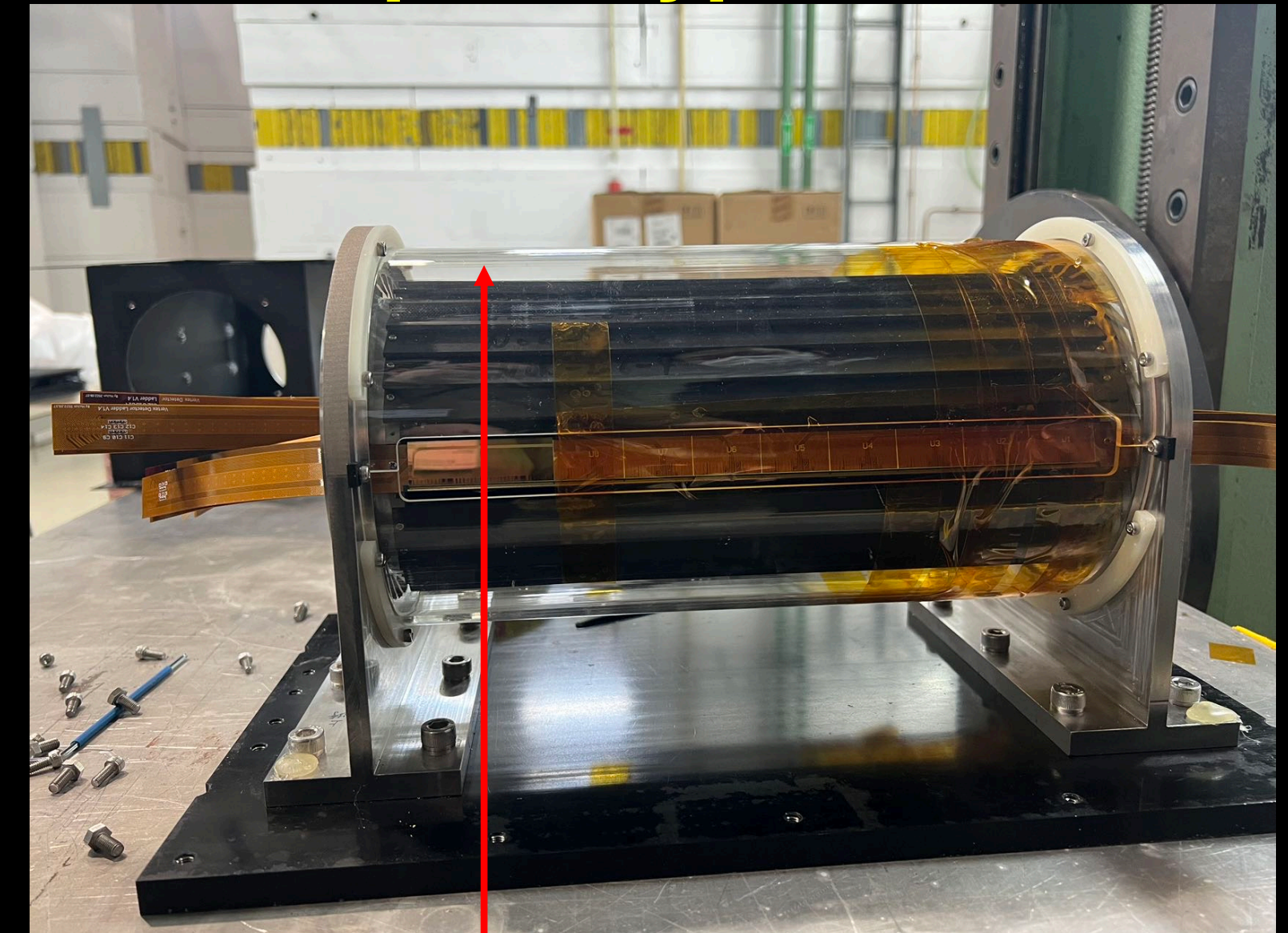
Test beam @ DESY for detector prototype

- Six double-side ladders installed on the vertex detector prototype for DESY testbeam
 - 12 flex PCB , 24 Taichupix chips installed on detector prototype
 - Beam spot ($\sim 2 \times 2 \text{cm}$) is visible on detector hit map
 - Record about one billion tracks in two weeks

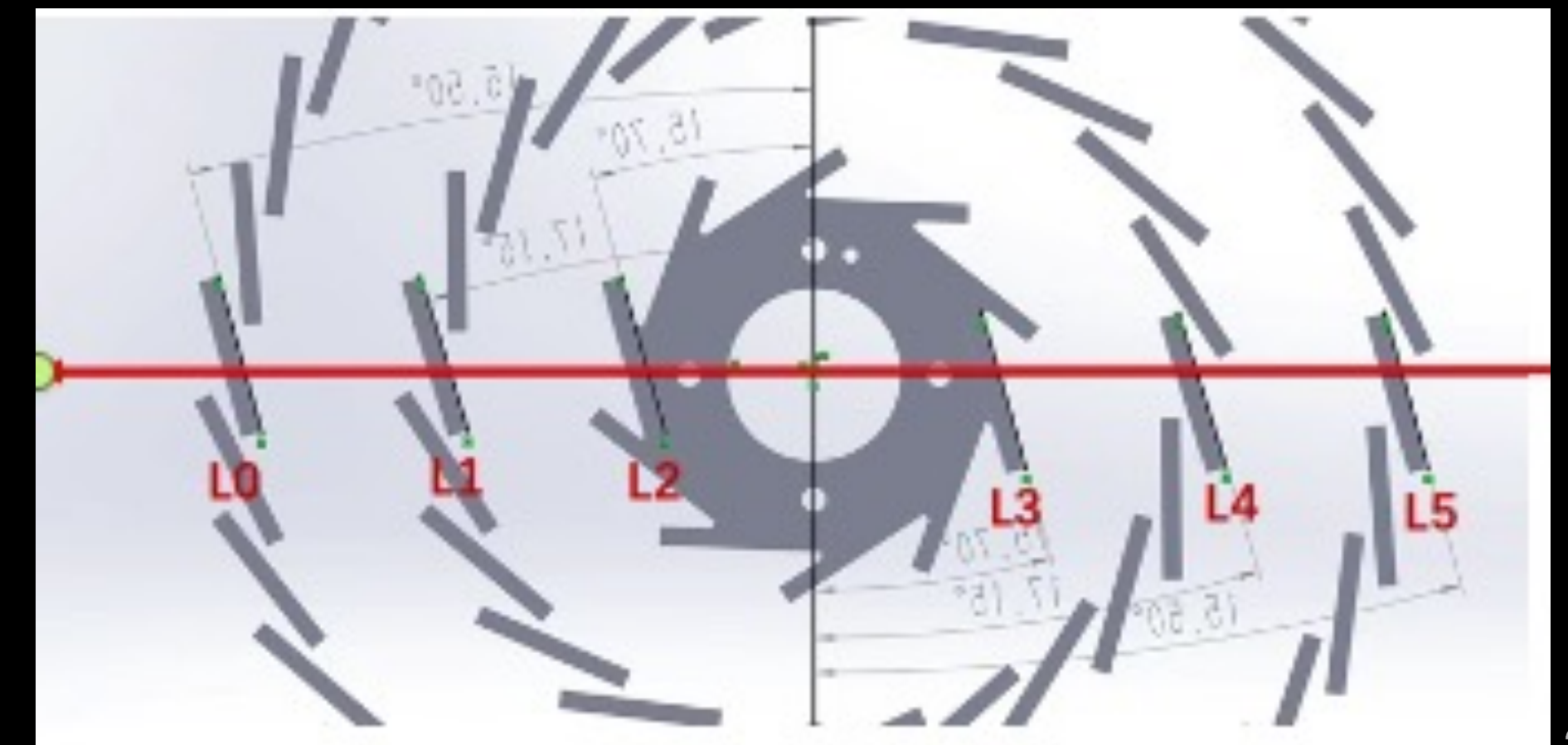
Hit maps of all layers taichupix on prototype



Detector prototype in testbeam



DESY Electron testbeam

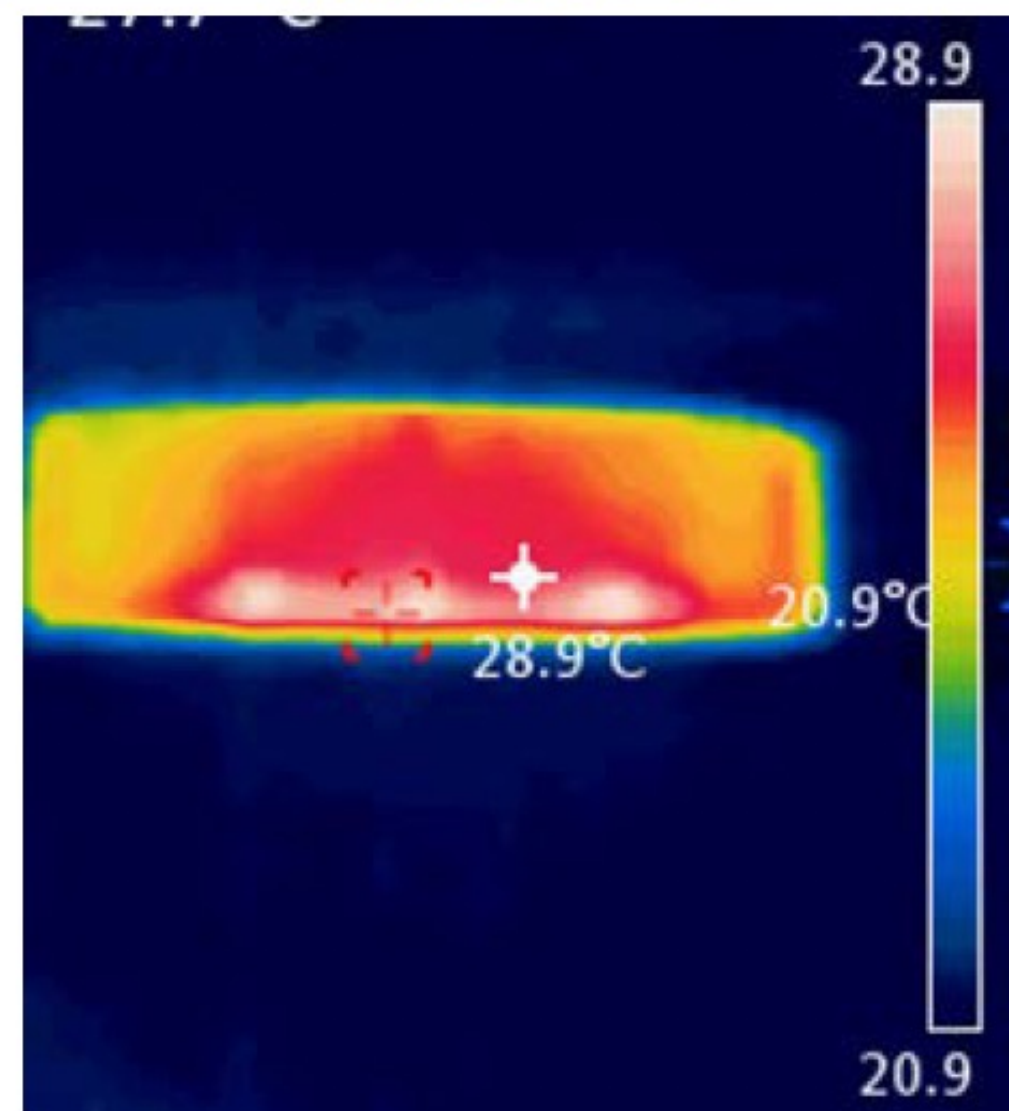


Air Cooling for vertex prototype

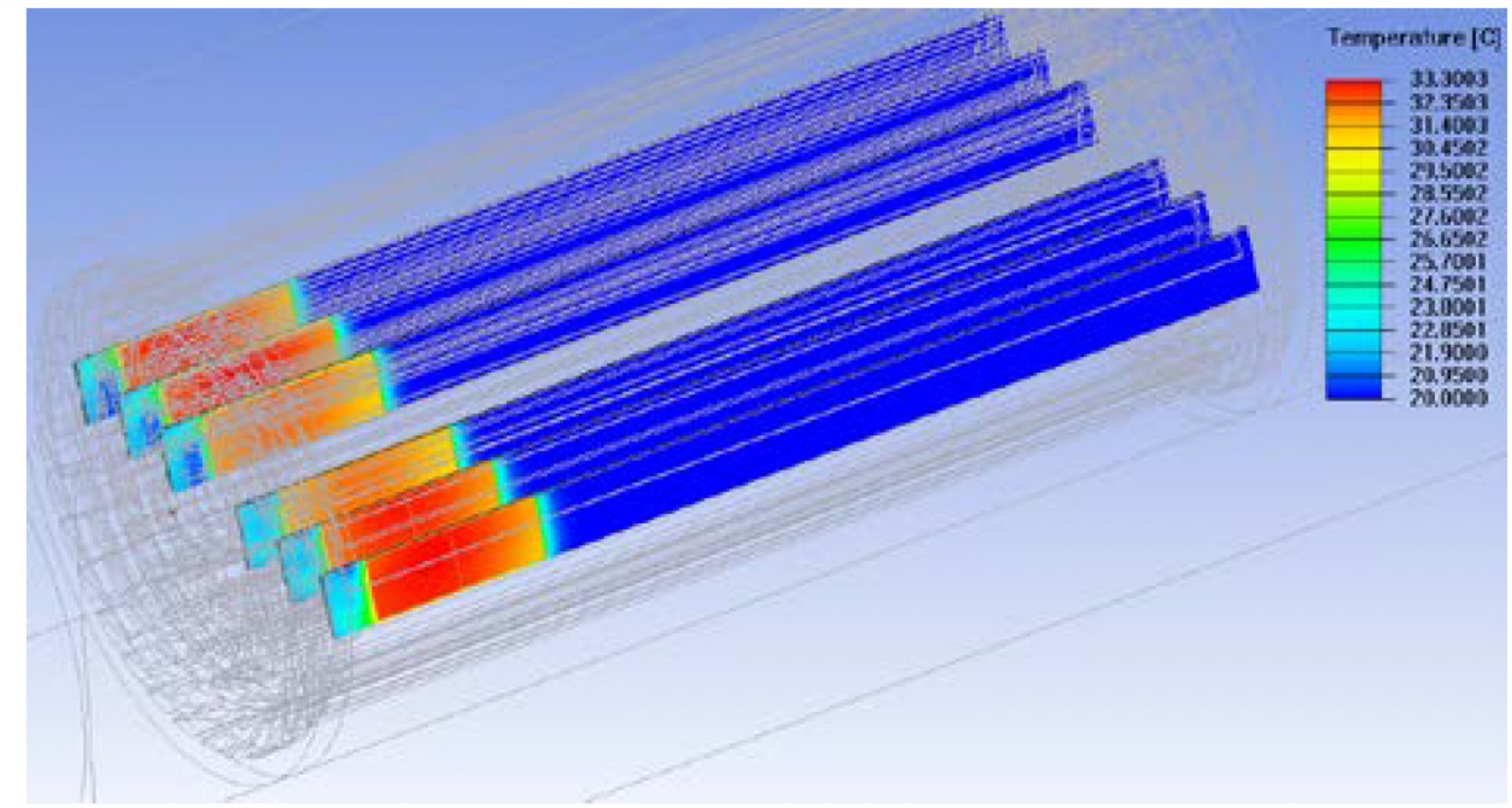
- Dedicated air cooling channel designed in prototype.
 - Measured Power Dissipation of Taichu chip: $\sim 60 \text{ mW/cm}^2$ (17.5 MHz clock in testbeam)
 - Before turning on the fan, chip temperature can go above 41°C .
 - With air cooling, chip temperature can be reduced to 25°C (in average)
 - In good agreement to our cooling simulation
 - No visible vibration effect observed in position resolution offline analysis when turning on the fan



Chip temperature under cooling during beam test:
Max 28.9°C

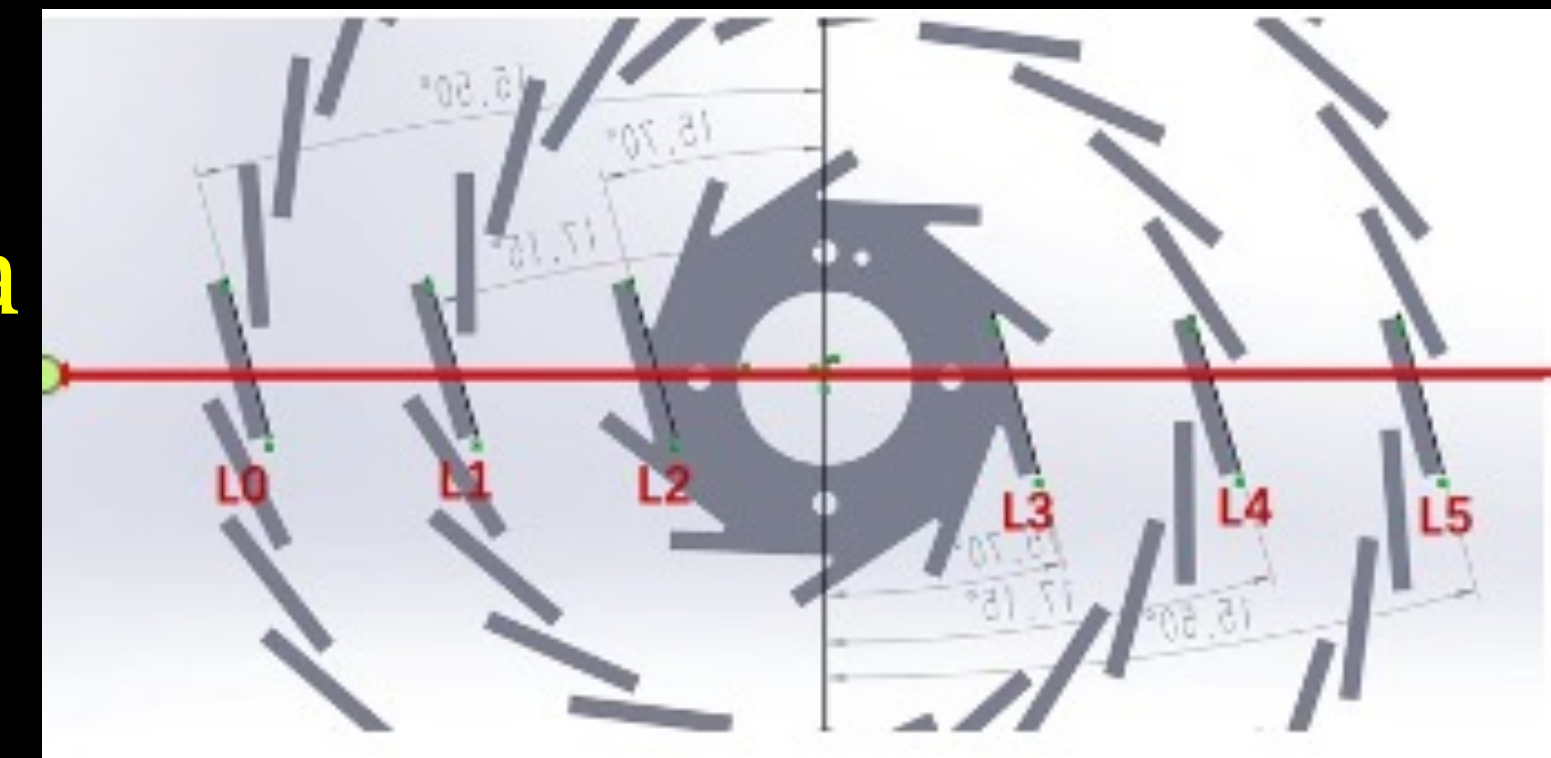


Prototype cooling simulation: Max 33.3°C



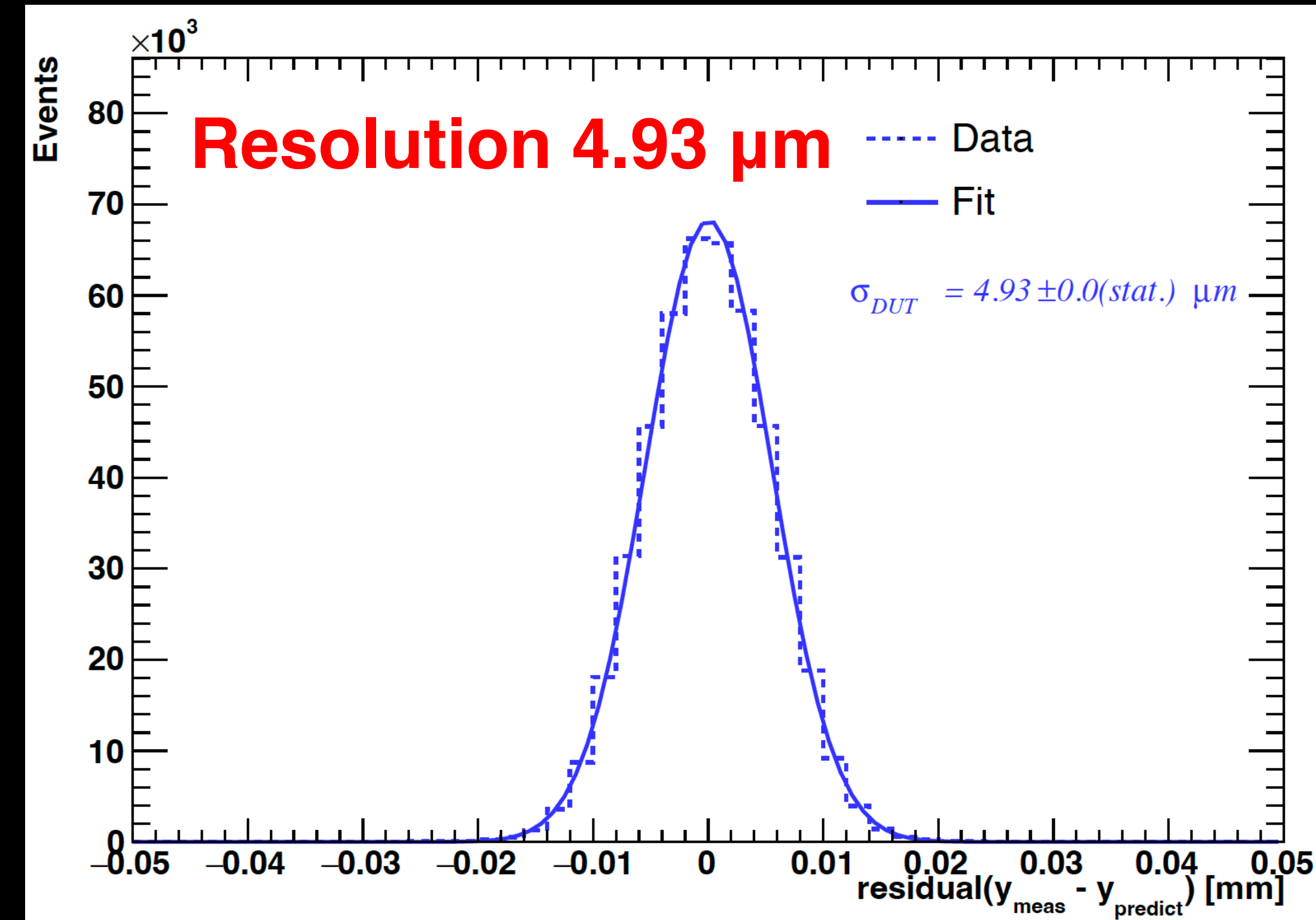
Test beam results (April 2023)

- Extract Spatial resolution from detector prototype testbeam data
 - One layer (L1) of TaichuPix used as Detector-Under-Test (DUT)
 - Other layers of vertex detector prototype used for track fitting
 - Spatial resolution reached $4.9\mu\text{m}$ (Y axis \rightarrow bending direction)
 - Spatial Resolution met the requirement (3-5 μm)

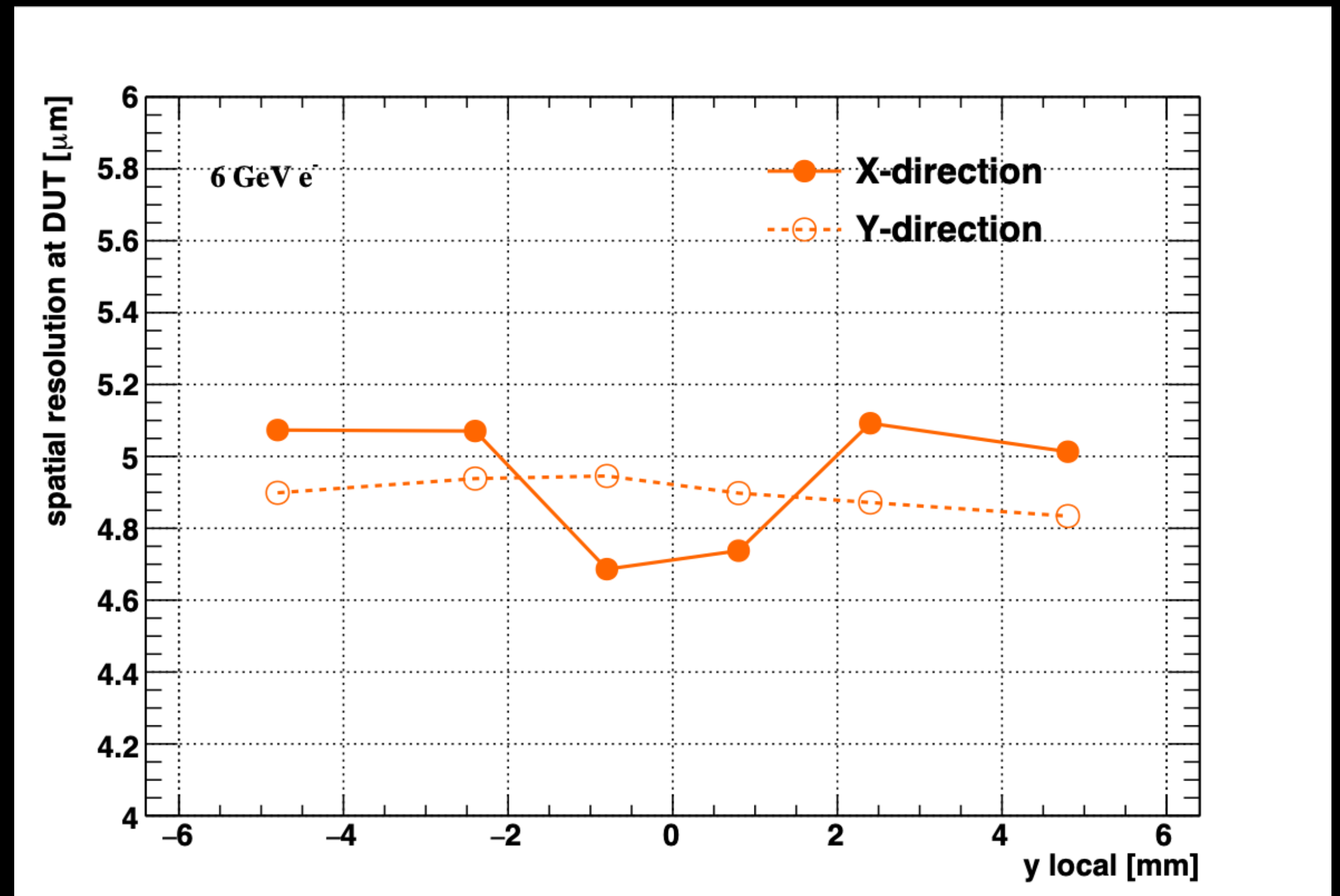


Residual distribution in Y axis

DUT measured position – expected position from track



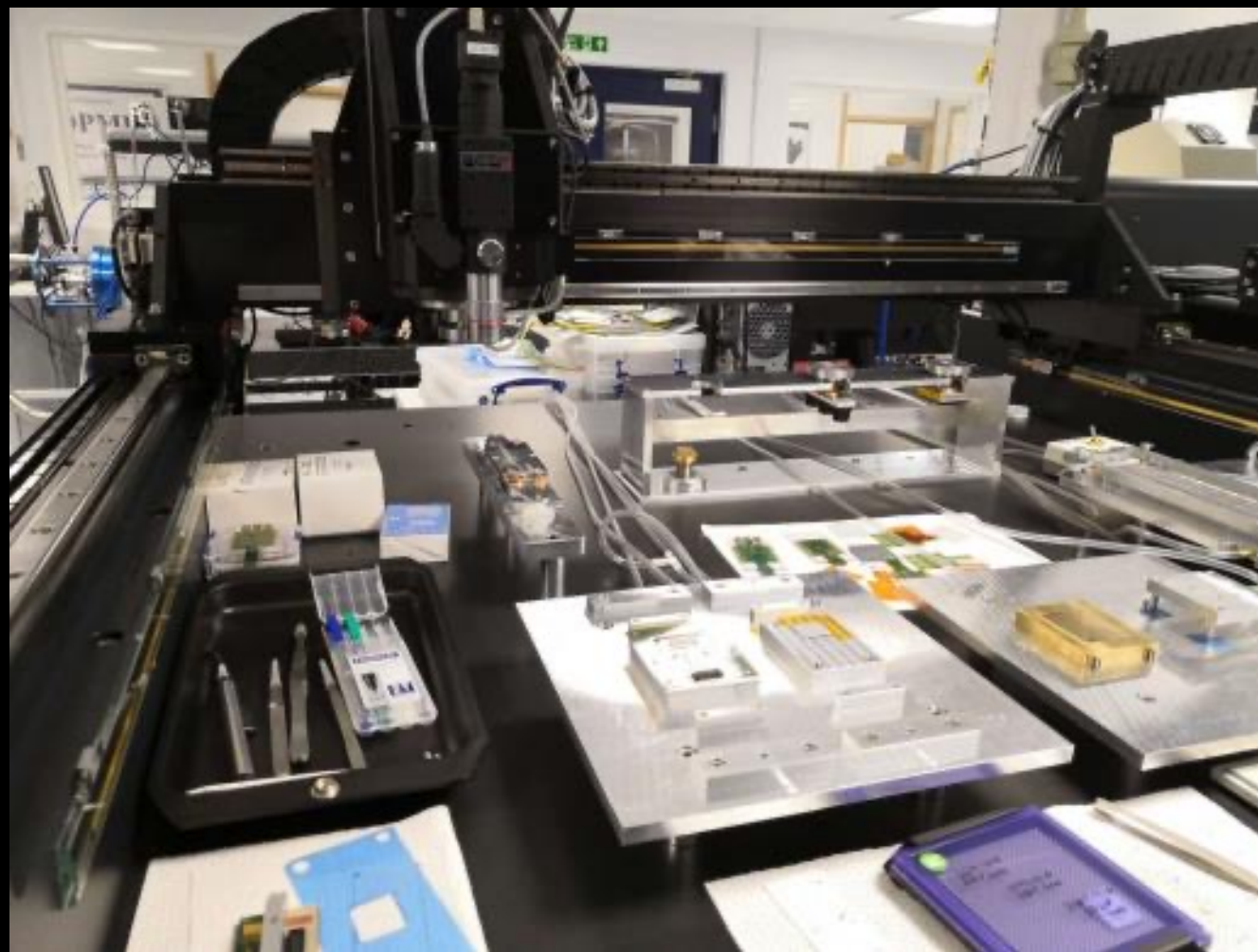
Spatial resolution vs hit positions
Y axis is bending direction



International Collaboration

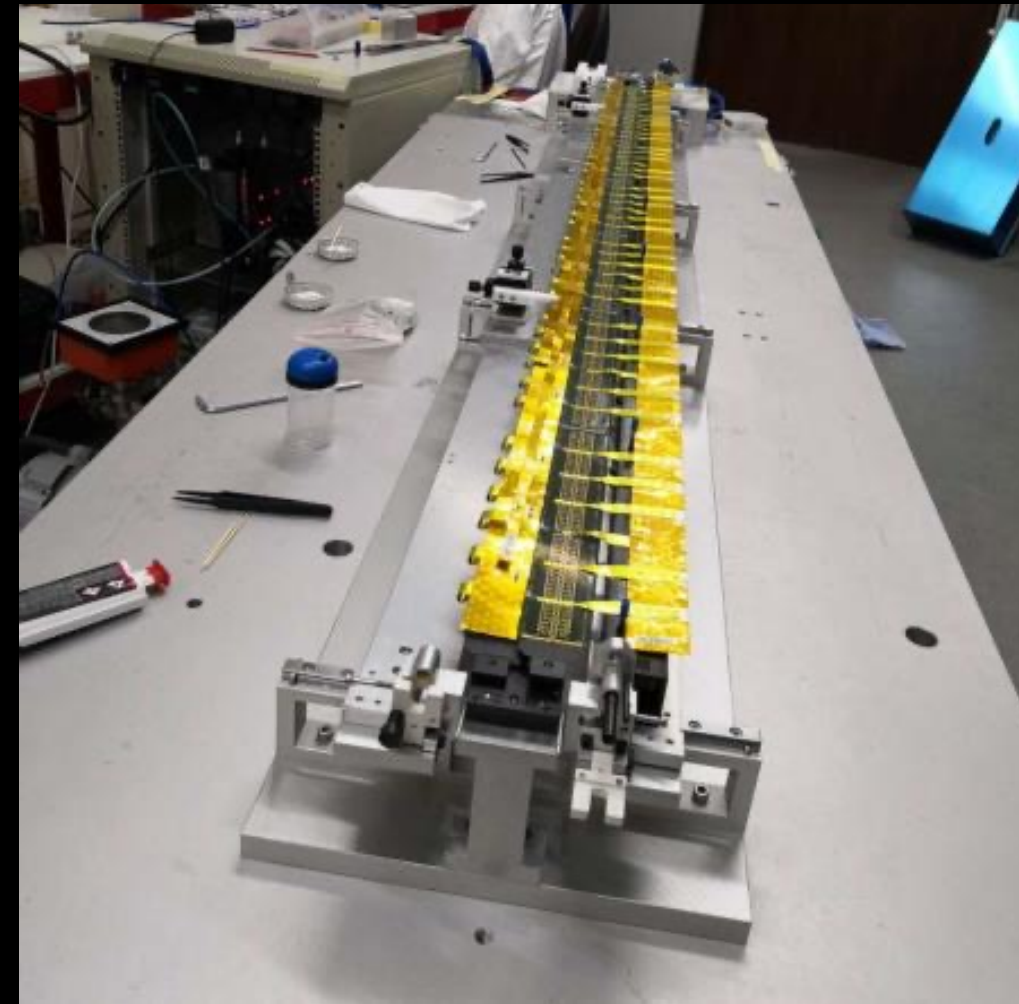
- **Active collaboration with IFAE (Spain) in sensor chip design.**
- **We have one engineer visited Oxford and Liverpool for 4 weeks in 2019**
- **Will incorporate the R & D with ECFA detector R & D (DRD3)**
- Planning to collaborate on module and detector structure
- Unfortunately, Collaboration didn't continue due to Covid

Lab visit in Oxford



*Mu3e ladder,
Atlas barrel
strip stave
prototype.*

Labs visit in Liverpool

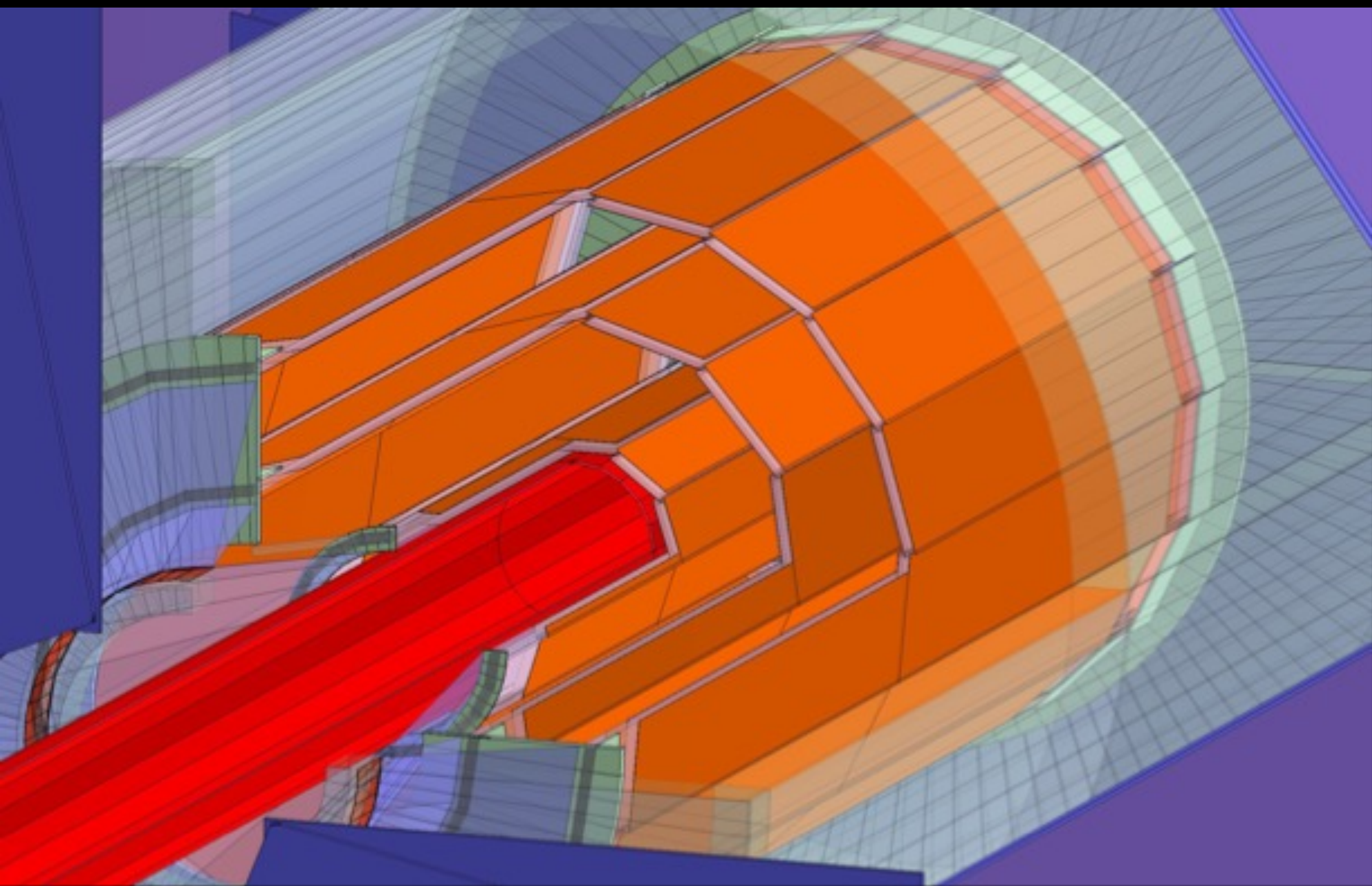


*Module of Alice's OB tracker,
Advance material Lab*

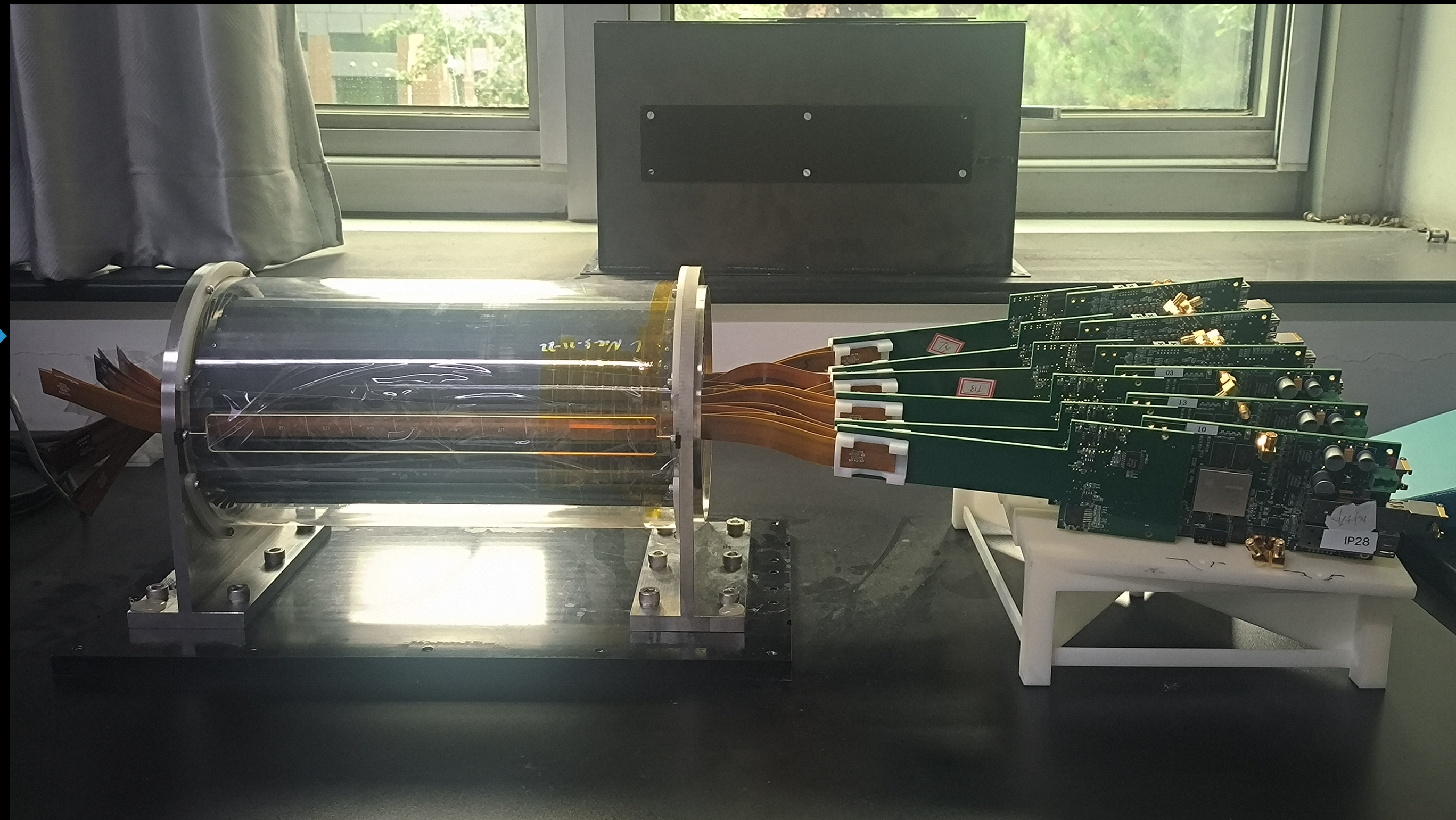
Summary of CECF vertex detector prototype

- **Developed full-size CMOS pixel sensor**
 - High spatial resolution and radiation hard
- **Developed the first vertex detector prototype in China**
 - Readout electronics and data acquisition for detector prototype was developed
- **Completed beam tests for the sensor prototype and the detector prototype at DESY**

CEPC design (2016)



Vertex detector prototype (2023)



Summary of CECF vertex detector prototype (2)

- **Some remarks about future development**
- **Incorporate the R & D effort with ECFA detector R &D (DRD3 development)**
- **Cooling for vertex detector @ Z pole running is still need to explore**
 - Air cooling feasibility for inner most layer is still need to be validated
- **Cross talk and noise for ladder (multi-chips) are still to reduce .**
 - Need to further develop In-chip LDO, reduce noise caused due to power lines.
 - Optimize the design of ladder
- **Still need to reduce material budget**
 - New solution of curved silicon (ALICE ITS3 like) is very attractive

backup

Air cooling for CEPC vertex detector

- Air cooling is baseline design for CEPC vertex detector
- Sensor Power dissipation:
 - Taichupix design : $\leq 100 \text{ mW/cm}^2$. (trigger mode), $\leq 150 \text{ mW/cm}^2$ (triggerless mode),
 - Taichupix measured result: $\sim 60 \text{ mW/cm}^2$ (triggerless mode, 17.5MHz)
 - CEPC final goal : $\leq 50 \text{ mW/cm}^2$
- Cooling simulations of a single complete ladder with detailed FPC were done.
 - Need 2 m/s air flow to cool down the ladder

Max temperature of ladder (°C) (air temperature 5 °C)					
Air speed (m/s) Power Dissipation (mW/cm2)	5	4	3	2	1
100	19.6	21.8	25.0	30.6	43.4
150	26.9	30.1	35	43.4	62.6

Summary of CECF vertex detector prototype

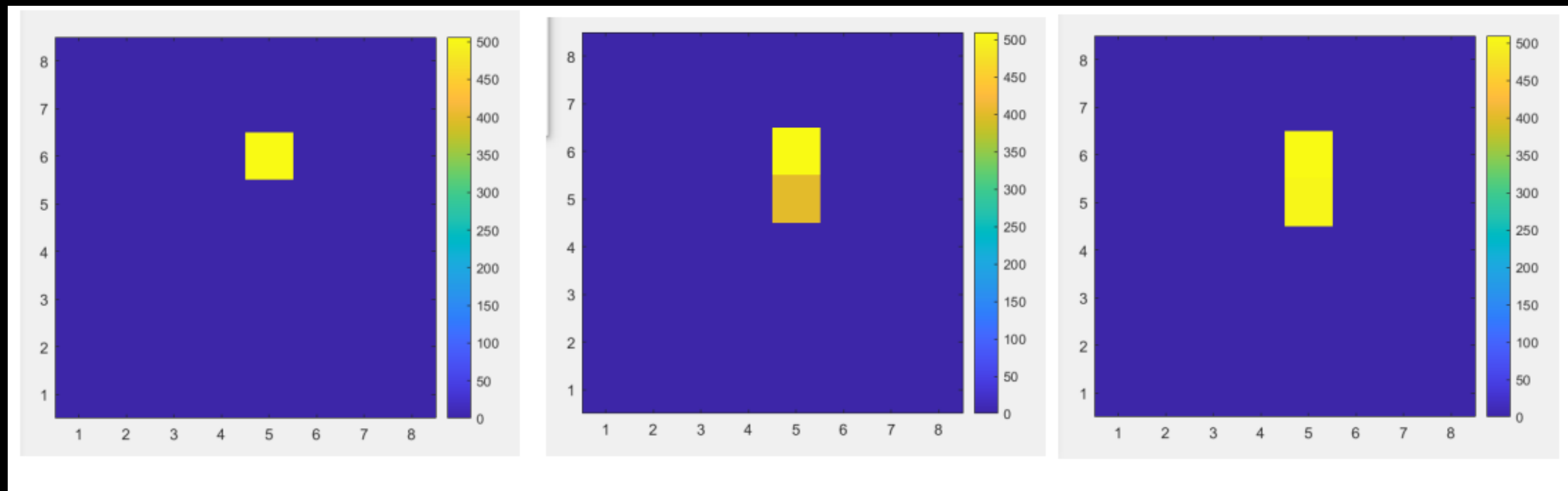
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	Requirement	Result
Single point Spatial resolution	3-5 μm	Laser test: $\sim 4 \mu\text{m}$ Chip-level Beam Test : $4.8 \mu\text{m}$ Prototype level Beam Test: $4.9 \mu\text{m}$

Spatial resolution measured by Laser tests

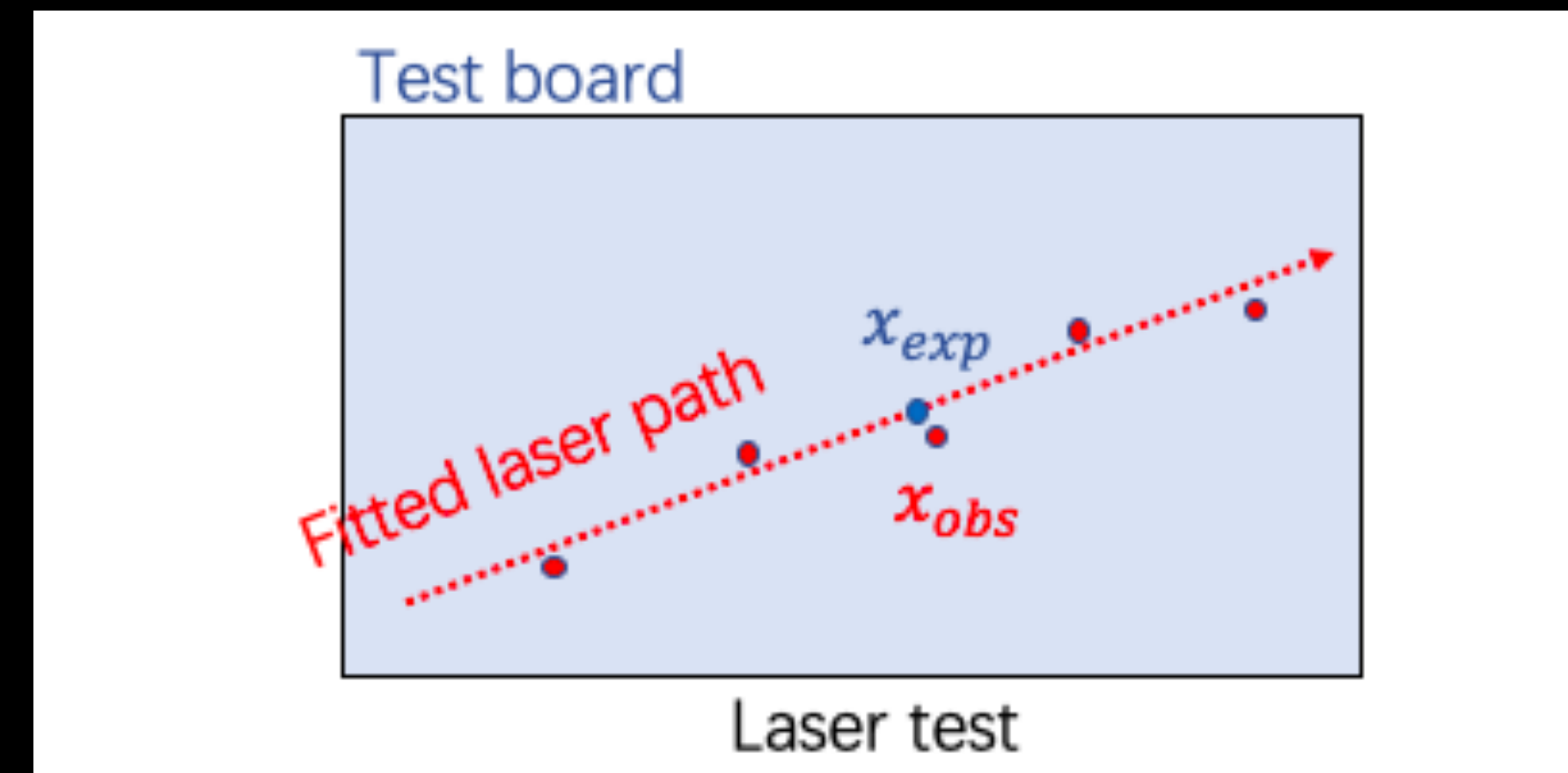
- Spatial resolution of Taichu2 can reach $\sim 4\text{ }\mu\text{m}$ in laser tests
 - Use high precision 2D movable station in laser scan
 - Laser was scanning with a step of $1\text{ }\mu\text{m}$

Laser beam spot during scan

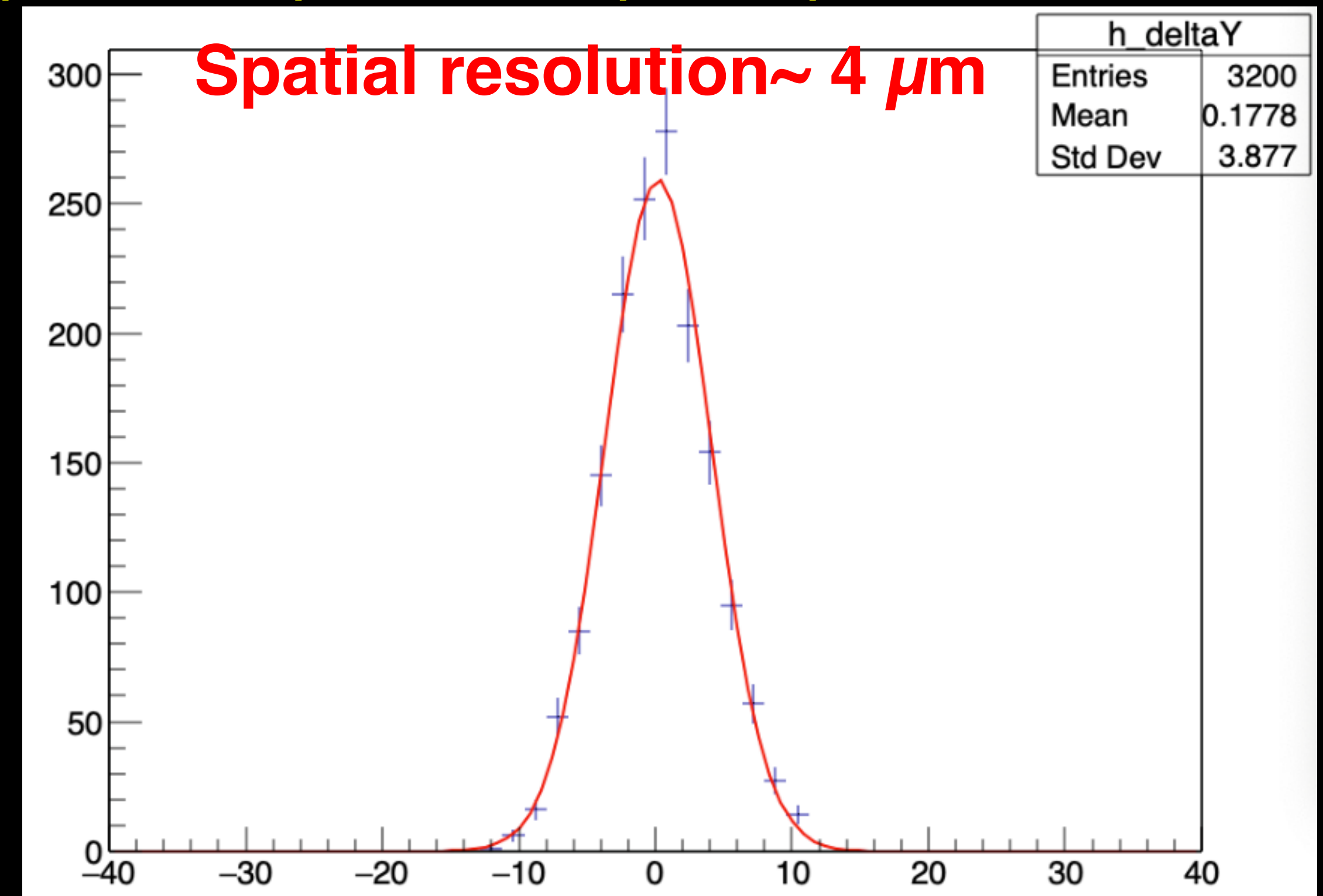


Spatial Resolution in X and Y direction

	Resolution (μm)	Overall error (μm)
X	3.98	± 0.23
Y	4.12	± 0.25



Residual distribution
(measured position – expected position from station)

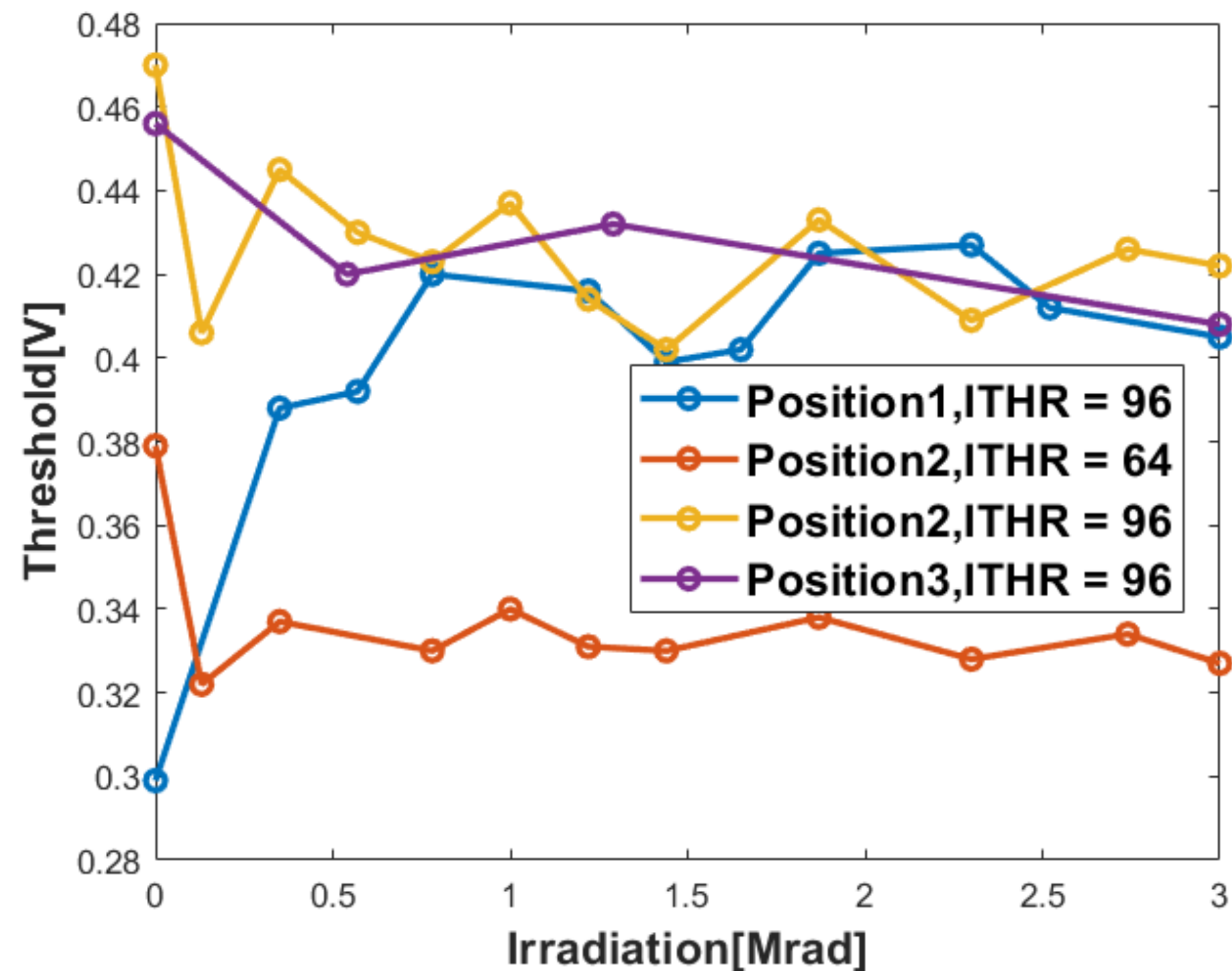


Spatial resolution $\sim 4\text{ }\mu\text{m}$

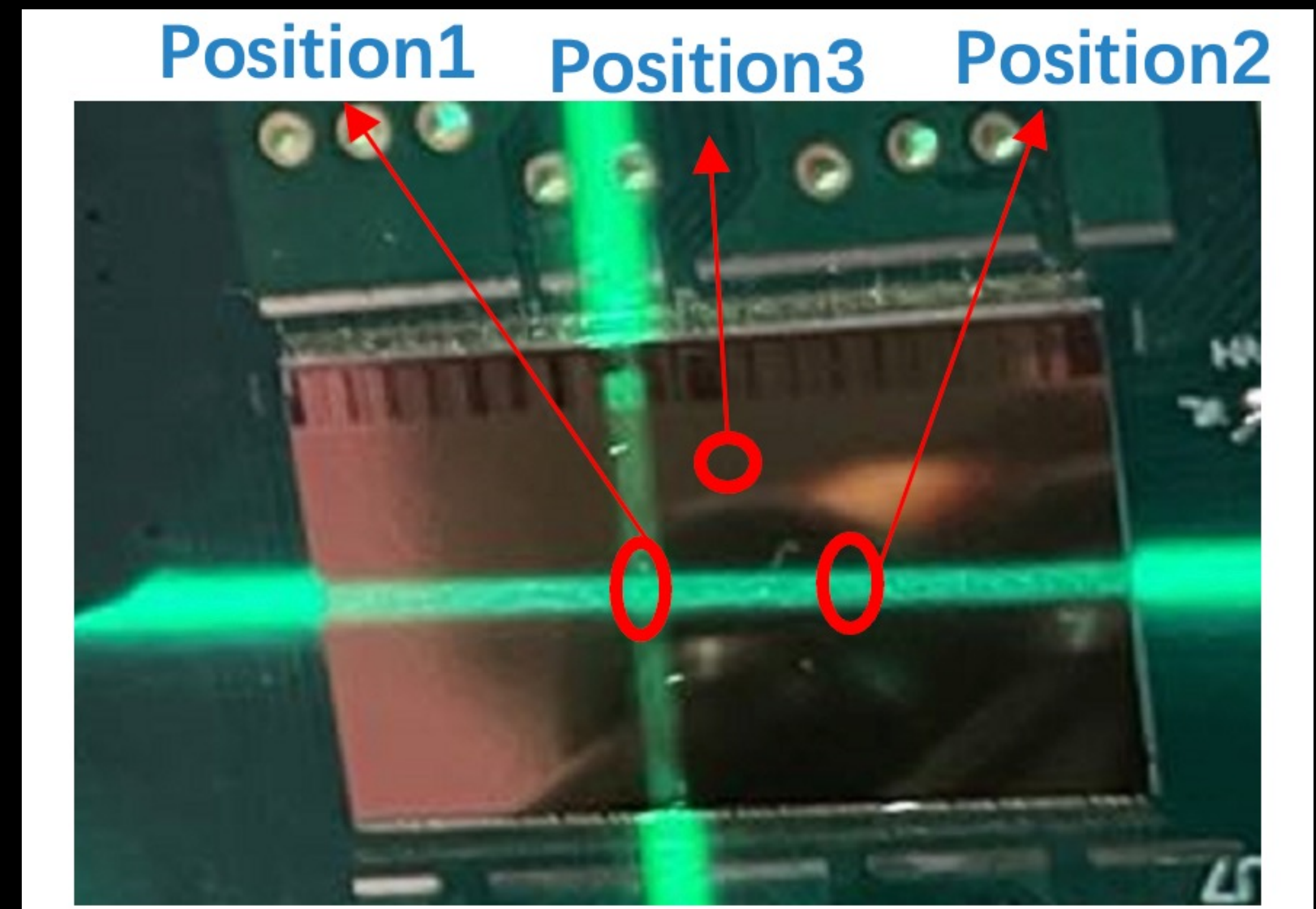
Radiation tests

- Taichupix3 was irradiated in-situ tested up to 3 Mrad
 - Normal chip functionality and reasonable noise performance
 - Reach the goal of the project: radiation hardness on total ionization does >1 Mrad

Taichupix3 irradiation test Pixel threshold vs. TID

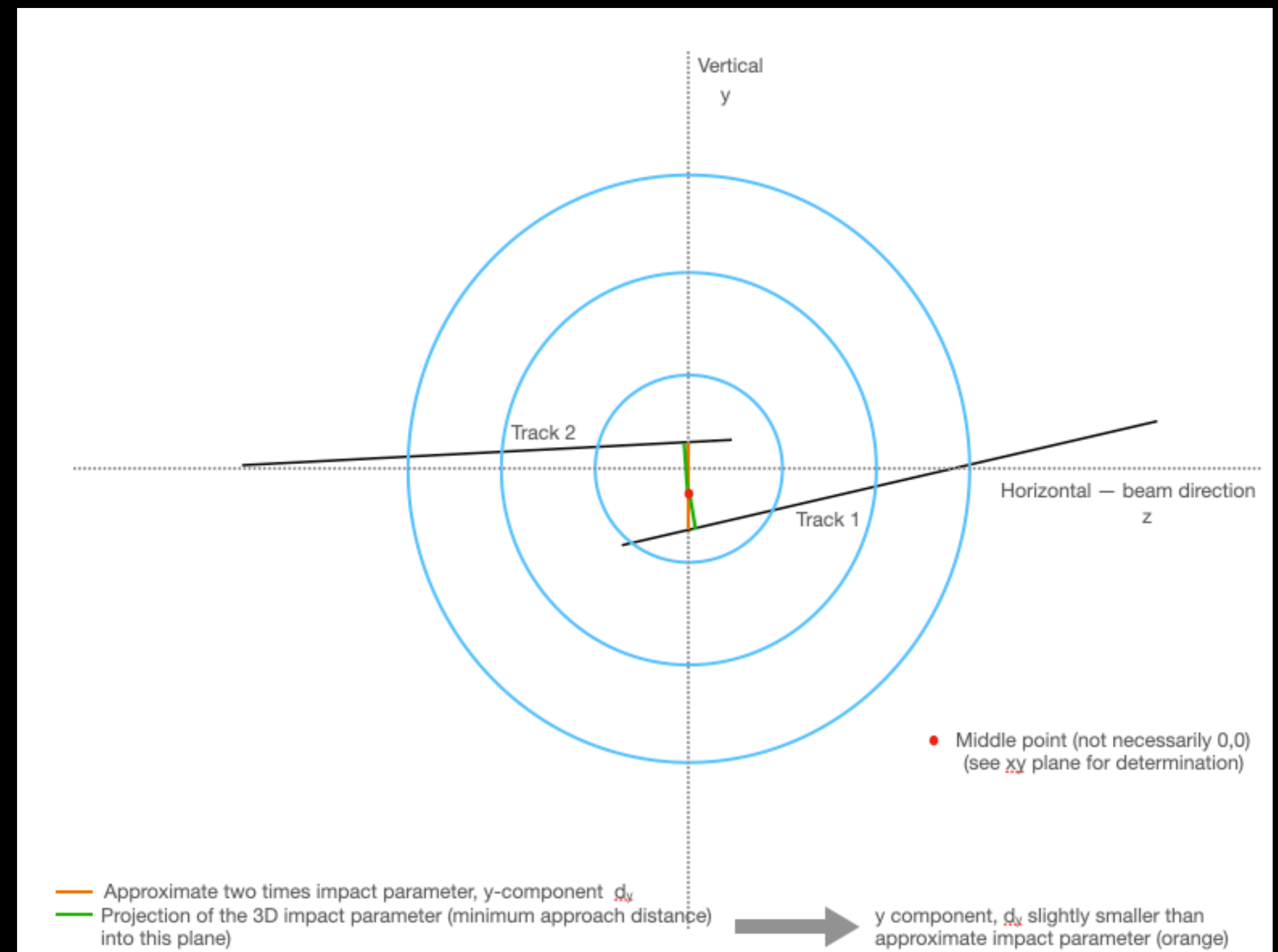
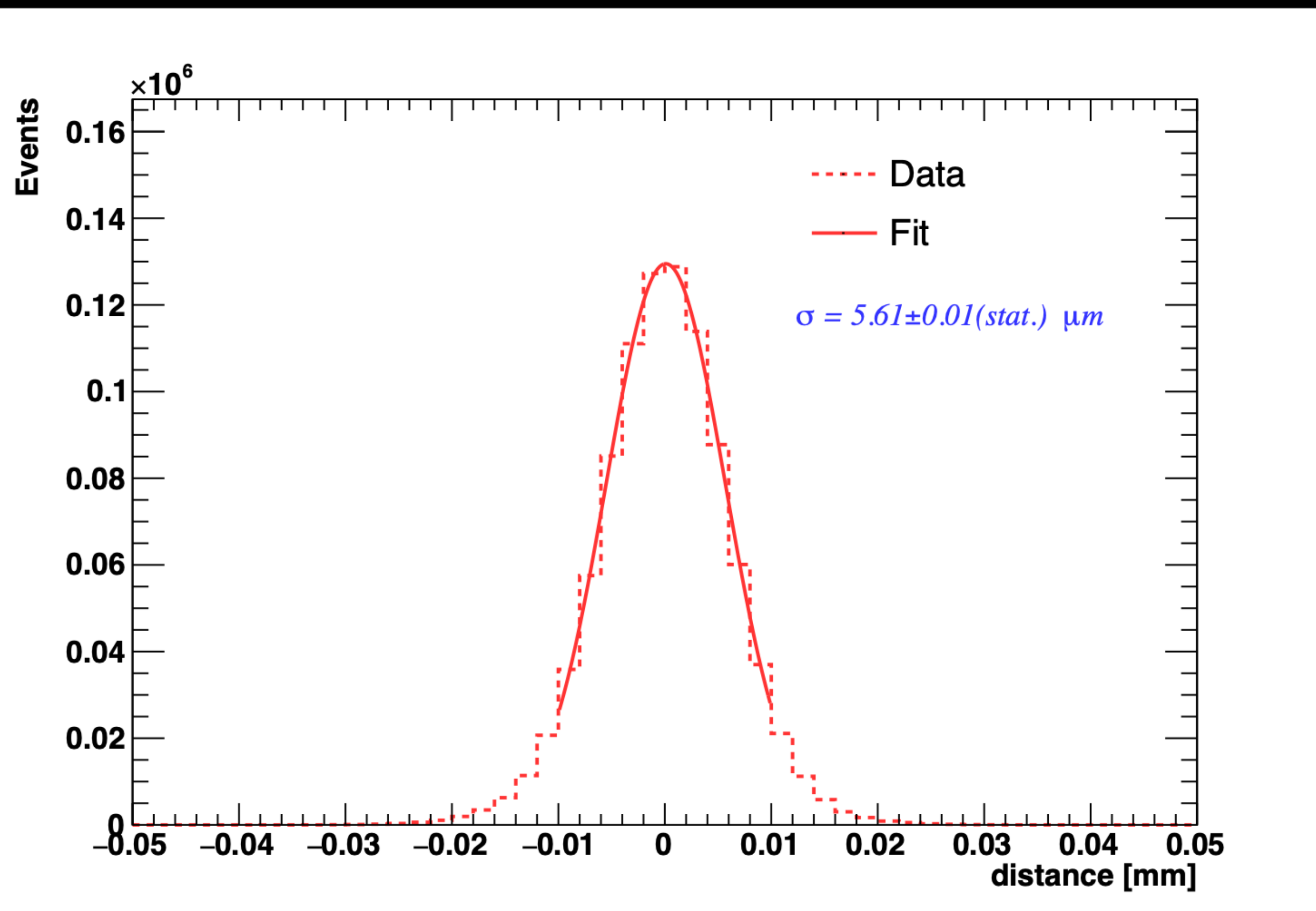


TaichuPix-3 irradiated at Synchrotron radiation beamline (12 keV X-ray)



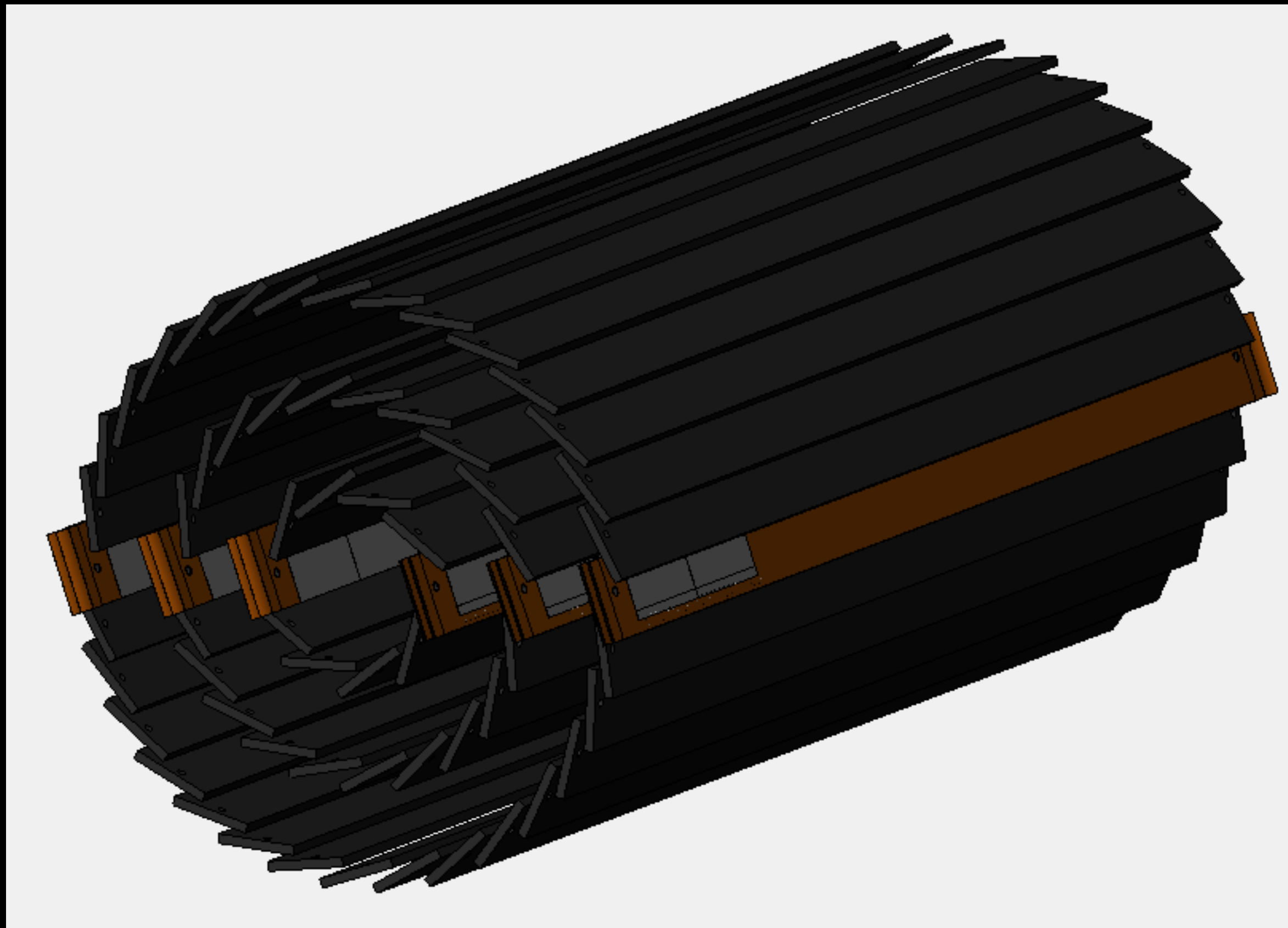
Preliminary result of impact parameter resolution

- No real interaction point or real primary vertex (PV) in testbeam setup
 - Define PV as the centre of the point in xy plane extrapolated from the up/downstream
 - Calculate the impact parameter between primary vertex and upstream/downstream tracks

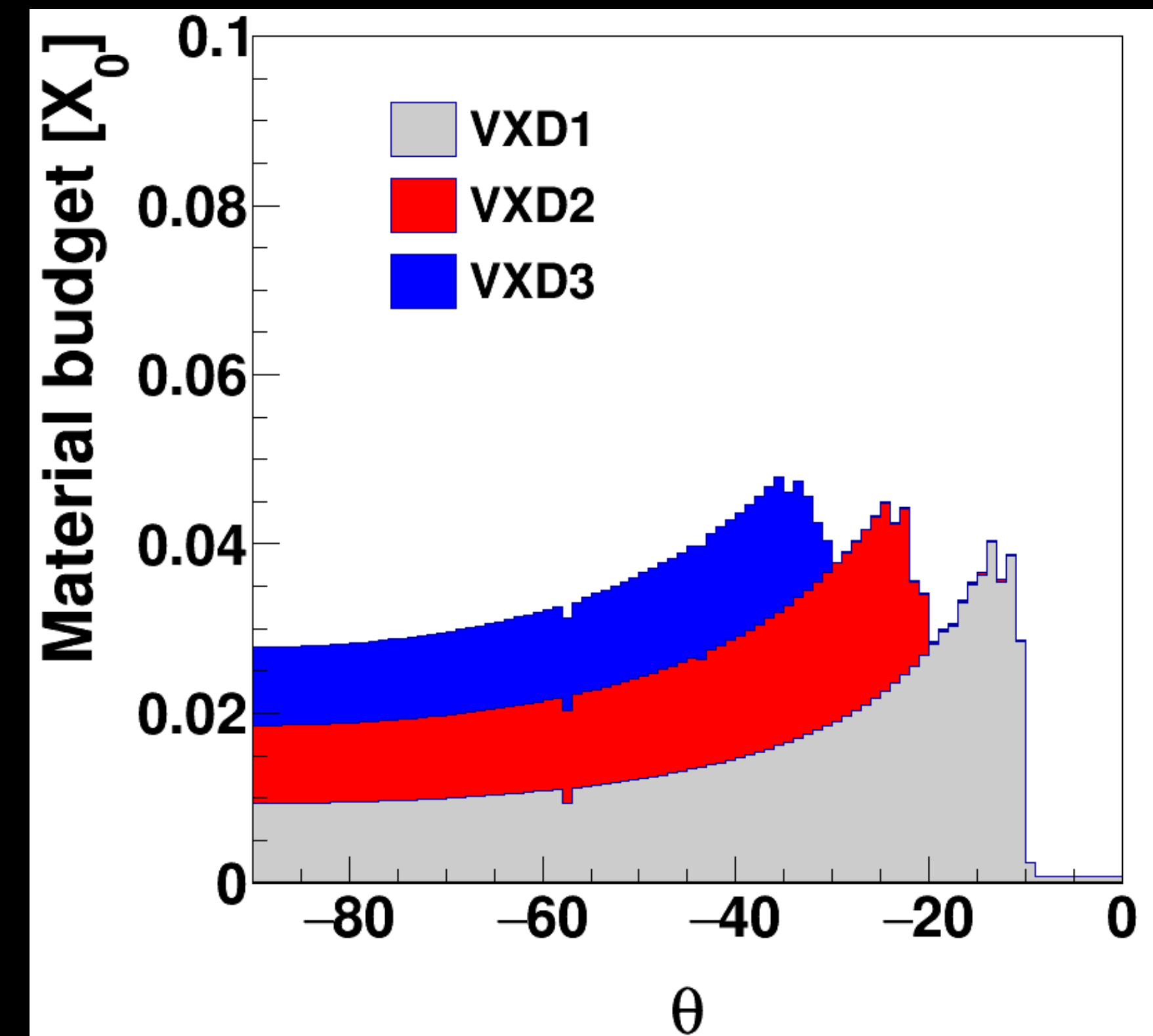


Estimated Material budget for vertex detector prototype

- Estimated material budget 0.026 X_0 for three double ladders vertex detector (6 layers)
 - Target for final CEPC vertex detector is 0.009 X_0 (0.015% X_0 per layer)
 - Copper in flexible PCB are major contributions
 - Plan to replace copper into Aluminum in final CEPC vertex detector
 - Further thinning of silicon wafer (150 μm \rightarrow 50 μm)



Estimated material budget for this prototype

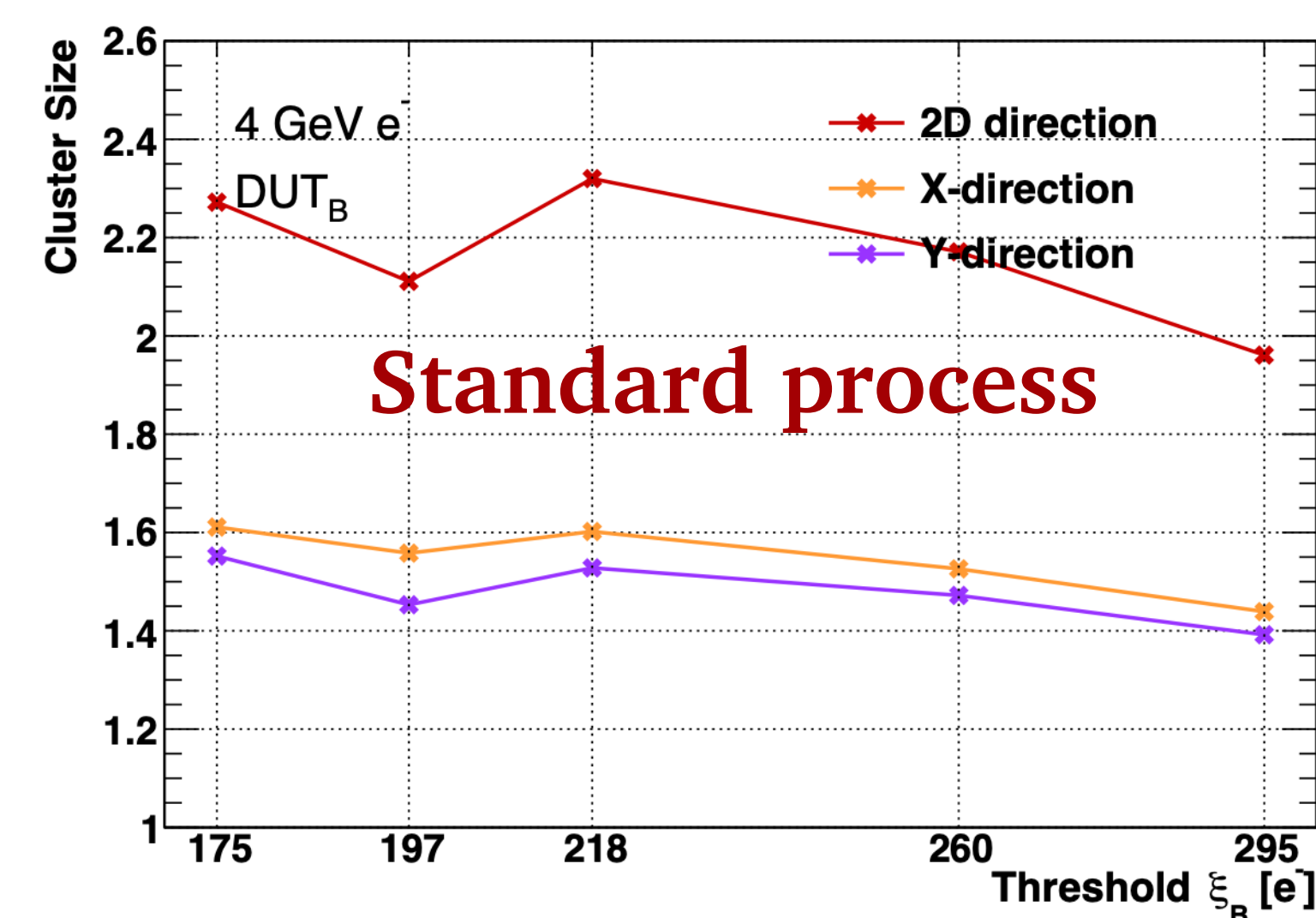
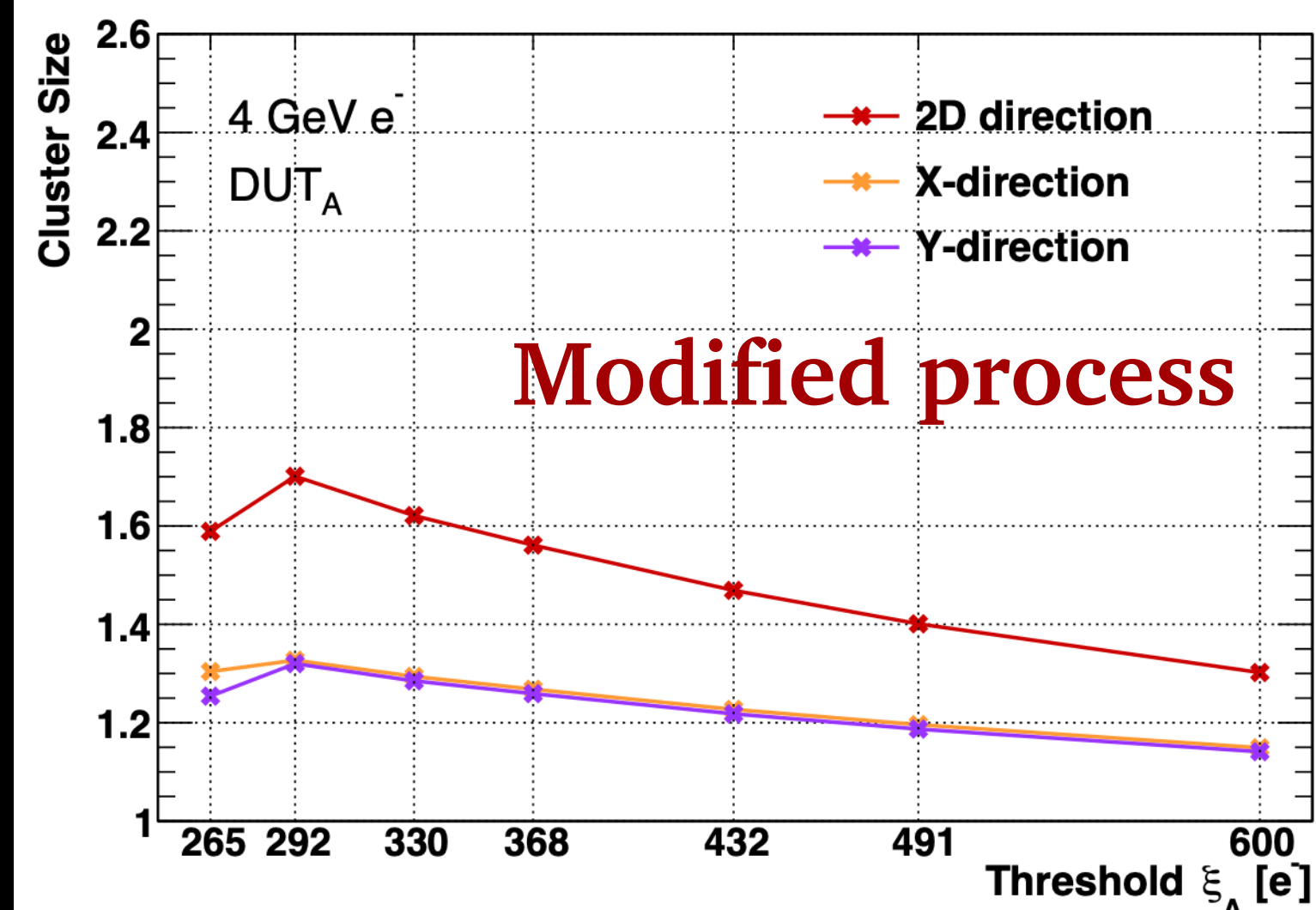
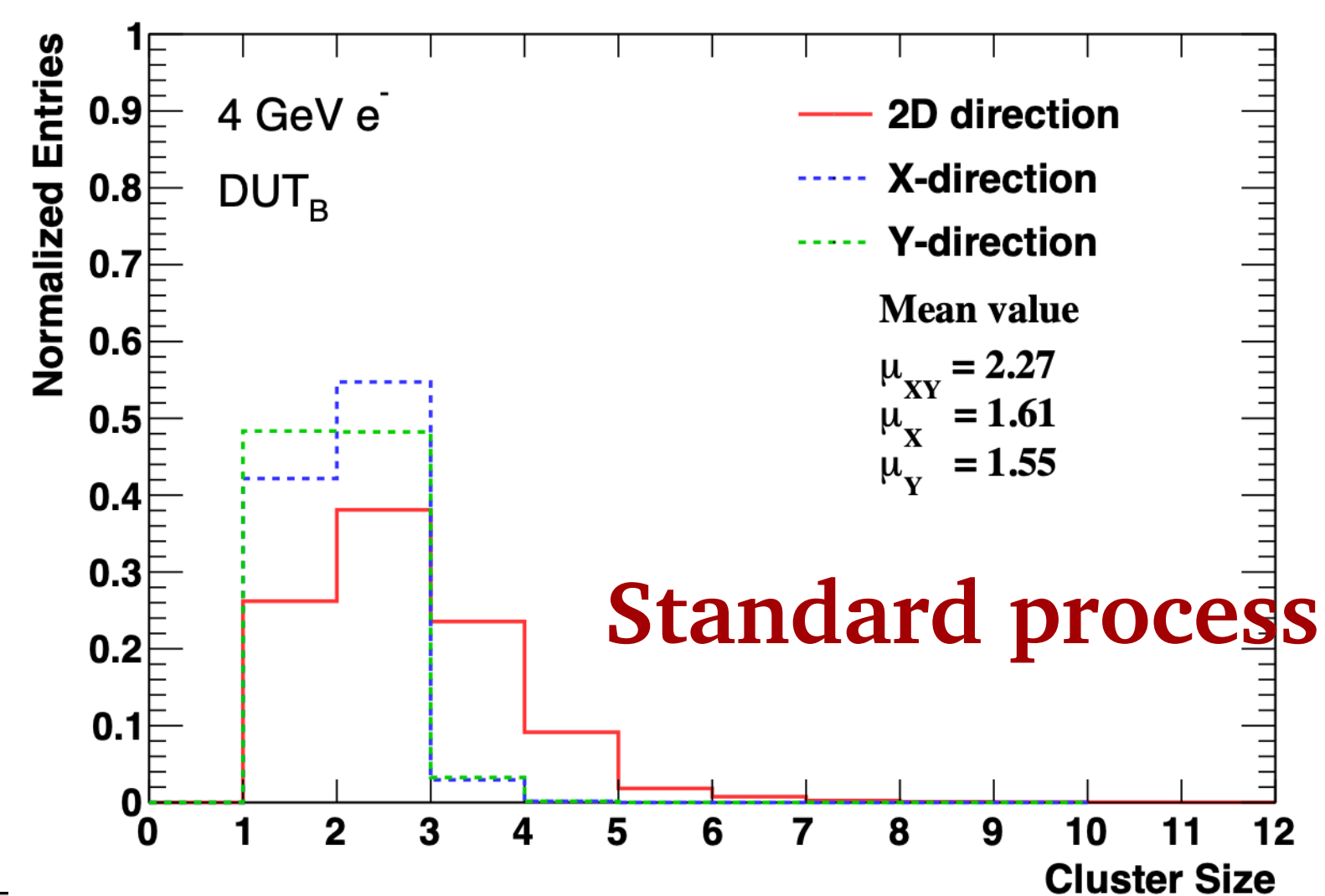
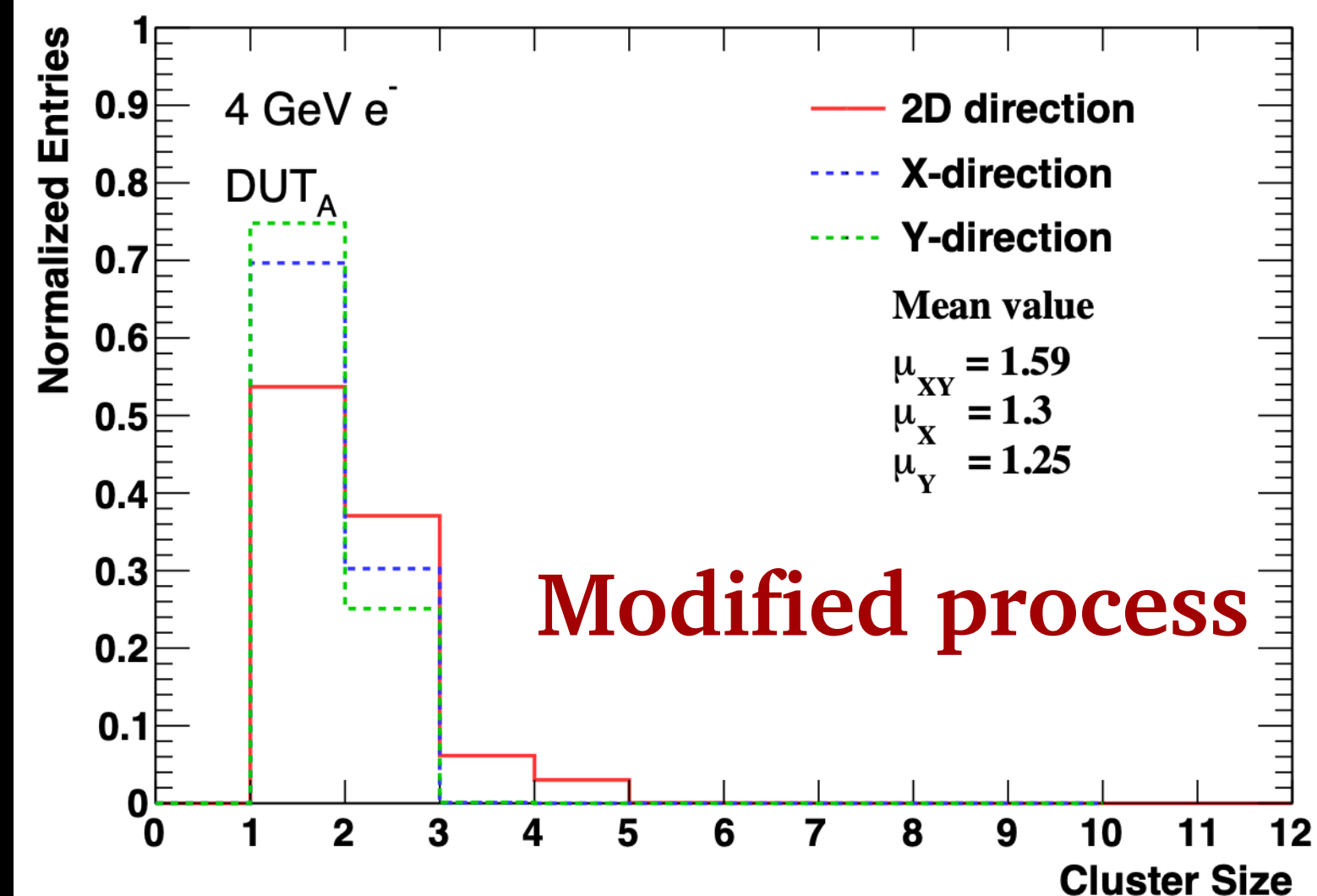


Carbon fiber Support structure of the ladder

- Fabricated support structure prototype of the ladder (IHEP designed)
 - **4 layer of carbon fiber, 0.12mm thick for the whole support**
 - **Shallow design inside ladder support to reduce material**
 - **2~3 time thinner than conventional carbon fiber in China**



Offline analysis results of first test beam



- Less charge sharing effects in modified process with full depletion
- If lowering the threshold, cluster size will be dominated by noise

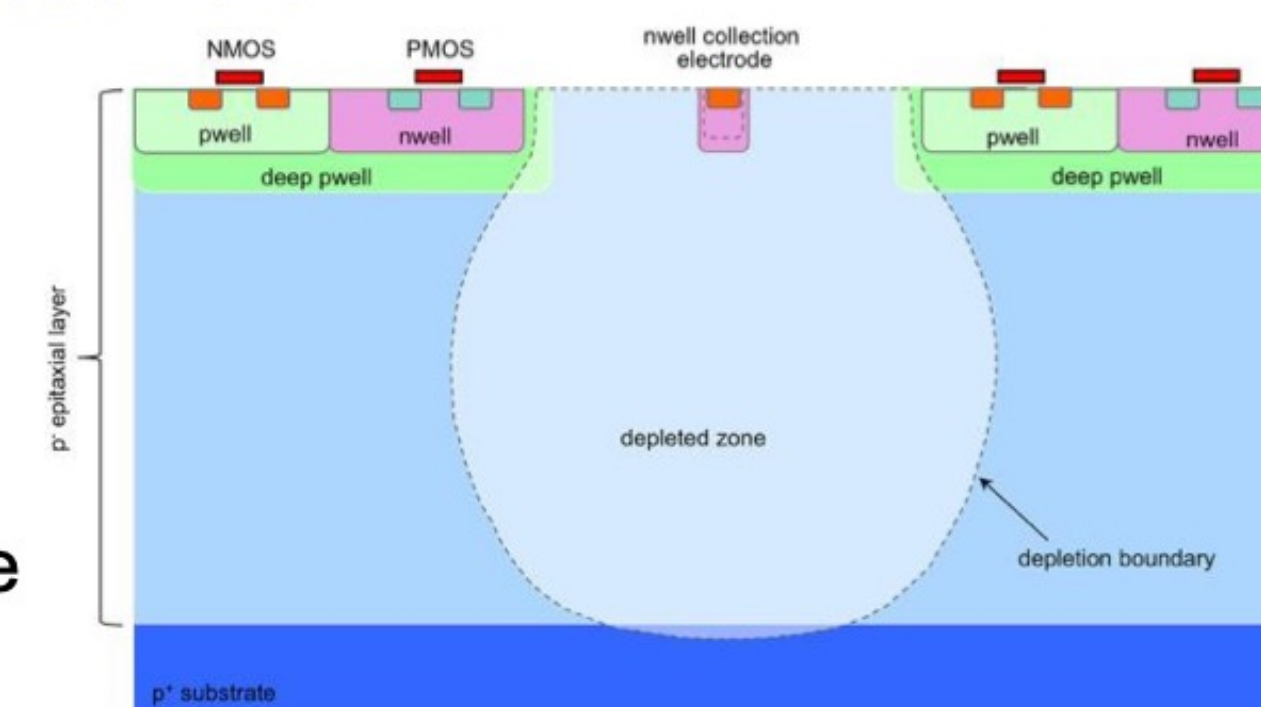
Structure and process of sensor

■ Technology: CMOS Monolithic pixel sensor

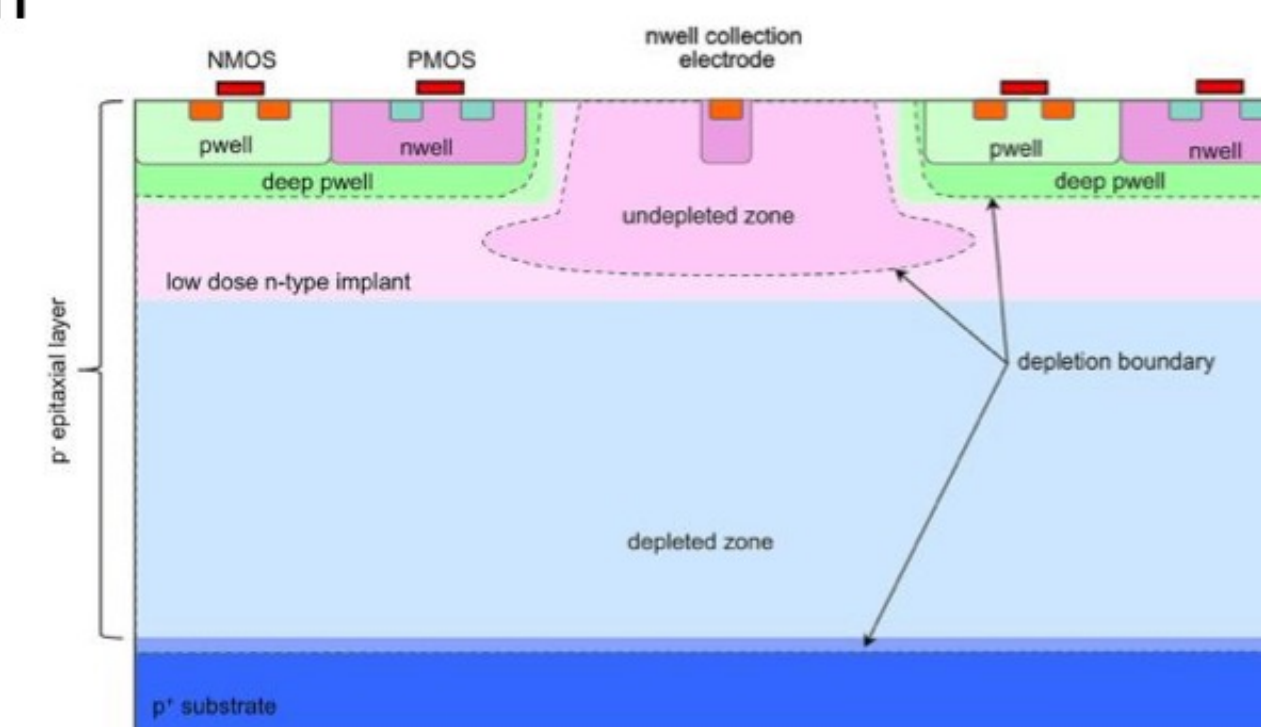
- N-well/P-epitaxial diodes employed collection elements
- Readout electronics integrated on the same Si-substrate
- ➔ Low material budget, low pixel capacitor, easy to assemble

■ Process : TowerJazz CIS 180 nm process

- Process splits:
 - **Standard process**
 - ❑ Baseline option, the only choice available in the MPW submissions
 - **Modified process***
 - ❑ Adding an extra low dose n-type layer based on the standard process, to achieve faster charge collection, thus a better radiation tolerance
 - ❑ **Very difficult to access, the first time available to a Chinese institute**



Standard process



Modified process*

*Reference: NIM, A 871 (2017) 90–96

Additional specifications on the full-scale chip

■ Additional specifications besides the main goals of project

- High detection efficiency → **small dead time**
- Assembled on ladder → **large sensitivity area**
- Low material → **low power density**
- Bunch spacing: Higgs: 680 ns; W: 210 ns; Z: 25 ns

Hit density: 2.5 hits/bunch/cm² for Higgs/W; 0.2 hits/bunch/cm² for Z → **high hit rate**

Specs	Parameter
Hit rate	120 MHz/chip
Data rate	3.84 Gbps (triggerless) ~110 Mbps (trigger)
Dead time	< 500 ns (for 98% efficiency)
Pixel array	512 row × 1024 col
Chip size	~1.4 × 2.56 cm ²
Power Density	< 200 mW/cm ² (air cooling)

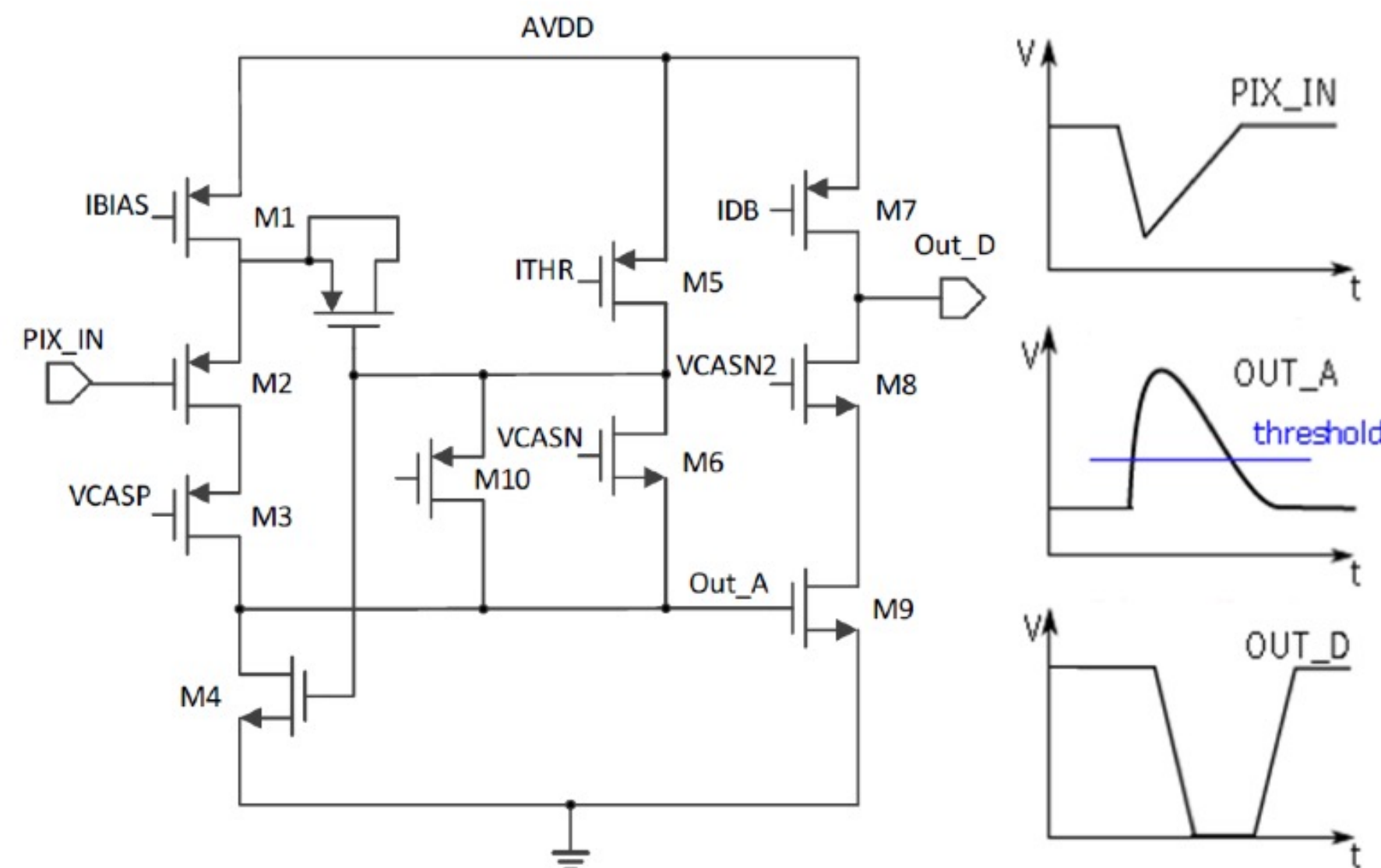
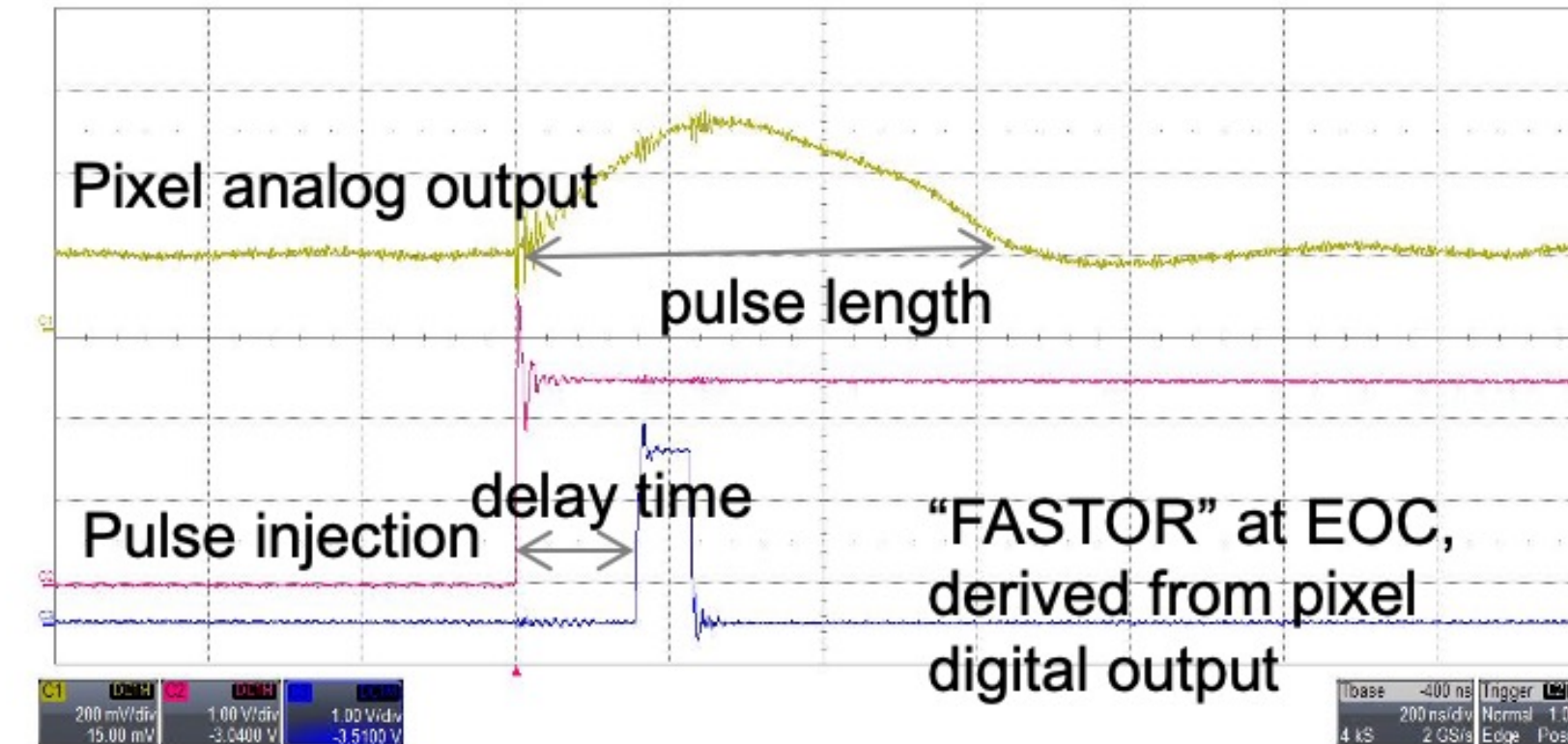
Major innovation: High data-rate processing maintaining good spatial resolution

Pixel analog front-end

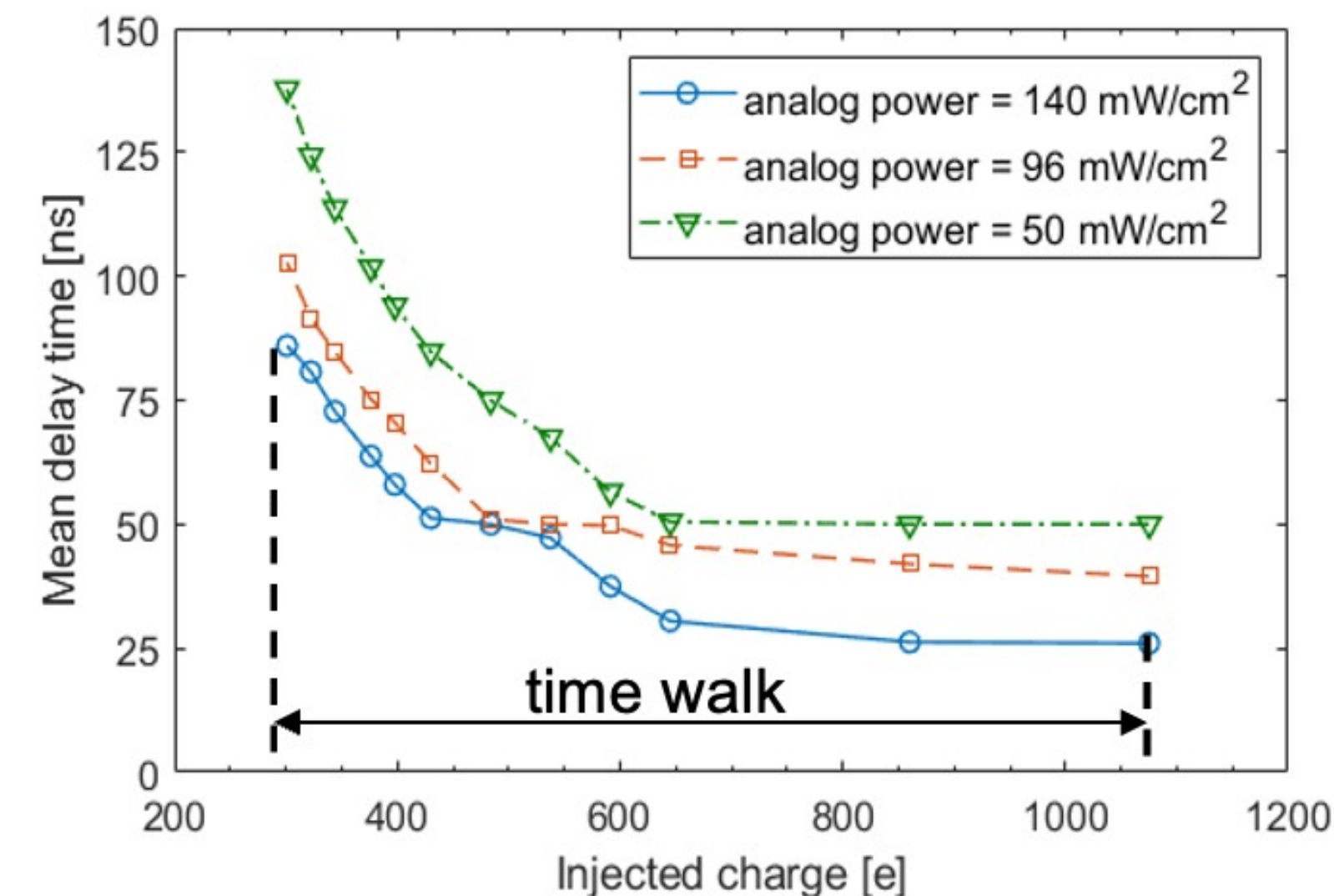


■ Based on ALPIDE* front-end scheme

- modified for faster response
- 'FASTOR' signal delivered to the EOC (end of column) when a pixel fired, timestamps of hit recorded at pos. edge of 'FASTOR'



Schematic of pixel front-end



Delay time of FASTOR with respect to the pulse injection vs. injected charge. The delay time was measured by the timestamp of a step of 25 ns.

CEPC vertex detector R & D

- Three on-going R & D programs on vertex detector
 - Previous update in CEPC day (June 15th) <https://indico.ihep.ac.cn/event/11875/>
- This talk focuses on MOST2 project
 - MOST2 aims to build full-size vertex detector prototype

Funding agency	Process	International collaborators	Objectives of the project	schedule
CEPC MOST1	CMOS	Strasbourg IPHC	Small pixel size design with in-pixel digitization and low power frontend	2016.6-2021.5
MOST2	CMOS	IFAE/Oxford/ Liverpool ...	vertex detector prototyping (Full-size sensor support structure, module ...)	2018.5-2023.4
NSFC	SOI	KEK/SOIPX collaboration	Verification of SOI process with small pixel size and low noise design	2016-